Inspector Checklist for the MON MACT (Maximum Achievable Control Technologies) or the

National Emission Standards for Hazardous Air Pollutants (NESHAP) for Miscellaneous Organic Chemical Manufacturing (known as the MON rule)

40 CFR Parts 63.2430 – 63.2550 or Subpart FFFF

Tables referenced in this checklist are listed separately. Definitions and acronyms are at the end of the checklist.

I. General Conditions

1. What should I do before I visit the facility to be inspected?

☐ Review any available information on the facility. This can be found in agency files containing construction and/or operating permits, reports, and enforcement actions or by contacting facility personnel.

☐ Facility ID/permit number(s)_____
☐ Facility Name/Address_____

_____

_____

_____
☐ Facility Contact Name_____
☐ Phone Number/e-mail/fax_____
☐ Facility Contact Address_____

☐ Inspection History

Inspector	Title/Agency	Phone Number	Date of Inspection
_____	_____	_____	_____
_____	_____	_____	_____
_____	_____	_____	_____
_____	_____	_____	_____

☐ Review any agency or facility specific safety procedures.

2. What type sources are subject to the requirements of the MON rule? 63.2435*

***** It should be noted that the Federal Register 11/10/03 MON rule publication's preamble states that the intent of the MON rule was to cover all miscellaneous organic chemical manufacturers not covered by other MACT standards.

☐ The affected source is subject to the requirements of this rule if they own or operate miscellaneous organic chemical manufacturing process units (MCPU) that are located at, or are part of, a major source of hazardous air pollutants (HAP) emissions. ☐ Yes ☐ No

☐ The source's MCPU includes equipment necessary to operate a miscellaneous organic chemical manufacturing process as listed in the definitions at the end of the checklist. An MCPU also includes any assigned storage tanks and product transfer racks; equipment in open systems that is used to convey or store water having the same concentration and flow characteristics as wastewater; and components such as pumps, compressors, agitators, pressure relief devices, sampling connection systems, open-ended valves or lines, valves, connectors, and instrumentation systems that are used to manufacture any material or family of materials described below in this section. ☐ Yes ☐ No

☐ The sources are listed below:

Alkyd Resins Production	☐ Yes ☐ No
Ammonium Sulfate Production	☐ Yes ☐ No
Benzyltrimethylammonium Chloride Production	☐ Yes ☐ No
Carbonyl Sulfide Production	☐ Yes ☐ No
Chelating Agents Production	☐ Yes ☐ No
Chlorinated Paraffins Production	☐ Yes ☐ No
Ethyllidene Norbomene Production	☐ Yes ☐ No
Explosives Production	☐ Yes ☐ No
Hydrazine Production	☐ Yes ☐ No
Maleic Anhydride Copolymers Production	☐ Yes ☐ No
Manufacture of Paints, Coatings, & Adhesives	☐ Yes ☐ No
OBPA/1, 3-diisocyanate Production	☐ Yes ☐ No
Photographic Chemicals Production	☐ Yes ☐ No
Phthalate Plasticizers Production	☐ Yes ☐ No
Polyester Resins Production	☐ Yes ☐ No
Polymerized Vinylidene Chloride Production	☐ Yes ☐ No
Polymethyl Methacrylate Resins Production	☐ Yes ☐ No
Polyvinyl Acetate Emulsions Production	☐ Yes ☐ No
Polyvinyl Alcohol Production	☐ Yes ☐ No
Polyvinyl Butyral Production	☐ Yes ☐ No
Quaternary Ammonium Comp. Production	☐ Yes ☐ No
Rubber Chemicals Production	☐ Yes ☐ No
Symmetrical Tetrachloropyridine Production	☐ Yes ☐ No

☐ The MCPU produces material or family of materials that is:

☐ An organic chemical or chemicals classified using the 1987 version of SIC code 282, 283, 284, 285, 286, 287, 289, or 386. ☐ Yes ☐ No

☐ An organic chemical or chemicals classified using the 1997 version of NAICS code 325. ☐ Yes ☐ No

☐ Quaternary ammonium compounds and ammonium sulfate produced with caprolactam. ☐ Yes ☐ No

☐ Hydrazine. ☐ Yes ☐ No

☐Organic solvents classified in any of the SIC or NAICS codes listed above that are recovered using nondedicated solvent recovery operations. ☐ Yes ☐ No

☐ The MCPU processes, uses, or produces any of the organic HAP listed in section 112(b) of the CAA or hydrogen halide and halogen HAP, as defined at the end of this checklist. ☐ Yes ☐ No

☐ The MCPU is not an affected source or part of an affected source under another subpart of 40 CFR 63, except for process vents from batch operations within a chemical manufacturing process unit (CMPU), as identified in 40 CFR 63.100(j)(4) (HON Rule). For this situation, the MCPU is the same as the CMPU as defined in 40 CFR 63.100, and the source is subject only to the requirements for batch process vents in the MON rule. ☐ Yes ☐ No

☐ The following operations are exempt from the MON rule.

☐ Research and development facilities, as defined in section 112(c)(7) of the CAA. ☐ Yes ☐ No

☐ The manufacture of ammonium sulfate as a by-product, if the slurry entering the by-product manufacturing process contains 50 parts per million by weight (ppmw) HAP or less or 10 ppmw benzene or less. The source must retain information, data, and analysis to document the HAP concentration in the entering slurry in order to claim this exemption. ☐ Yes ☐ No

☐ The affiliated operations located at an affected source under subparts GG (National Emission Standards for Aerospace Manufacturing and Rework Facilities), KK (National Emission Standards for the Printing and Publishing Industry), JJJJ (NESHAP: Paper and Other Web Coating), MMMM (NESHAP: Surface Coating of Miscellaneous Metal Parts and Products), and SSSS (NESHAP: Surface Coating of Metal Coil) of 40 CFR 63. Affiliated operations include, but are not limited to, mixing or dissolving of coating ingredients; coating mixing for viscosity adjustment, color tint or additive blending, or pH adjustment; cleaning of coating lines and coating line parts; handling and storage of coatings and solvent; and conveyance and treatment of wastewater. ☐ Yes ☐ No

☐ Fabricating operations such as spinning a polymer into its end use. ☐ Yes ☐ No

☐ Production activities described using the 1997 version of NAICS codes 325131, 325181, 325188 (except the requirements do apply to hydrazine), 325314, 325991 (except the requirements do apply to reformulating plastics resins from recycled plastics products), and 325992 (except the requirements do apply to photographic chemicals). ☐ Yes ☐ No

☐ Tall oil recovery systems. ☐ Yes ☐ No

☐ If the predominant use of a transfer rack loading arm or storage tank (including storage tanks in series) is associated with a miscellaneous organic chemical manufacturing process, and the loading arm or storage tank is not part of an affected source under another subpart of 40 CFR 63, then the source must assign the loading arm or storage tank to the MCPU for that miscellaneous organic chemical manufacturing process. ☐ Yes ☐ No

☐ If the predominant use cannot be determined, then the source may assign the loading arm or storage tank to any MCPU that shares it and is subject to the MON rule. ☐ Yes ☐ No

☐ If the use varies from year to year, then the source must base the determination on the utilization that occurred during the year preceding November 10, 2003. ☐ Yes ☐ No

☐ If the loading arm or storage tank was not in operation during that year, the source must base the use on the expected use for the first 5-year period after startup. The source must include the determination in the notification of compliance status report specified in 40 CFR 63.2520(d). The source must redetermine the primary use at least once every 5 years, or any time they implement emissions averaging or pollution prevention after the compliance date. ☐ Yes ☐ No

☐ For nondedicated equipment used to create at least one MCPU, the source may elect to develop process unit groups (PUG), determine the primary product of each PUG, and comply with the requirements of the subpart in 40 CFR part 63 that applies to that primary product as specified in 40 CFR 63.2535(l). ☐ Yes ☐ No

3. What parts of a facility is covered by the MON rule? 63.2440

☐ The MON rule applies to each miscellaneous organic chemical manufacturing affected source. ☐ Yes ☐ No

☐ The miscellaneous organic chemical manufacturing affected source is the facility wide collection of MCPU and heat exchange systems, wastewater, and waste management units that are associated with manufacturing materials described in 40 CFR 63.2435(b)(1). ☐ Yes ☐ No

☐ A new affected source is described below:

> ☐ Each affected source as described in section 2 above for which the source commenced construction or reconstruction after April 4, 2002, and they meet the applicability criteria at the time they commenced construction or reconstruction. ☐ Yes ☐ No
>
> ☐ Each dedicated MCPU that has the potential to emit 10 tons per year (tpy) of any one HAP or 25 tpy of combined HAP, and they commenced construction or reconstruction of the MCPU after April 4, 2002. An MCPU is an affected source in the definition of the term "reconstruction" in 40 CFR 63.2. ☐ Yes ☐ No

☐ An MCPU that is also a CMPU under 40 CFR 63.100 (HON rule) is reconstructed for the purposes of this subpart if, and only if, the CMPU meets the requirements for reconstruction in 40 CFR 63.100(l)(2). ☐ Yes ☐ No

II. Compliance Dates

4. When does an affected source have to comply with the MON rule? 63.2445

☐ If the facility is a new affected source, they must comply according to the requirements below:

> ☐ If the startup of the new affected source is before November 10, 2003, then the source must comply with the requirements for new sources in the MON rule no later than November 10, 2003. ☐ Yes ☐ No
>
> ☐ If the startup of the new affected source is after November 10, 2003, then they must comply with the requirements for new sources in the MON rule upon startup of the affected source. ☐ Yes ☐ No

☐ If the source is an existing source on November 10, 2003, they must comply with the requirements for existing sources in the MON rule no later than November 10, 2006. ☐ Yes ☐ No

☐ The source must meet the notification requirements in 40 CFR 63.2515 according to the schedule in 40 CFR 63.2515 and in 40 CFR 63, subpart A. Some of the notifications must be

submitted before the source is required to comply with the emission limits, operating limits, and work practice standards in the MON rule. ☐ Yes ☐ No

III. Emission Limits, Work Practice Standards, and Compliance Requirements

5. What are the general requirements for complying with the MON rule? 63.2450

☐ The affected source must be in compliance with the emission limits and work practice standards in Tables 1 through 7 of the MON rule all times, except during periods of startup, shutdown, and malfunction (SSM). ☐ Yes ☐ No

☐ The source must meet the requirements specified in 40 CFR 63.2455 through 63.2490 (or the alternative means of compliance in 40 CFR 63.2495, 63.2500, or 63.2505). ☐ Yes ☐ No

☐ The source must meet the notification, reporting, and recordkeeping requirements specified in 40 CFR 63.2515, 63.2520, and 63.2525. ☐ Yes ☐ No

Emissions

☐ **Determine halogenated vent streams**. The source must determine if an emission stream is a halogenated vent stream, as defined in 40 CFR 63.2550 (see definitions), by calculating the mass emission rate of halogen atoms in accordance with 40 CFR 63.115(d)(2)(v). Alternatively, the source may elect to designate the emission stream as halogenated. ☐ Yes ☐ No

☐ **Requirements for combined emission streams**. When organic HAP emissions from different emission types (e.g., continuous process vents, batch process vents, storage tanks, transfer operations, and waste management units) are combined, the source must comply with either of the **two** requirements below:

☐ **#1** Comply with the applicable requirements of the MON rule for each kind of organic HAP emissions in the stream (e.g., the requirements of the MON rule's Table 1 for continuous process vents and the requirements of Table 4 for emissions from storage tanks). ☐ Yes ☐ No

☐ **#2** Determine the applicable requirements based on the hierarchy presented below. For a combined stream, the applicable requirements are specified in the highest-listed six items in the hierarchy that applies to any of the individual streams that make up the combined stream.

> ☐**1.** The requirements of the MON rule Table 2 and 40 CFR 63.2460 for Group 1 batch process vents, including applicable monitoring, recordkeeping, and reporting. ☐ Yes ☐ No
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> ☐**2.** The requirements of the MON rule Table 1 and 40 CFR 63.2455 for continuous process vents that are routed to a control device, as defined in 40 CFR 63.981, including applicable monitoring, recordkeeping, and reporting. ☐ Yes ☐ No
>
> ☐**3.** The requirements of the MON rule Table 5 and 40 CFR 63.2475 for transfer operations, including applicable monitoring, recordkeeping, and reporting. ☐ Yes ☐ No
>
> ☐**4.** The requirements of the MON rule Table 7 and 40 CFR 63.2485 for emissions from waste management units that are used to manage and treat Group 1 wastewater streams and residuals from Group 1 wastewater streams, including applicable monitoring, recordkeeping, and reporting. ☐ Yes ☐ No
>
> ☐**5.** The requirements of the MON rule Table 4 and 40 CFR 63.2470 for control of emissions from storage tanks, including applicable monitoring, recordkeeping, and reporting. ☐ Yes ☐ No

☐**6.** The requirements of the MON rule Table 1 and 40 CFR 63.2455 for continuous process vents after a recovery device including applicable monitoring, recordkeeping, and reporting. ☐ Yes ☐ No

☐ Two exceptions are that:

☐ The source must comply with the requirements in the MON rule Table 3 and 40 CFR 63.2465 for all process vents with hydrogen halide and halogen HAP emissions, and ☐ Yes ☐ No
☐ Recordkeeping requirements for Group 2 applicability or compliance are still required (e.g., the requirement in 63.2525(f) to track the number of batches produced and calculate rolling annual emissions for processes with Group 2 batch process vents). ☐ Yes ☐ No

☐ Except when complying with 40 CFR 63.2485, if the source reduces organic HAP emissions by venting emissions through a closed-vent system to any combination of control devices (except a flare) or recovery devices, the source must meet the requirements of 40 CFR 63.982(c) and the requirements referenced therein. ☐ Yes ☐ No

☐ Except when complying with 40 CFR 63.2485, if the source reduces organic HAP emissions by venting emissions through a closed-vent system to a flare, the source must meet the requirements of 40 CFR 63.982(b) and the requirements referenced therein. ☐ Yes ☐ No

☐ If the source uses a halogen reduction device to reduce hydrogen halide and halogen HAP emissions from halogenated vent streams, the source must meet the requirements of 40 CFR 63.994 and the requirements referenced therein. ☐ Yes ☐ No

☐ If the source uses a halogen reduction device before a combustion device, the source must determine the halogen atom emission rate prior to the combustion device according to the procedures in 40 CFR 63.115(d)(2)(v). ☐ Yes ☐ No

Performance Tests

☐ **Requirements for performance tests**. The requirements specified below apply instead of or in addition to the requirements specified in of this 40 CFR 63.980 -.999 Subpart SS (National Emission Standards for Closed Vent Systems, Control Devices, Recovery Devices and Routing to a Fuel Gas System or a Process).

☐ Conduct gas molecular weight analysis using Method 3, 3A, or 3B in appendix A to 40 CFR 60. ☐ Yes ☐ No
☐ Measure moisture content of the stack gas using Method 4 in appendix A to 40 CFR 60. ☐ Yes ☐ No
☐ If the uncontrolled or inlet gas stream to the control device contains carbon disulfide, the source must conduct emissions testing according to either of the items below.

☐ If the source elects to comply with the percent reduction emission limits in Tables 1 through 7 of the MON rule, and carbon disulfide is the principal organic HAP component (i.e., greater than 50 percent of the HAP in the stream by volume), then the source must use Method 18, or Method 15 (40 CFR 60, appendix A) to measure carbon disulfide at the inlet and outlet of the control device. Use the percent reduction in carbon disulfide as a surrogate for the percent reduction in total organic HAP emissions. ☐ Yes ☐ No
☐ If the source elects to comply with the outlet total organic compound (TOC) concentration emission limits in Tables 1 through 7 of the MON rule, and the uncontrolled or inlet gas stream to the control device contains greater than 10 percent (volume concentration) carbon disulfide, the source must use Method 18

or Method 15 to separately determine the carbon disulfide concentration. Calculate the total HAP or TOC emissions by totaling the carbon disulfide emissions measured using Method 18 or 15 and the other HAP emissions measured using Method 18 or 25A. ☐ Yes ☐ No

☐ As an alternative to using Method 18, Method 25/25A, or Method 26/26A of 40 CFR 60, appendix A, to comply with any of the emission limits specified in Tables 1 through 7 of the MON rule, the source may use Method 320 of 40 CFR 60, appendix A. When using Method 320, the source must follow the analyte spiking procedures of section 13 of Method 320, unless the source demonstrates that the complete spiking procedure has been conducted at a similar source. ☐ Yes ☐ No

☐ 40 CFR 63.997(c)(1) (National Emission Standards for Closed Vent Systems, Control Devices, Recovery Devices and Routing to a Fuel Gas System or a Process) does not apply. For the purposes of the MON rule, results of all initial compliance demonstrations must be included in the notification of compliance status report, which is due 150 days after the compliance date, as specified in 40 CFR 63.2520(d)(1). ☐ Yes ☐ No

☐ **Design evaluation**. To determine the percent reduction of a small control device, the source may elect to conduct a design evaluation as specified in 40 CFR 63.1257(a)(1) (National Emission Standards for Pharmaceuticals Production) instead of a performance test as specified in subpart SS of 40 CFR 63 (National Emission Standards for Closed Vent Systems, Control Devices, Recovery Devices and Routing to a Fuel Gas System or a Process). The source must establish the value(s) and basis for the operating limits as part of the design evaluation. ☐ Yes ☐ No

☐ **Outlet concentration correction for supplemental gases**. In 40 CFR 63.997(e)(2)(iii)(C), (Subpart SS - National Emission Standards for Closed Vent Systems, Control Devices, Recovery Devices and Routing to a Fuel Gas System or a Process) the correction to 3 percent oxygen for emission streams at the outlet of combustion devices is required if the source adds supplemental gases, as defined in 40 CFR 63.2550 (see definitions), to the vent stream or manifold. ☐ Yes ☐ No

Monitoring

☐ **Continuous emissions monitoring systems**. Each continuous emissions monitoring system (CEMS) must be installed, operated, and maintained according to the requirements in 40 CFR 63.8 and according to the items below. ☐ Yes ☐ No

☐ Each CEMS must be installed, operated, and maintained according to the applicable Performance Specification of 40 CFR 60, appendix B (quality of installation specifications), and according to the three requirements below. **(see exception marked *** below)** For any CEMS meeting Performance Specification 8, the source must also comply with appendix F, procedure 1 of 40 CFR 60. ☐ Yes ☐ No

☐ The source must determine the calibration gases and reporting units for TOC CEMS in accordance to:

☐ For CEMS meeting Performance Specification 9 or 15 requirements, determine the target analyte(s) for calibration using either process knowledge of the control device inlet stream or the screening procedures of Method 18 on the control device inlet stream. ☐ Yes ☐ No

☐ For CEMS meeting Performance Specification 8 used to monitor performance of a combustion device, calibrate the instrument on the predominant organic HAP and report the results as carbon (C 1), and use Method 25A or any approved alternative as the reference method for the relative accuracy tests. ☐ Yes ☐ No

☐ For CEMS meeting Performance Specification 8 used to monitor performance of a noncombustion device, determine the predominant organic HAP using either process knowledge or the screening procedures of Method 18 on the control device inlet stream, calibrate the monitor on the predominant organic HAP, and report the results as C1. Use Method 18, ASTM D6420–99, or any approved alternative as the reference method for the relative accuracy tests, and report the results as C1. ☐ Yes ☐ No

☐ ***If the source wishes to use a CEMS other than an Fourier Transform Infrared Spectroscopy (FTIR) meeting the requirements of Performance Specification 15 to measure hydrogen halide and halogen HAP before the US EPA promulgates a Performance Specification for such CEMS, the source must prepare a monitoring plan and submit it for approval in accordance with the procedures specified in 40 CFR 63.8. ☐ Yes ☐ No

☐ The source must conduct a performance evaluation of each CEMS according to the requirements in 40 CFR 63.8 and according to the applicable Performance Specification of 40 CFR part 60, appendix B, except that the schedule in 40 CFR 63.8(e)(4) does not apply, and the results of the performance evaluation must be included in the notification of compliance status report. ☐ Yes ☐ No

☐ The CEMS data must be reduced to operating day or operating block averages computed using valid data consistent with the data availability requirements specified in 40 CFR 63.999(c)(6)(i)(B) through (D), except monitoring data also are sufficient to constitute a valid hour of data if measured values are available for at least two of the 15-minute periods during an hour when calibration, quality assurance, or maintenance activities are being performed. An operating block is a period of time from the beginning to end of batch operations within a process. Operating block averages may be used only for batch process vent data. ☐ Yes ☐ No

☐ If the source adds supplemental gases, the source must correct the measured concentrations in accordance to the **outlet concentration correction for supplemental gases** section above and 40 CFR 63.2460(c)(6). ☐ Yes ☐ No

☐ **Continuous parameter monitoring**. The provisions below apply in addition to the requirements for continuous parameter monitoring system (CPMS) in 40 CFR 63 subpart SS.

☐ The source must record the results of each calibration check and all maintenance performed on the CPMS as specified in 40 CFR 63.998(c)(1)(ii)(A). ☐ Yes ☐ No

☐ When 40 CFR 63 subpart SS uses the term “a range” or “operating range” of a monitored parameter, it means an “operating limit” for a monitored parameter. ☐ Yes ☐ No

☐ As an alternative to measuring pH as specified in 40 CFR 63.994(c)(1)(i), the source may elect to continuously monitor the caustic strength of the scrubber effluent. ☐ Yes ☐ No

☐ As an alternative to the inlet and outlet temperature monitoring requirements for catalytic incinerators as specified in 40 CFR 63.988(c)(2), the source may elect to comply with the requirements specified below.

☐ Monitor the inlet temperature as specified in 40 CFR 63 subpart SS. ☐ Yes ☐ No

☐ Check the activity level of the catalyst at least every 12 months and take any necessary corrective action, such as replacing the catalyst to ensure that the catalyst is performing as designed. ☐ Yes ☐ No

☐ Maintain records of the annual checks of catalyst activity levels and the subsequent corrective actions. ☐ Yes ☐ No

Reporting, etc.

☐ **Startup, shutdown, and malfunction (SSM)**. 40 CFR 63.152(f)(7)(ii) through (iv) (Subpart G) and 40 CFR 63.998(b)(2)(iii) and (b)(6)(i)(A), which apply to the exclusion of monitoring data collected during periods of SSM from daily averages, do not apply to the MON rule. ☐ Yes ☐ No

☐ **Reporting**. When 40 CFR 63.2455 through 63.2490 reference other parts of the MON Rule that use the term "periodic report," it means "compliance report" for the purposes of this rule. The compliance report must include the information specified in 40 CFR 63.2520(e), as well as the information specified other referenced rules. ☐ Yes ☐ No

☐ When there are conflicts between the MON rule and other referenced rules for the due dates of reports required by the MON rule, reports must be submitted according to the due dates presented in the MON rule. ☐ Yes ☐ No
☐ Excused excursions, as defined in subparts G and SS of 40 CFR 63, are not allowed. ☐ Yes ☐ No

☐ The option in 40 CFR 63.997(e)(2)(iv)(C) to demonstrate compliance with a percent reduction emission limit by measuring TOC is not allowed. ☐ Yes ☐ No

☐ The source may not use a flare to control halogenated vent streams or hydrogen halide and halogen HAP emissions. ☐ Yes ☐ No

☐ Opening a safety device, as defined in 40 CFR 63.2550 (see definitions), is allowed at any time conditions require it to avoid unsafe conditions. ☐ Yes ☐ No

☐ If an emission stream contains energetics or organic peroxides that, for safety reasons, cannot meet an applicable emission limit specified in Tables 1 through 7 of the MON rule, then the source must submit documentation in their precompliance report explaining why an undue safety hazard would be created if the air emission controls were installed, and the source must describe the procedures that the source will implement to minimize HAP emissions from these vent streams. ☐ Yes ☐ No

☐ **Surge control vessels and bottoms receivers**. For each surge control vessel or bottoms receiver that meets the capacity and vapor pressure thresholds for a Group 1 storage tank, the source must meet emission limits and work practice standards specified in Table 4 of the MON rule. ☐ Yes ☐ No

☐ For the purposes of determining Group status for continuous process vents, batch process vents, and storage tanks in 40 CFR 63.2455, 63.2460, and 63.2470, hydrazine is to be considered an organic HAP. ☐ Yes ☐ No

Vents

6. What requirements must the source meet for continuous process vents? 63.2455

☐ The affected source must meet each emission limit in Table 1 of the MON rule that applies to their continuous process vents, and they must meet each applicable requirement specified below. ☐ Yes ☐ No

☐ For each continuous process vent, the source must either designate the vent as a Group 1 continuous process vent or determine the total resource effectiveness (TRE) index value as specified in 40 CFR 63.115(d) (Subpart G—National Emission Standards for Organic Hazardous Air Pollutants From the Synthetic Organic Chemical Manufacturing Industry for Process Vents, Storage Vessels, Transfer Operations, and Wastewater), except as listed below. ☐ Yes ☐ No

☐ The source is not required to determine the Group status or the TRE index value for any continuous process vent that is combined with Group 1 batch process vents before a control device or recovery device because the requirements of 40 CFR 63.2450(c)(2)(i) apply to the combined stream. ☐ Yes ☐ No

☐ When a TRE index value of 4.0 is referred to in 40 CFR 63.115(d), TRE index values of 5.0 for existing affected sources and 8.0 for new and reconstructed affected sources apply for the purposes of the MON rule. ☐ Yes ☐ No

☐ When 40 CFR 63.115(d) refers to "emission reductions specified in 40 CFR 63.113(a)," the reductions specified in Table 1 of the MON rule apply for the purposes of the MON rule. ☐ Yes ☐ No

☐ If the source uses a recovery device to maintain the TRE above a specified threshold, the source must meet the requirements of 40 CFR 63.982(e) and the requirements referenced therein, except as specified in 40 CFR 63.2450 and the requirement below. ☐ Yes ☐ No

☐ When 40 CFR 63.993 uses the phrase "the TRE index value is between the level specified in a referencing subpart and 4.0," the phrase "the TRE index value is >1.9 but ≤5.0" applies for an existing affected source, and the phrase "the TRE index value is >5.0 but ≤8.0" they apply for new and reconstructed affected sources, for the purposes of the MON rule. ☐ Yes ☐ No

7. What requirements must the source meet for batch process vents? 63.2460

☐ The source must meet each emission limit in Table 2 of the MON rule, and the source must meet each applicable requirement specified below. ☐ Yes ☐ No

☐ **Group status**. If a process has batch process vents, as defined in 40 CFR 63.2550 (see definitions), the source must determine the group status of the batch process vents by determining and summing the uncontrolled organic HAP emissions from each of the batch process vents within the process using the procedures specified in 40 CFR 63.1257(d)(2)(i) and (ii) (Subpart GGG--National Emission Standards for Pharmaceuticals Production), except as specified below. ☐ Yes ☐ No

☐ To calculate emissions caused by the heating of a vessel to a temperature lower than the boiling point, the source must use the procedures in 40 CFR 63.1257(d)(2)(i)(C)(3). ☐ Yes ☐ No

☐ To calculate emissions from depressurization, the source must use the procedures in 40 CFR 63.1257(d)(2)(i)(D)(10). ☐ Yes ☐ No

☐ To calculate emissions from vacuum systems for the purposes of the MON rule, the receiving vessel is part of the vacuum system, and terms used in Equation 33 to 40 CFR part 63, subpart GGG, are defined as follows:

P system = absolute pressure of receiving vessel; P i = partial pressure of the HAP at the receiver temperature; P j = partial pressure of condensable (including HAP) at the receiver temperature; MW i = molecular weight of the individual HAP in the emission stream, with HAP partial pressures calculated at the temperature of the receiver. ☐ Yes ☐ No

☐ The source may elect to designate the batch process vents within a process as Group 1 and not calculate uncontrolled emissions under either of the situations described below. ☐ Yes ☐ No

☐ If the source complies with the alternative standard specified in 40 CFR 63.2505. ☐ Yes ☐ No

☐ If all Group 1 batch process vents within a process are controlled; the source must conduct the performance test under hypothetical worst case conditions, as defined in 40 CFR 63.1257(b)(8)(i)(B); and the emission profile is based on capture and control system limitations as specified in 40 CFR 63.1257(b)(8)(ii)(C). ☐ Yes ☐ No

☐ Exceptions to the requirements in 40 CFR 63 subpart SS (National Emission Standards for Closed Vent Systems, Control Devices, Recovery Devices and Routing to a Fuel Gas System or a Process) are specified below.

☐ **Process condensers**. Process condensers, as defined in 40 CFR 63.1251, are not considered to be control devices for batch process vents. ☐ Yes ☐ No

☐ **Initial compliance**.

☐ To demonstrate initial compliance with a percent reduction emission limit in Table 2 of the MON rule, the source must compare the sums of the controlled and uncontrolled emissions for the applicable Group 1 batch process vents within the process and show that the specified reduction is met. ☐ Yes ☐ No

☐ When the source conducts a performance test or design evaluation for a control device used to control emissions from batch process vents, they must establish emission profiles and conduct the test under worst-case conditions according to 40 CFR 63.1257(b)(8) instead of under normal operating conditions as specified in 40 CFR 63.7(e)(1). The requirements in 40 CFR 63.997(e)(1)(i) and (iii) also do not apply for performance tests conducted to determine compliance with the emission limits for batch process vents. References in 40 CFR 63.997(b)(1) to "methods specified in §63.997(e)" include the methods specified in 40 CFR 63.1257(b)(8). ☐ Yes ☐ No

☐ As an alternative to conducting a performance test or design evaluation for a condenser, the source may determine controlled emissions using the procedures specified in 40 CFR 63.1257(d)(3)(i)(B). ☐ Yes ☐ No

☐ When 40 CFR 63.1257(d)(3)(i)(B)(7) specifies that condenser-controlled emissions from an air dryer must be calculated using Equation 11 of 40 CFR part 63, subpart GGG, with "V equal to the air flow rate," it means "V equal to the dryer outlet gas flow rate," for the purposes of the MON rule. Alternatively, the source may use Equation 12 of 40 CFR part 63, subpart GGG, with V equal to the dryer inlet air flow rate. Account for time as appropriate in either equation. ☐ Yes ☐ No

☐ The source must demonstrate that each process condenser is properly operated according to the procedures specified in 40 CFR 63.1257(d)(2)(i)(C)(4)(ii) and (d)(3)(iii)(B). The reference in 40 CFR 63.1257 (d)(3)(iii)(B) to the alternative standard in 40 CFR 63.1254(c) means 40 CFR 63.2505 for the purposes of the MON rule. As an alternative to measuring the exhaust gas temperature, as required by 40 CFR 63.1257(d)(3)(iii)(B), the source may elect to measure the liquid temperature in the receiver. ☐ Yes ☐ No

☐ The source must conduct a subsequent performance test or compliance demonstration equivalent to an initial compliance demonstration within 180 days of a change in the worst-case conditions. ☐ Yes ☐ No

☐ **Establishing operating limits**. The source must establish operating limits under the conditions required for their initial compliance demonstration, except that they may elect

to establish operating limit(s) for conditions other than those under which a performance test was conducted as specified below. ☐ Yes ☐ No

☐ The operating limits may be based on the results of the performance test and supplementary information such as engineering assessments and manufacturer's recommendations. These limits may be established for conditions as unique as individual emission episodes for a batch process. The source must provide rationale in the precompliance report for the specific level for each operating limit, including any data and calculations used to develop the limit and a description of why the limit indicates proper operation of the control device. Procedures that have not been approved by the local air pollution compliance agency and determination of the operating limit using these procedures is subject to review and approval by that agency. ☐ Yes ☐ No

☐ If applicable, the source may elect to establish separate monitoring levels for different emission episodes within a batch process, and they must maintain records in their daily schedule or log of processes indicating each point at which the source changes from one operating limit to another, even if the duration of the monitoring for an operating limit is less than 15 minutes. The source must maintain a daily schedule or log of processes according to 40 CFR 63.2525(c). ☐ Yes ☐ No

☐ **Averaging periods**. As an alternative to the requirement for daily averages in 40 CFR 63.998(b)(3), the source may determine averages for operating blocks. An operating block is a period of time that is equal to the time from the beginning to end of batch process operations within a process. ☐ Yes ☐ No

☐ **Periodic verification**. For a control device with total inlet HAP emissions less than 1 tpy, the source must establish an operating limit(s) for a parameter(s) that will measure and record at least once per averaging period (i.e., daily or block) to verify that the control device is operating properly. The source may elect to measure the same parameter(s) that is required for control devices that control inlet HAP emissions equal to or greater than 1 tpy. If the parameter will not be measured continuously, the source must request approval of their proposed procedure in the precompliance report. The source must identify the operating limit(s) and the measurement frequency, and they must provide rationale to support how these measurements demonstrate the control device is operating properly. ☐ Yes ☐ No

☐ **Outlet concentration correction for supplemental gases**. If the source uses a control device other than a combustion device to comply with a TOC, organic HAP, or hydrogen halide and halogen HAP outlet concentration emission limit for batch process vents, they must correct the actual concentration for supplemental gases using Equation 1 of this section; the source may use process knowledge and representative operating data to determine the fraction of the total flow due to supplemental gas.

$$C_a = C_m \left(\frac{Q_s + Q_a}{Q_a} \right) \qquad (Eq.\ 1)$$

Where:

Ca = corrected outlet TOC, organic HAP, or hydrogen halide and halogen HAP concentration, dry basis, ppmv;

Cm = actual TOC, organic HAP, or hydrogen halide and halogen HAP concentration measured at control device outlet, dry basis, ppmv;

Qa = total volumetric flowrate of all gas streams vented to the control device, except supplemental gases;

Qs = total volumetric flowrate of supplemental gases. ☐ Yes ☐ No

☐ If flow to a control device could be intermittent, the source must install, calibrate, and operate a flow indicator at the inlet or outlet of the control device to identify periods of no flow. Periods of no flow may not be used in daily or block averages, and it may not be used in fulfilling a minimum data availability requirement. ☐ Yes ☐ No

8. What requirements must the affected source meet for process vents that emit hydrogen halide and halogen HAP or PM HAP? 63.2465

☐ The source must meet each emission limit in Table 3 of the MON rule that applies, and they must meet each applicable requirement below. ☐ Yes ☐ No

☐ If any process vents within a process emit hydrogen halide and halogen HAP, the source must determine and sum the uncontrolled hydrogen halide and halogen HAP emissions from each of the process vents within the process using the procedures specified in 40 CFR 63.1257(d)(2)(i) and (ii). ☐ Yes ☐ No
☐ If collective uncontrolled hydrogen halide and halogen HAP emissions from the process vents within a process are greater than or equal to 1,000 pounds per year (lb/yr), the source must comply with 40 CFR 63.994 and the requirements referenced therein, except as specified below. ☐ Yes ☐ No

☐ When 40 CFR 63.994(b)(1) requires a performance test, the source may elect to conduct a design evaluation in accordance with 40 CFR 63.1257(a)(1). ☐ Yes ☐ No
☐ When 40 CFR 63.994(b)(1) refers to "a combustion device followed by a halogen scrubber or other halogen reduction device," it means any combination of control devices used to meet the emission limits specified in Table 3 of the MON rule. ☐ Yes ☐ No
☐ Section 40 CFR 63.994(b)(2) does not apply for the purposes of this section. ☐ Yes ☐ No

☐ To demonstrate compliance with the particulate matter (PM) HAP emission limit for new sources in Table 3 of the MON rule, the source must comply with the requirements below.

☐ Use Method 5 of appendix A of 40 CFR part 60 to determine the concentration of PM HAP at the inlet and outlet of a control device. ☐ Yes ☐ No
☐ Comply with the monitoring requirements specified in 40 CFR 63.1366(b)(1)(xi) for each fabric filter used to control PM HAP emissions. ☐ Yes ☐ No

Storage Tanks

9. What requirements must the affected source meet for storage tanks? 63.2470

☐ The source must meet each emission limit in Table 4 of the MON rule that applies to their storage tanks, and also the applicable requirement specified below.

☐ If the source reduces organic HAP emissions by venting emissions to a fuel gas system or process, they must meet the requirements of 40 CFR 63.982(d) (Subpart SS) and the requirements referenced therein. ☐ Yes ☐ No
☐ Exceptions to subparts SS and WW of 40 CFR 63.

☐ If the source conducts a performance test or design evaluation for a control device used to control emissions only from storage tanks, they must establish operating limits, conduct monitoring, and keep records using the same procedures as required in subpart SS of 40 CFR 63 for control devices used to

reduce emissions from process vents instead of the procedures specified in 40 CFR 63.985(c), 63.998(d)(2)(i), and 63.999(b)(2). ☐ Yes ☐ No

☐ When the term "storage vessel" is used in subparts SS and WW of 40 CFR 63, the term "storage tank," as defined in 40 CFR 63.2550 (see definitions) applies for the purposes of the MON rule. ☐ Yes ☐ No

☐ Planned routine maintenance. The emission limits in Table 4 of the MON rule for control devices used to control emissions from storage tanks do not apply during periods of planned routine maintenance. Periods of planned routine maintenance of each control device, during which the control device does not meet the emission limit specified in Table 4 of the MON rule, must not exceed 240 hours per year (hr/yr). The source may submit an application to the local air pollution control agency requesting an extension of this time limit to a total of 360 hr/yr. The application must explain why the extension is needed, it must indicate that no material will be added to the storage tank between the time the 240-hr limit is exceeded and the control device is again operational, and it must be submitted at least 60 days before the 240-hr limit will be exceeded. ☐ Yes ☐ No

☐ Vapor balancing alternative. As an alternative to the emission limits specified in Table 4 of the MON rule, the source may elect to implement vapor balancing in accordance with 40 CFR 63.1253(f) (Subpart GGG - Pharmaceuticals), except as specified below. ☐ Yes ☐ No

☐ When 40 CFR 63.1253(f)(6)(i) refers to a 90 percent reduction, 95 percent applies for the purposes of the MON rule. ☐ Yes ☐ No

☐ To comply with 40 CFR 63.1253(f)(6)(i), the owner or operator of an offsite cleaning and reloading facility must comply with 40 CFR 63.2445 through 63.2550 (see definitions) instead of complying with 40 CFR 63.1253(f)(7)(ii). ☐ Yes ☐ No

☐ The source may elect to set a pressure relief device to a value less than the 2.5 pounds per square inch gage pressure (psig) required in 40 CFR 63.1253 (f)(5) if the source provides rationale in their notification of compliance status report explaining why the alternative value is sufficient to prevent breathing losses at all times. ☐ Yes ☐ No

Transfer Racks

10. What requirements must the affected source meet for transfer racks? 63.2475

☐ The source must comply with each emission limit and work practice standard in Table 5 of the MON rule that applies to their transfer racks, and they must meet each applicable requirement below. ☐ Yes ☐ No

☐ When the term "high throughput transfer rack" is used in subpart SS of 40 CFR 63, the term "Group 1 transfer rack," as defined in 40 CFR 63.2550 (see definitions), applies for the purposes of this subpart. ☐ Yes ☐ No

☐ If the source reduces organic HAP emissions by venting emissions to a fuel gas system or process, they must meet the requirements of 40 CFR 63.982(d) (subpart SS) and the requirements referenced therein. ☐ Yes ☐ No

Equipment Leaks

11. What requirements must the affected source meet for equipment leaks? 63.2480

☐ The source must meet each requirement in Table 6 of the MON rule that applies to their equipment leaks, except as specified below. ☐ Yes ☐ No

☐ The requirements for pressure testing in 40 CFR 63.1036(b) (subpart UU – Equipment Leaks) may be applied to all processes, not just batch processes. ☐ Yes ☐ No
☐ For the purposes of the MON rule, pressure testing for leaks in accordance with 40 CFR 63.1036(b) is not required after reconfiguration of an equipment train if flexible hose connections are the only disturbed equipment. ☐ Yes ☐ No

Wastewater and Liquid Streams

12. What requirements must the affected source meet for wastewater streams and liquid streams in open systems within an MCPU? 63.2485

☐ The source must meet each requirement in Table 7 to this subpart that applies to the source wastewater streams and liquid streams in open systems within an MCPU, except as specified below. ☐ Yes ☐ No

☐ **Wastewater HAP**. Where 40 CFR 63.105 and 40 CFR 63.132 through 63.148 refer to compounds in Table 9 of subpart G of 40 CFR 63, the compounds in Tables 8 and 9 of the MON apply. ☐ Yes ☐ No

☐ **Group 1 wastewater**. 40 CFR 63.132(c)(1) (i) and (ii) subpart G do not apply. For the purposes of the MON rule, a process wastewater stream is Group 1 for compounds in Tables 8 and 9 of the MON rule if any of the conditions specified below are met. ☐ Yes ☐ No☐

☐**C1.** The total annual average concentration of compounds in Table 8 of the MON rule is greater than 50 ppmw, and the combined total annual average concentration of compounds in Tables 8 and 9 of the MON rule is greater than or equal to 10,000 ppmw at any flowrate. ☐ Yes ☐ No☐
☐**C2.** The total annual average concentration of compounds Table 8 of the MON rule is greater than 50 ppmw, the combined total annual average concentration of compounds in Tables 8 and 9 of the MON rule is greater than or equal to 1,000 ppmw, and the annual average flowrate is greater than or equal to 1 l/min. ☐ Yes ☐ No
☐**C3.** The total annual average concentration of compounds in Table 8 of the MON rule is less than or equal to 50 ppmw, the total annual average concentration of compounds in Table 9 of the MON rule is greater than or equal to 30,000 ppmw at an existing source or greater than or equal to 4,500 ppmw at a new source, and the total annual load of compounds in Table 9 of the MON rule is greater than or equal to 1 tpy. ☐ Yes ☐ No

☐ **Wastewater tank requirements**.
☐ When 40 CFR 63.133 and 63.147 reference floating roof requirements in 40 CFR 63.119 and 63.120, the corresponding requirements in subpart WW of 40 CFR 63 may be applied for the purposes of the MON rule. ☐ Yes ☐ No
☐ When 40 CFR 63.133 refers to Table 9 of subpart G of 40 CFR 63, the maximum true vapor pressure in the table shall be limited to the HAP listed in Tables 8 and 9 of the MON rule. ☐ Yes ☐ No
☐ For the purposes of the MON rule, the requirements of 40 CFR 63.133(a)(2) are satisfied by operating and maintaining a fixed roof if the source demonstrates that the total soluble and partially soluble HAP emissions from the wastewater tank are no more than 5 percent higher than the emissions would be if the contents of the wastewater tank were not heated, treated by an exothermic reaction, or sparged. ☐ Yes ☐ No
☐ The emission limits specified in 40 CFR 63.133(b)(2) and 63.139 for control devices used to control emissions from wastewater tanks do not apply during

periods of planned routine maintenance of the control device(s) of no more than 240 hr/yr. The source may request an extension to a total of 360 hr/yr in accordance with the procedures specified in 40 CFR 63.2470(d) (MON rule).
☐ Yes ☐ No

☐ **Individual drain systems**. The provisions of 40 CFR 63.136(e)(3) apply except as specified below.

☐ A sewer line connected to drains that are in compliance with 40 CFR 63.136(e)(1) may be vented to the atmosphere, provided that the sewer line entrance to the first downstream junction box is water sealed and the sewer line vent pipe is designed as specified in 40 CFR 63.136(e)(2)(ii)(A). ☐ Yes ☐ No

☐ **Closed-vent system requirements**. When 40 CFR 63.148(k) refers to closed vent systems that are subject to the requirements of 40 CFR 63.172, the requirements of either 40 CFR 63.172 or 40 CFR 63.1034 apply for the purposes of the MON rule.
☐ Yes ☐ No

☐ **Halogenated vent stream requirements**. For each halogenated vent stream from a Group 1 wastewater stream or residual removed from a Group 1 wastewater stream that is vented through a closed-vent system to a combustion device to reduce organic HAP emissions, the source must meet the same emission limits as specified for batch process vents in item 2 of Table 2 to the MON rule. ☐ Yes ☐ No

☐ **Alternative test methods**.

☐ As an alternative to the test methods specified in 40 CFR 63.144(b)(5)(i), the source may use Method 8260 or 8270 as specified in 40 CFR 63.1257(b)(10)(iii).
☐ Yes ☐ No

☐ As an alternative to using the methods specified in 40 CFR 63.144(b)(5)(i), the source may conduct wastewater analyses using Method 1666 or 1671 of 40 CFR 136 and comply with the sampling protocol requirements specified in 40 CFR 63.144(b)(5)(ii). The validation requirements specified in 40 CFR 63.144(b)(5)(iii) do not apply if the source use Method 1666 or 1671 of 40 CFR 136.
☐ Yes ☐ No

☐ As an alternative to using Method 18 of 40 CFR 60, as specified in 40 63.139(c)(1)(ii) and 63.145(i)(2), the source may elect to use Method 25A of 40 CFR 60 as specified in 40 CFR 63.997. ☐ Yes ☐ No

☐ **Offsite management and treatment option**.

☐ If the source ships wastewater to an offsite treatment facility that meets the requirements of 40 CFR 63.138(h), they may elect to document in their notification of compliance status report that the wastewater will be treated as hazardous waste at a facility that meets the requirements of 40 CFR 63.138(h) as an alternative to having the offsite facility submit the certification specified in 40 CFR 63.132(g)(2). ☐ Yes ☐ No

☐ As an alternative to the management and treatment options specified in 40 63.132(g)(2), any affected wastewater stream (or residual removed from an affected wastewater stream) with a total annual average concentration of compounds in Table 8 of the MON rule less than 50 ppmw may be transferred offsite in accordance with the two items below. ☐ Yes ☐ No

☐**1.** The transferee (or the source) must demonstrate that less than 5 percent of the HAP in Table 9 to this subpart is emitted from the waste management units up to the activated sludge unit. ☐ Yes ☐ No

☐**2.** The transferee must treat the wastewater stream or residual in a biological treatment unit in accordance with 40 CFR 63.138 and 63.145 and the requirements referenced therein. ☐ Yes ☐ No

☐ The source must determine the annual average concentration and annual average flowrate for wastewater streams for each MCPU. The procedures for flexible operation units specified in 40 CFR 63.144 (b) and (c) do not apply for the purposes of the MON rule. ☐ Yes ☐ No

☐ The requirement to correct outlet concentrations from combustion devices to 3 percent oxygen in 40 CFR 63.139(c)(1)(ii) and 63.146(i)(6) applies only if supplemental gases are combined with a vent stream from a Group 1 wastewater stream. If emissions are controlled with a vapor recovery system as specified in 40 CFR 63.139(c)(2), the source must correct for supplemental gases as specified in 40 CFR 63.2460(c)(6)(MON rule). ☐ Yes ☐ No

☐ **Requirements for liquid streams in open systems**.

☐ References in 40 CFR 63.149 to 63.100(b) mean 40 CFR 63.2435(b) for the purposes of the MON rule. ☐ Yes ☐ No

☐ When 40 CFR 63.149(e) refers to 40 CFR 63.100(l) (1) or (2), 40 CFR 63.2445(a) applies for the purposes of the MON rule. ☐ Yes ☐ No

☐ When 40 CFR 63.149 uses the term "chemical manufacturing process unit," the term "MCPU" applies for the purposes of the MON rule. ☐ Yes ☐ No

☐ When 40 CFR 63.149(e)(1) refers to characteristics of water that contain compounds in Table 9 to 40 CFR 63, subpart G, the characteristics listed in three sentences just above for liquid streams in open systems specified in paragraphs **(C1)** through **(C3)** of this section apply for the purposes of the MON rule. ☐ Yes ☐ No

☐ When 40 CFR 63.149(e)(2) refers to characteristics of water that contain compounds in Table 9 to 40 CFR 63, subpart G, the characteristics specified in paragraph **(C2)** of this section apply for the purposes of the MON rule. ☐ Yes ☐ No

Heat Exchange Systems

13. What requirements must I meet for heat exchange systems? 63.2490

☐ The source must comply with each requirement in Table 10 of the MON rule that applies to their heat exchange systems, except as specified below. ☐ Yes ☐ No

☐ The phrase "a chemical manufacturing process unit meeting the conditions of 40 CFR 63.100 (b)(1) through (b)(3) of this section" in 40 CFR 63.104(a) means "an MCPU meeting the conditions of 40 CFR 63.2435 (MON rule)" for the purposes of the MON rule. ☐ Yes ☐ No

☐ The reference to 40 CFR 63.100(c) in 40 CFR 63.104(a) does not apply for the purposes of the MON rule. ☐ Yes ☐ No

IV. Alternative Means of Compliance

14. How does the source comply with the pollution prevention standard? 63.2495

☐**A.** The source may elect to comply with the pollution prevention alternative requirements specified below in lieu of the emission limitations and work practice standards contained in Tables 1 through 7 of the MON rule for any MCPU for which initial startup occurred before April 4, 2002. ☐ Yes ☐ No

☐**(1)** The source must reduce the production-indexed HAP consumption factor (HAP factor) by at least 65 percent from a 3-year average baseline beginning no earlier than the 1994 through 1996 calendar years. For any reduction in the HAP factor that the source achieves by reducing HAP that are also volatile organic compounds (VOC), they must demonstrate an equivalent reduction in the production-indexed VOC consumption factor (VOC factor) on a mass basis. For any reduction in the HAP factor that they achieve by reducing a HAP that is not a VOC, the source may not increase the VOC factor. ☐ Yes ☐ No

☐**(2)** Any MCPU for which the source seeks to comply by using the pollution prevention alternative must begin with the same starting material(s) and end with the same product(s). The source may not comply by eliminating any steps of a process by transferring the step offsite (to another manufacturing location). The source may also not merge a solvent recovery step conducted offsite to onsite and as part of an existing process as a method of reducing consumption. ☐ Yes ☐ No

☐**(3)** The source may comply with the requirements of paragraph **A1** of this section for a series of processes, including situations where multiple processes are merged, if the source demonstrates to the satisfaction of the air pollution control agency or that the multiple processes were merged after the baseline period into an existing process or processes. ☐ Yes ☐ No

☐**B. Exclusions.**

☐ The source must comply with the emission limitations and work practice standards contained in Tables 1 through 7 of the MON rule for all HAP that are generated in the MCPU and that are not included in consumption, as defined in 40 CFR 63.2550 (see definitions at the end of the checklist). Hydrogen halides that are generated as a result of combustion control must be controlled according to the requirements of 40 CFR 63.994 and the requirements referenced therein. ☐ Yes ☐ No

☐ The source may not merge nondedicated formulation or nondedicated solvent recovery processes with any other processes. ☐ Yes ☐ No

☐**C. Initial compliance procedures.** To demonstrate initial compliance with **A** of this section, the source must prepare a demonstration summary in accordance with the requirements below in **C1** and calculate baseline and target annual HAP and VOC factors in accordance with **C2** and **C3** below. ☐ Yes ☐ No

☐**1. Demonstration plan**. The source must prepare a pollution prevention demonstration plan that contains, at a minimum, the information in items below for each MCPU for which the source comply with **A** of this section. ☐ Yes ☐ No

☐ Descriptions of the methodologies and forms used to measure and record consumption of HAP and VOC compounds. ☐ Yes ☐ No

☐ Descriptions of the methodologies and forms used to measure and record production of the product(s). ☐ Yes ☐ No

☐ Supporting documentation for these descriptions including, but not limited to, samples of operator log sheets and daily, monthly, and/or annual inventories of materials and products. The source must describe how this documentation will be used to calculate the annual factors required in **D** of this section. ☐ Yes ☐ No

☐**2. Baseline factors.** The source must calculate baseline HAP and VOC factors by dividing the consumption of total HAP and total VOC by the production rate, per process, for the first 3-year period in which the process was operational, beginning no earlier than the period consisting of the 1994 through 1996 calendar years. ☐ Yes ☐ No

☐**3. Target annual factors.** The source must calculate target annual HAP and VOC factors. The target annual HAP factor must be equal to 35 percent of the baseline HAP factor. The target annual VOC factor must be lower than the baseline VOC factor by an amount equivalent to the reduction in any HAP that is also a VOC, on a mass basis. The target annual VOC factor may be the same as the baseline VOC factor if the only HAP reduced is not a VOC. ☐ Yes ☐ No

☐**D. Continuous compliance requirements**. The source must calculate annual rolling average values of the HAP and VOC factors (annual factors) in accordance with the procedures specified below. To show continuous compliance, the annual factors must be equal to or less than the target annual factors calculated according to paragraph **C3** of this section. ☐ Yes ☐ No

☐ To calculate the annual factors, the source must divide the consumption of both total HAP and total VOC by the production rate, per process, for 12-month periods at the frequency specified below, as applicable.

☐ **For continuous processes**, the source must calculate the annual factors every 30 days for the 12-month period preceding the 30th day (i.e., annual rolling average calculated every 30 days). A process with both batch and continuous operations is considered a continuous process for the purposes of this section. ☐ Yes ☐ No

☐ **For batch processes**, the source must calculate the annual factors every 10 batches for the 12-month period preceding the 10th batch (i.e., annual rolling average calculated every 10 batches), except as specified below. ☐ Yes ☐ No

☐ If the source produces more than 10 batches during a month, the source must calculate the annual factors at least once during that month. ☐ Yes ☐ No

☐ If the source produces less than 10 batches in a 12-month period, they must calculate the annual factors for the number of batches in the 12-month period since the previous calculations. ☐ Yes ☐ No

☐**E. Records**. The source must keep records of HAP and VOC consumption, production, and the rolling annual HAP and VOC factors for each MCPU for which they are complying with according to **A** of this section. ☐ Yes ☐ No

☐**F. Reporting**.

☐ The source must include the pollution prevention demonstration plan in the precompliance report required by 40 CFR 63.2520(c) (MON rule). ☐ Yes ☐ No

☐ The source must identify all days when the annual factors were above the target factors in the compliance reports. ☐ Yes ☐ No

15. How does an affected source comply with emissions averaging? 63.2500

☐ An existing source may elect to comply with the percent reduction emission limitations in Tables 1, 2, 4, 5, and 7 to the MON rule by complying with the emissions averaging provisions specified in 40 CFR 63.150 (subpart G), except as specified below. ☐ Yes ☐ No

☐ The batch process vents in an MCPU collectively are considered one individual emission point for the purposes of emissions averaging, except that only individual batch process vents must be excluded to meet the requirements of 40 CFR 63.150(d)(5). ☐ Yes ☐ No

☐ References in 40 CFR 63.150 to 63.112 through 63.130 (subpart G) mean the corresponding requirements in 40 CFR 63.2450 through 63.2490 (MON rule), including applicable monitoring, recordkeeping, and reporting. ☐ Yes ☐ No

☐ References to "periodic reports" in 40 CFR 63.150 mean "compliance report" for the purposes of the MON rule. ☐ Yes ☐ No

☐ For batch process vents, estimate uncontrolled emissions for a standard batch using the procedures in 40 CFR 63.1257(d)(2)(i) and (ii) (subpart GGG, Pharmaceuticals) instead of the procedures in 40 CFR 63.150(g)(2). Multiply the calculated emissions per batch by the number of batches per month when calculating the monthly emissions for use in calculating debits and credits. ☐ Yes ☐ No

☐ References to "storage vessels" in 40 CFR63.150 mean "storage tank" as defined in 40 CFR 63.2550 for the purposes of the MON rule. ☐ Yes ☐ No

16. How does a source comply with the alternative standard? 63.2505

☐ As an alternative to complying with the emission limits and work practice standards for process vents and storage tanks in Tables 1 through 4 to the MON rule and the requirements in 40 CFR 63.2455 through 63.2470, the source may comply with the emission limits and compliance requirements listed below. ☐ Yes ☐ No

☐ **Emission limits and work practice standards**.

☐ The source must route vent streams through a closed-vent system to a control device that reduces HAP emissions as specified below.

☐ If the source uses a combustion control device, it must reduce HAP emissions as specified below.

☐ To an outlet total organic compound (TOC) concentration of 20 parts per million by volume (ppmv) or less. ☐ Yes ☐ No

☐ To an outlet concentration of hydrogen halide and halogen HAP of 20 ppmv or less. ☐ Yes ☐ No

☐ As an alternative to the emission limit listed above, if the source controls halogenated vent streams emitted from a combustion device followed by a scrubber, reduce the hydrogen halide and halogen HAP generated in the combustion device by greater than or equal to 95 percent by weight in the scrubber. ☐ Yes ☐ No

☐ If the source uses a noncombustion control device(s), it must reduce HAP emissions to an outlet total organic HAP concentration of 50 ppmv or less, and an outlet concentration of hydrogen halide and halogen HAP of 50 ppmv or less. ☐ Yes ☐ No

☐ Any Group 1 process vents within a process that are not controlled according to this alternative standard must be controlled according to the emission limits in Tables 1 through 3 of the MON rule. ☐ Yes ☐ No

☐ **Compliance requirements**. To demonstrate compliance with the emission limits listed above, the source must meet the requirements of 40 CFR 63.1258(b)(5)(i) (subpart GGG) beginning no

later than the initial compliance date specified in 40 CFR 63.2445, except as listed below. ☐ Yes ☐ No

☐ The source must comply with the requirements in 40 CFR 63.983 (subpart DD) and the requirements referenced therein for closed-vent systems. ☐ Yes ☐ No

☐ When 40 CFR 63.1258(b)(5)(i) refers to 40 CFR 63.1253(d) and 63.1254(c) (subpart GGG), the emission limits listed above in this section apply for the purposes of the MON rule. ☐ Yes ☐ No

☐ The source must submit the results of any determination of the target analytes or predominant HAP in the notification of compliance status report. ☐ Yes ☐ No

☐ When 40 CFR 63.1258(b)(5)(i)(B) refers to "HCl," it means "total hydrogen halide and halogen HAP" for the purposes of the MON rule. ☐ Yes ☐ No

☐ If the source elects to comply with the requirement to reduce hydrogen halide and halogen HAP by greater than or equal to 95 percent by weight emitted from a combustion device followed by a scrubber, the source must meet the requirements below. ☐ Yes ☐ No

☐ Demonstrate initial compliance with the 95 percent reduction by conducting a performance test and setting a site-specific operating limit(s) for the scrubber in accordance with 40 CFR 63.994 (subpart SS) and the requirements referenced therein. The source must submit the results of the initial compliance demonstration in the notification of compliance status report. ☐ Yes ☐ No

☐ Install, operate, and maintain a continuous process monitoring system (CPMS) for the scrubber as specified in 40 CFR 63.2450(k), instead of as specified in 40 CFR 63.1258(b)(5)(i)(C). ☐ Yes ☐ No

☐ If flow to the scrubber could be intermittent, the source must install, calibrate, and operate a flow indicator as specified in 40 CFR 63.2460(c)(7). ☐ Yes ☐ No

☐ Use the operating day as the averaging period for CEMS data and scrubber parameter monitoring data. ☐ Yes ☐ No

V. Notification, Reports, and Records

17. What notifications must an affected source submit and when? 63.2515

☐ The source must submit all of the notifications listed in 40 CFR 63.6(h)(4) and (5), 63.7(b) and (c), 63.8(e), (f)(4) and (6), and 63.9(b) through (h) (General Provisions) that apply by the dates specified. ☐ Yes ☐ No

☐ **Initial notification**. As specified in 40 CFR 63.9(b)(2), if the startup of an affected source is before November 10, 2003, they must submit an initial notification not later than 120 calendar days after November 10, 2003. ☐ Yes ☐ No

☐ As specified in 40 CFR 63.9(b)(3), if the startup of a new affected source is on or after November 10, 2003, they must submit an initial notification not later than 120 calendar days after they become subject to the MON rule. ☐ Yes ☐ No

☐ **Notification of performance test**. If the source is required to conduct a performance test, they must submit a notification of intent to conduct a performance test at least 60 calendar days before the performance test is scheduled to begin as required in 40 CFR 63.7(b)(1). For any performance test required as part of the initial compliance procedures for batch process vents in Table 2 of the MON rule, the source must also submit the test plan required by 40 CFR 63.7(c) and the emission profile with the notification of the performance test. ☐ Yes ☐ No

18. What reports must the source submit and when? 63.2520

☐ The source must submit each report in Table 11 of the MON rule that applies. ☐ Yes ☐ No

☐ Unless the air pollution control agency has approved a different schedule for submission of reports under 40 CFR 63.10(a), the source must submit each report by the date in Table 11 of the MON rule and according to the items below. ☐ Yes ☐ No

☐ The first compliance report must cover the period beginning on the compliance date that is specified for the affected source in 40 CFR 63.2445 and ending on June 30 or December 31, whichever date is the first date following the end of the first 6 months after the compliance date that is specified for the affected source in 40 CFR 63.2445. ☐ Yes ☐ No

☐ The first compliance report must be postmarked or delivered no later than August 31 or February 28, whichever date is the first date following the end of the first reporting period specified immediately above. ☐ Yes ☐ No

☐ Each subsequent compliance report must cover the semiannual reporting period from January 1 through June 30 or the semiannual reporting period from July 1 through December 31. ☐ Yes ☐ No

☐ Each subsequent compliance report must be postmarked or delivered no later than August 31 or February 28, whichever date is the first date following the end of the semiannual reporting period. ☐ Yes ☐ No

☐ For each affected source that is subject to permitting regulations pursuant to 40 CFR part 70 or 40 CFR part 71, and if the permitting authority has established dates for submitting semiannual reports pursuant to 40 CFR 70.6(a)(3)(iii)(A) or 40 CFR 71.6(a)(3)(iii)(A), the source may submit the first and subsequent compliance reports according to the dates the permitting authority has established instead of according to the dates listed above. ☐ Yes ☐ No

☐ **Precompliance report**. The source must submit a precompliance report to request approval for any of the **seven** items below. The air pollution control agency will either approve or disapprove the report within 90 days after they have received it. If they disapprove the report, the source must still be in compliance with the emission limitations and work practice standards in the MON rule by the compliance date. To change any of the information submitted in the report, the source must notify the air pollution control agency 60 days before the planned change is to be implemented. ☐ Yes ☐ No

☐ **(1)** Requests for approval to set operating limits for parameters other than those specified in 40 CFR 63.2455 through 63.2485 and referenced therein. Alternatively, the source may make these requests according to 40 CFR 63.8(f). ☐ Yes ☐ No

☐ **(2)** Descriptions of daily or per batch demonstrations to verify that control devices subject to 40 CFR 63.2460(c)(5) are operating as designed. ☐ Yes ☐ No

☐ **(3)** A description of the test conditions, data, calculations, and other information used to establish operating limits according to 40 CFR 63.2460(c)(3). ☐ Yes ☐ No

☐ **(4)** Data and rationale used to support an engineering assessment to calculate uncontrolled emissions in accordance with 40 CFR 63.1257(d)(2)(ii). ☐ Yes ☐ No

☐ **(5)** The pollution prevention demonstration plan required in 40 CFR 63.2495(c)(1), if the source is complying with the pollution prevention alternative. ☐ Yes ☐ No

☐ **(6)** Documentation of the practices that the source will implement to minimize HAP emissions from streams that contain energetics and organic peroxides, and rationale for why meeting the emission limit specified in Tables 1 through 7 of the MON rule would create an undue safety hazard. ☐ Yes ☐ No

☐ **(7)** For fabric filters that are monitored with bag leak detectors, an operation and maintenance plan that describes proper operation and maintenance procedures, and a corrective action plan that describes corrective actions to be taken, and the timing of those actions, when the PM concentration exceeds the set point and activates the alarm. ☐ Yes ☐ No

☐ **Notification of compliance status report**. The source must submit a notification of compliance status report according to **item 1** below, and the notification of compliance status report must contain the information specified in **item 2** below. ☐ Yes ☐ No

☐**(1)** The source must submit the notification of compliance status report no later than 150 days after the applicable compliance date specified in 40 CFR 63.2445. ☐ Yes ☐ No

☐ **(2)** The notification of compliance status report must include the information in **items (i)** through **(ix)** below.

☐ **(i)** The results of any applicability determinations, emission calculations, or analyses used to identify and quantify HAP emissions from the affected source. ☐ Yes ☐ No

☐ **(ii)** The results of emissions profiles, performance tests, engineering analyses, design evaluations, flare compliance assessments, inspections and repairs, and calculations used to demonstrate initial compliance according to 40 CFR 63.2455 through 63.2485. For performance tests, results must include descriptions of sampling and analysis procedures and quality assurance procedures. ☐ Yes ☐ No

☐ **(iii)** Descriptions of monitoring devices, monitoring frequencies, and the operating limits established during the initial compliance demonstrations, including data and calculations to support the levels the source establishes. ☐ Yes ☐ No

☐ **(iv)** All operating scenarios. ☐ Yes ☐ No

☐ **(v)** Descriptions of worst-case operating and/or testing conditions for control devices. ☐ Yes ☐ No

☐ **(vi)** Identification of parts of the affected source subject to overlapping requirements described in 40 CFR 63.2535 and the authority under which the source will comply. ☐ Yes ☐ No

☐ **(vii)** The information specified in 40 CFR 63.1039(a)(1) through (3) for each process subject to the work practice standards for equipment leaks in Table 6 of the MON rule. ☐ Yes ☐ No

☐ **(viii)** Identify storage tanks for which the source is complying with the vapor balancing alternative in 40 CFR 63.2470(g). ☐ Yes ☐ No

☐ **(ix)** Records as specified in 40 CFR 63.2535(i)(1) through (3) of process units used to create a PUG and calculations of the initial primary product of the PUG. ☐ Yes ☐ No

☐ **Compliance report**. The compliance report must contain the information specified in items 1 through 10 below.

☐ **(1)** Company name and address. ☐ Yes ☐ No

☐ **(2)** Statement by a responsible official with that official's name, title, and signature, certifying the accuracy of the content of the report. ☐ Yes ☐ No

☐ **(3)** Date of report and beginning and ending dates of the reporting period. ☐ Yes ☐ No

☐ **(4)** For each SSM during which excess emissions occur, the compliance report must include records that the procedures specified in the startup, shutdown, and malfunction plan (SSMP) were followed or documentation of actions taken that are not consistent with the SSMP, and include a brief description of each malfunction. ☐ Yes ☐ No

☐ **(5)** The compliance report must contain the information on deviations, as defined in 40 CFR 63.2550, according to items **(i)**, **(ii)**, and **(iii)** below.

☐ **(i)** If there are no deviations from any emission limit, operating limit or work practice standard specified in the MON rule, include a statement that there were no deviations from the emission limits, operating limits, or work practice standards during the reporting period. ☐ Yes ☐ No

☐ **(ii)** For each deviation from an emission limit, operating limit, and work practice standard that occurs at an affected source where they are not using a continuous monitoring system (CMS) to comply with the emission limit or work practice standard of the MON rule, the source must include the information in items **(A)** through **(C)** below. This includes periods of SSM. ☐ Yes ☐ No

☐ **(A)** The total operating time of the affected source during the reporting period. ☐ Yes ☐ No
☐ **(B)** Information on the number, duration, and causes of deviations (including unknown cause, if applicable), and the corrective action taken. ☐ Yes ☐ No
☐ **(C)** Operating logs for the day(s) during which the deviation occurred, except operating logs are not required for deviations of the work practice standards for equipment leaks. ☐ Yes ☐ No

☐ **(iii)** For each deviation from an emission limit or operating limit occurring at an affected source where a source is using a CMS to comply with an emission limit in the MON rule, the source must include the information in items **(A)** through **(L)** of this section. This includes periods of SSM. ☐ Yes ☐ No

☐ **(A)** The date and time that each CMS was inoperative, except for zero (low-level) and high-level checks. ☐ Yes ☐ No
☐ **(B)** The date, time, and duration that each CEMS was out-of-control, including the information in 40 CFR 63.8(c)(8). ☐ Yes ☐ No
☐ **(C)** The date and time that each deviation started and stopped, and whether each deviation occurred during a period of startup, shutdown, or malfunction or during another period. ☐ Yes ☐ No
☐ **(D)** A summary of the total duration of the deviation during the reporting period, and the total duration as a percent of the total operating time of the affected source during that reporting period. ☐ Yes ☐ No
☐ **(E)** A breakdown of the total duration of the deviations during the reporting period into those that are due to startup, shutdown, control equipment problems, process problems, other known causes, and other unknown causes. ☐ Yes ☐ No
☐ **(F)** A summary of the total duration of CMS downtime during the reporting period, and the total duration of CMS downtime as a percent of the total operating time of the affected source during that reporting period. ☐ Yes ☐ No
☐ **(G)** An identification of each HAP that is known to be in the emission stream. ☐ Yes ☐ No
☐ **(H)** A brief description of the process units. ☐ Yes ☐ No
☐ **(I)** A brief description of the CMS. ☐ Yes ☐ No
☐ **(J)** The date of the latest CMS certification or audit. ☐ Yes ☐ No
☐ **(K)** Operating logs for each day(s) during which the deviation occurred. ☐ Yes ☐ No
☐ **(L)** The operating day or operating block average values of monitored parameters for each day(s) during which the deviation occurred. ☐ Yes ☐ No

☐ **(6)** If the source uses a CEMS, and there were no periods during which it was out-of-control as specified in 40 CFR 63.8(c)(7), include a statement that there were no periods during which the CEMS was out-of-control during the reporting period. ☐ Yes ☐ No

☐ **(7)** Include each new operating scenario which has been operated since the time period covered by the last compliance report and has not been submitted in the notification of compliance status report or a previous compliance report. For each new

operating scenario, the source must provide verification that the operating conditions for any associated control or treatment device have not been exceeded and that any required calculations and engineering analyses have been performed. For the purposes of this paragraph, a revised operating scenario for an existing process is considered to be a new operating scenario. ☐ Yes ☐ No

☐ **(8)** Records of process units added to a PUG as specified in 40 CFR 63.2525(i)(4) and records of primary product redeterminations as specified in 40 CFR 63.2525(i)(5). ☐ Yes ☐ No

☐ **(9**) Applicable records and information for periodic reports as specified in referenced subparts F, G, SS, UU, WW, and GGG. ☐ Yes ☐ No

☐ **(10) Notification of process change**. Whenever the source makes a process change, or change any of the information submitted in the notification of compliance status report, that is not within the scope of an existing operating scenario, the source must document the change in their compliance report. A process change does not include moving within a range of conditions identified in the standard batch. The notification must include all of the information in items **(A)** through **(C)** below. ☐ Yes ☐ No

☐ **(A)** A description of the process change. ☐ Yes ☐ No
☐ **(B)** Revisions to any of the information reported in the original notification of compliance status report listed above. ☐ Yes ☐ No
☐ **(C)** Information required by the notification of compliance status report listed above section for changes involving the addition of processes or equipment at the affected source. ☐ Yes ☐ No
☐ **Exception.** The source must submit a report 60 days before the scheduled implementation date of any of the changes identified in items **(1), (2), or (3)** listed below. ☐ Yes ☐ No

☐**(1)** Any change to the information contained in the precompliance report. ☐ Yes ☐ No

☐**(2)** A change in the status of a control device from small to large. ☐ Yes ☐ No

☐**(3)** A change from Group 2 to Group 1 for any emission point. ☐ Yes ☐ No

19. What records must an affected source keep? 63.2525

The source must keep the records specified below.

☐ Each applicable record required by subpart A of 40 CFR 63 and in referenced subparts F, G, SS, UU, WW, and GGG of 40 CFR 63. ☐ Yes ☐ No

☐ Records of each operating scenario as specified in items **(1)** through **(8)** below.

☐ **(1)** A description of the process and the type of process equipment used. ☐ Yes ☐ No

☐ **(2)** An identification of related process vents, including their associated emissions episodes if not complying with the alternative standard in 40 CFR 63.2505; wastewater point of determination (POD); storage tanks; and transfer racks. ☐ Yes ☐ No
☐ **(3)** The applicable control requirements of the MON rule, including the level of required control, and for vents, the level of control for each vent. ☐ Yes ☐ No
☐ **(4)** The control device or treatment process used, as applicable, including a description of operating and/or testing conditions for any associated control device. ☐ Yes ☐ No

☐ **(5)** The process vents, wastewater POD, transfer racks, and storage tanks (including those from other processes) that are simultaneously routed to the control device or treatment process(s). ☐ Yes ☐ No

☐ **(6)** The applicable monitoring requirements of this subpart and any parametric level that assures compliance for all emissions routed to the control device or treatment process. ☐ Yes ☐ No

☐ **(7)** Calculations and engineering analyses required to demonstrate compliance. ☐ Yes ☐ No

☐ **(8)** For reporting purposes, a change to any of these elements not previously reported, except for (5) of this section, constitutes a new operating scenario. ☐ Yes ☐ No

☐ A schedule or log of operating scenarios updated each time a different operating scenario is put into operation. ☐ Yes ☐ No

☐ The information specified in items **(1)** and **(2)** below for Group 1 batch process vents in compliance with a percent reduction emission limit in Table 2 of the MON rule if some of the vents are controlled to less than the percent reduction requirement. ☐ Yes ☐ No

☐ **(1)** Records of whether each batch operated was considered a standard batch. ☐ Yes ☐ No

☐ **(2)** The estimated uncontrolled and controlled emissions for each batch that is considered to be a nonstandard batch. ☐ Yes ☐ No

☐ The information specified in items **(1)** through **(4)** below for each process with Group 2 batch process vents or uncontrolled hydrogen halide and halogen HAP emissions from the sum of all batch and continuous process vents less than 1,000 lb/yr. No record is required if the source documents in the notification of compliance status report that the MCPU does not process, use, or produce HAP. ☐ Yes ☐ No

☐ **(1)** A record of the day each batch was completed. ☐ Yes ☐ No

☐ **(2)** A record of whether each batch operated was considered a standard batch. ☐ Yes ☐ No

☐ **(3)** The estimated uncontrolled and controlled emissions for each batch that is considered to be a nonstandard batch. ☐ Yes ☐ No

☐ **(4)** Records of the daily 365-day rolling summations of emissions, or alternative records that correlate to the emissions (e.g., number of batches), calculated no less frequently than monthly. ☐ Yes ☐ No

☐ A record of each time a safety device is opened to avoid unsafe conditions in accordance with 40 CFR 63.2450(s). ☐ Yes ☐ No

☐ Records of the results of each CPMS calibration check and the maintenance performed, as specified in 40 CFR 63.2450(k)(1). ☐ Yes ☐ No

☐ For each CEMS, the source must keep records of the date and time that each deviation started and stopped, and whether the deviation occurred during a period of startup, shutdown, or malfunction or during another period. ☐ Yes ☐ No

☐ For each PUG, the source must keep records specified in items **(1)** through **(5)** below.

☐ **(1)** Descriptions of the MCPU and other process units in the initial PUG required by 40 CFR 63.2535(l)(1)(v). ☐ Yes ☐ No

☐ **(2)** Rationale for including each MCPU and other process unit in the initial PUG (i.e., identify the overlapping equipment between process units) required by 40 CFR 63.2535(l)(1)(v). ☐ Yes ☐ No

☐ **(3)** Calculations used to determine the primary product for the initial PUG required by 40 CFR 63.2535(l)(2)(iv). ☐ Yes ☐ No

☐ **(4)** Descriptions of process units added to the PUG after the creation date and rationale for including the additional process units in the PUG as required by 40 CFR 63.2535(l)(1)(v). ☐ Yes ☐ No

☐ **(5)** The calculation of each primary product redetermination required by 40 CFR 63.2535(l)(2)(iv). ☐ Yes ☐ No

☐ In the SSMP required by 40 CFR 63.6(e)(3), the source is not required to include Group 2 emission points, unless those emission points are used in an emissions average. For equipment leaks, the SSMP requirement is limited to control devices and is optional for other equipment. ☐ Yes ☐ No

☐ For each bag leak detector used to monitor PM HAP emissions from a fabric filter, maintain records of any bag leak detection alarm, including the date and time, with a brief explanation of the cause of the alarm and the corrective action taken. ☐ Yes ☐ No

VI. Other Requirements and Information

20. What compliance options does an affected source have if part of the plant is subject to both the MON rule and another rule? 63.2535

☐ For any equipment, emission stream, or wastewater stream subject to the provisions of both the MON rule and another rule, the source may elect to comply only with the provisions as specified below. The source also must identify the subject equipment, emission stream, or wastewater stream, and the provisions with which the source will comply, in their notification of compliance status report required by 40 CFR 63.2520(d). ☐ Yes ☐ No

☐ **Compliance with other subparts of 40 CFR 63**. If the source has an MCPU that includes a batch process vent that also is part of a CMPU as defined in subparts F and G of 40 CFR 63, the source must comply with the emission limits; operating limits; work practice standards; and the compliance, monitoring, reporting and recordkeeping requirements for batch process vents in the MON rule, and they must continue to comply with the requirements in subparts F, G, and H of 40 CFR 63 that are applicable to the CMPU and associated equipment. ☐ Yes ☐ No

☐ **Compliance with 40 CFR 264 and 265, subparts AA, BB, and/or CC**.

☐**(1)** After the compliance dates specified in 40 CFR 63.2445, if a control device that the source uses to comply with the MON rule is also subject to monitoring, recordkeeping, and reporting requirements in 40 CFR 264, subpart AA, BB, or CC; or the monitoring and recordkeeping requirements in 40 CFR 265, subpart AA, BB, or CC; and they comply with the periodic reporting requirements under 40 CFR 264, subpart AA, BB, or CC that would apply to the device if the facility had final-permitted status, the source may elect to comply either with the monitoring, recordkeeping, and reporting requirements of the MON rule; or with the monitoring and recordkeeping requirements in 40 CFR 264 or 265 and the reporting requirements in 40 CFR 264, as described in this paragraph, which constitute compliance with the monitoring, recordkeeping, and reporting requirements of the MON rule. If the source elects to comply with the monitoring, recordkeeping, and reporting requirements in 40 CFR 264 and/or 265, they must report the information described in 40 CFR 63.2520(e). ☐ Yes ☐ No

☐**(2)** After the compliance dates specified in 40 CFR 63.2445, if a facility has an affected source with equipment that is also subject to 40 CFR 264, subpart BB, or to 40 CFR 265, subpart BB, then compliance with the recordkeeping and reporting requirements of 40 CFR 264 and/or 265 may be used to comply with the recordkeeping and reporting

requirements of the MON rule, to the extent that the requirements of 40 CFR 264 and/or 265 duplicate the requirements of the MON rule. ☐ Yes ☐ No

☐ **Compliance with 40 CFR 60, subpart Kb and 40 CFR 61, subpart Y**. After the compliance dates specified in 40 CFR 63.2445, the source is in compliance with subpart FFFF (MON rule) for any storage tank that is assigned to an MCPU and that is both controlled with a floating roof and in compliance with of either 40 CFR 60, subpart Kb, or 40 CFR 61, subpart Y. The source is in compliance with the MON rule if they have a storage tank with a fixed roof, closed-vent system, and control device in compliance with the provisions of either 40 CFR 60, subpart Kb, or 40 CFR 61, subpart Y, except that the source must comply with the monitoring, recordkeeping, and reporting requirements in this subpart FFFF. Alternatively, if a storage tank assigned to an MCPU is subject to control under 40 CFR 60, subpart Kb, or 40 CFR 61, subpart Y, the source may elect to comply only with the requirements for Group 1 storage tanks in the MON rule.
☐ Yes ☐ No

☐ **Compliance with subpart I, GGG, or MMM of 40 CFR 63**. After the compliance dates specified in 40 CFR 63.2445, if the facility has an affected source with equipment subject to subpart I, GGG, or MMM of 40 CFR 63, they may elect to comply with the provisions of subpart H, GGG, or MMM of 40 CFR 63, respectively, for all such equipment. ☐ Yes ☐ No

☐ **Compliance with subpart GGG of 40 CFR 63 for wastewater**. After the compliance dates specified in 40 CFR 63.2445, if a facility has an affected source subject to the MON rule and they have an affected source that generates wastewater streams that meet the applicability thresholds specified in 40 CFR 63.1256, the source may elect to comply with the provisions of the MON rule for all such wastewater streams. ☐ Yes ☐ No

☐ **Compliance with subpart MMM of 40 CFR 63 for wastewater**. After the compliance dates specified in 40 CFR 63.2445, if a facility has an affected source subject to the MON rule, and they have an affected source that generates wastewater streams that meet the applicability thresholds specified in 40 CFR 63.1362(d), the source may elect to comply with the provisions of the MON rule for all such wastewater streams (except that the 99 percent reduction requirement for streams subject to 40 CFR 63.1362(d)(10) still applies). ☐ Yes ☐ No

☐ **Compliance with other regulations for wastewater**. After the compliance dates specified in 40 CFR 63.2445, if the source has a Group 1 wastewater stream that is also subject to provisions in 40 CFR 260 through 272, they may elect to determine whether the MON rule or 40 CFR 260 through 272 contain the more stringent control requirements (e.g., design, operation, and inspection requirements for waste management units; numerical treatment standards; etc.) and the more stringent testing, monitoring, recordkeeping, and reporting requirements. Compliance with provisions of 40 CFR 260 through 272 that are determined to be more stringent than the requirements of the MON rule constitute compliance with the MON rule. For example, provisions of 40 CFR 260 through 272 for treatment units that meet the conditions specified in 40 CFR 63.138(h) represent compliance with the MON rule. The source must identify in the notification of compliance status report required by 40 CFR 63.2520(d) the information and procedures that they used to make any stringency determinations. ☐ Yes ☐ No

☐ **Compliance with 40 CFR 60, subpart DDD, III, NNN, or RRR**. After the compliance dates specified in 40 CFR 63.2445, if the source has an MCPU that contains equipment subject to the MON rule that are also subject to 40 CFR 60, subpart DDD, III, NNN, or RRR, they may elect to apply the MON rule to all such equipment in the MCPU. If an MCPU subject to the MON rule has equipment to which the MON rule does not apply but which is subject to a standard in 40 CFR 60, subpart DDD, III, NNN, or RRR, they may elect to comply with the requirements for Group 1 process vents in this subpart for such equipment. If the source elects any of these methods of compliance, they must consider all total organic compounds, minus methane and ethane, in such equipment for purposes of compliance with the MON rule, as if they were organic HAP.

Compliance with the provisions of the MON rule, in the manner described in this paragraph, will constitute compliance with 40 CFR 60, subpart DDD, III, NNN, or RRR, as applicable.

☐ Yes ☐ No

☐ **Compliance with 40 CFR 61, subpart BB**.

☐ **(1)** After the compliance dates specified in 40 CFR 63.2445, a Group 1 transfer rack, as defined in 40 CFR 63.2550, that is also subject to the provisions of 40 CFR 61, subpart BB, the source is required to comply only with the provisions of the MON rule.

☐ Yes ☐ No

☐ **(2)** After the compliance dates specified in 40 CFR 63.2445, a Group 2 transfer rack, as defined in 40 CFR 63.2550, that is also subject to the provisions of 40 CFR 61, subpart BB, is required to comply with the provisions of either items **(i)** or **(ii)** below.

☐ **(i)** If the transfer rack is subject to the control requirements specified in 40 CFR 61.302 of 40 CFR 61, subpart BB, then the source may elect to comply with either the requirements of 40 CFR 61, subpart BB, or the requirements for Group 1 transfer racks under the MON rule. ☐ Yes ☐ No

☐ **(ii)** If the transfer rack is subject only to reporting and recordkeeping requirements under 40 CFR 61, subpart BB, then the source is required to comply only with the reporting and recordkeeping requirements specified in the MON rule for Group 2 transfer racks, and they are exempt from the reporting and recordkeeping requirements in 40 CFR 61, subpart BB.

☐ Yes ☐ No

☐**Compliance with 40 CFR 61, subpart FF**. After the compliance date specified in 40 CFR 63.2445, for a Group 1 or Group 2 wastewater stream that is also subject to the provisions of 40 CFR 61.342(c) through (h), and is not exempt under 40 CFR 61.342(c)(2) or (3), the source may elect to comply only with the requirements for Group 1 wastewater streams in this subpart FFFF. If a Group 2 wastewater stream is exempted from 40 CFR 61.342(c)(1) under 40 CFR 61.342(c)(2) or (3), then the source is required to comply only with the reporting and recordkeeping requirements specified in the MON rule for Group 2 wastewater streams, and they are exempt from the requirements in 40 CFR 61, subpart FF. ☐ Yes ☐ No

☐ **Compliance with 40 CFR 60, subpart VV, and 40 CFR 61, subpart V.** After the compliance date specified in 40 CFR 63.2445, if a facility has an affected source with equipment that is also subject to the requirements of 40 CFR 60, subpart VV, or 40 CFR 61, subpart V, they may elect to apply the MON rule to all such equipment. Alternatively, if the facility has an affected source with no continuous process vents and equipment that is also subject to the requirements of 40 CFR 60, subpart VV, or 40 CFR 61, subpart V, they may elect to comply with 40 CFR 60, subpart VV or 40 CFR 61, subpart V, as applicable, for all such equipment. ☐ Yes ☐ No

☐ **Applicability of process units included in a process unit group**. The source may elect to develop and comply with the requirements for PUG in accordance with items **(1)** through **(3)** below.

☐ **(1) Procedures to create process unit groups.** Develop and document changes in a PUG in accordance with the procedures specified in items **(i)** through **(v)** below.

☐ **(i)** Initially, identify an MCPU that is created from nondedicated equipment that will operate on or after November 10, 2003 and identify all processing equipment that is part of this MCPU, based on descriptions in operating scenarios.

☐ Yes ☐ No

☐ **(ii)** Add to the group any other nondedicated MCPU and other nondedicated process units expected to be operated in the 5 years after the date specified in item **(i)** above, provided they satisfy the criteria specified in items **(A)** through **(C)** below. Also identify all of the processing equipment used for each process unit

based on information from operating scenarios and other applicable documentation. ☐ Yes ☐ No

☐ **(A)** Each process unit that is added to a group must have some processing equipment that is also part of one or more process units in the group. ☐ Yes ☐ No

☐ **(B)** No process unit may be part of more than one PUG. ☐ Yes ☐ No

☐ **(C)** The processing equipment used to satisfy the requirement of item **(A)** of this section may not be a storage tank or control device. ☐ Yes ☐ No

☐ **(iii)** The initial PUG consists of all of the processing equipment for the process units identified in items **(i)** and **(ii)** above. As an alternative to the procedures specified in items **(i)** and **(ii),** the source may use a PUG that was developed in accordance with 40 CFR 63.1360(h) as the source initial PUG. ☐ Yes ☐ No

☐ **(iv)** Add process units developed in the future in accordance with the conditions specified in items **(A)** and **(B)** above. ☐ Yes ☐ No

☐ **(v)** Maintain records that describe the process units in the initial PUG, the procedure used to create the PUG, and subsequent changes to each PUG as specified in 40 CFR 63.2525(i). Submit the records in reports as specified in 40 CFR 63.2520(d)(2)(ix) and (e)(8). ☐ Yes ☐ No

☐ **(2) Determine primary product.** The source must determine the primary product of each PUG created in items **(1)** above according to the procedures specified in items **(i)** through **(iv)** below. ☐ Yes ☐ No

☐ **(i)** The primary product is the type of product (e.g., organic chemicals subject to 40 CFR 63.2435(b)(1), pharmaceutical products subject to 40 CFR 63.1250, or pesticide active ingredients subject to 40 CFR 63.1360) expected to be produced for the greatest operating time in the 5-year period specified in item **(1)(ii)** above. ☐ Yes ☐ No

☐ **(ii)** If the PUG produces multiple types of products equally based on operating time, then the primary product is the type of product with the greatest production on a mass basis over the 5-year period specified in paragraph **(1)(ii)** above. ☐ Yes ☐ No

☐ **(iii)** At a minimum, the source must redetermine the primary product of the PUG following the procedure specified in items **(2)(i)** and **(ii)** of this section every 5 years. ☐ Yes ☐ No

☐ **(iv)** The source must record the calculation of the initial primary product determination as specified in 40 CFR 63.2525(i)(3) and report the results in the notification of compliance status report as specified in 40 CFR 63.2520(d)(8)(ix). The source must record the calculation of each redetermination of the primary product as specified in 40 CFR 63.2525(i)(5) and report the calculation in a compliance report submitted no later than the report covering the period for the end of the 5th year after cessation of production of the previous primary product, as specified in 40 CFR 63.2520(e)(8). ☐ Yes ☐ No

☐ **(3) Compliance requirements.**

☐ **(i)** If the primary product of the PUG is determined, according to item **(2)** above, to be material described in 40 CFR 63.2435(b)(1), then the source must comply with the MON rule for each MCPU in the PUG. The source may also elect to comply with the MON rule for all other process units in the PUG, which constitutes compliance with other 40 CFR 63 rules. ☐ Yes ☐ No

☐ **(ii)** If the primary product of the PUG is determined according to item **(2)** above to be material not described in 40 CFR 63.2435(b)(1), then the source must comply with items **(A)**, **(B)**, or **(C)** below, as applicable. ☐ Yes ☐ No

☐ **(A)** If the primary product is subject to subpart GGG of 40 CFR 63, then comply with the requirements of subpart GGG for each MCPU in the PUG. ☐ Yes ☐ No

☐ **(B)** If the primary product is subject to subpart MMM of 40 CFR 63, then comply with the requirements of subpart MMM for each MCPU in the PUG. ☐ Yes ☐ No

☐ **(C)** If the primary product is subject to any subpart in 40 CFR 63 other than subpart GGG or subpart MMM, then comply with the requirements of the MON rule for each MCPU in the PUG. ☐ Yes ☐ No

☐ **(iii)** The requirements for new and reconstructed sources in the alternative subpart apply to all MCPU in the PUG if and only if the affected source under the alternative subpart meets the requirements for construction or reconstruction. ☐ Yes ☐ No

21. What parts of the General Provisions apply to the affected source? 63.2540

☐ Table 12 of the MON rule shows which parts of the General Provisions in 40 CFR 63.1 through 63.15 apply to the source.

VII. Definitions & Acronyms

22. What definitions apply to this checklist? 63.2550

Ancillary activities means boilers and incinerators (not used to comply with the emission limits in Tables 1 through 7 to this subpart), chillers and refrigeration systems, and other equipment and activities that are not directly involved (i.e., they operate within a closed system and materials are not combined with process fluids) in the processing of raw materials or the manufacturing of a product or isolated intermediate.

Batch operation means a noncontinuous operation involving intermittent or discontinuous feed into equipment, and, in general, involves the emptying of the equipment after the operation ceases and prior to beginning a new operation. Addition of raw material and withdrawal of product do not occur simultaneously in a batch operation.

Batch process vent means a vent from a unit operation or vents from multiple unit operations within a process that are manifolded together into a common header, through which a HAP-containing gas stream is, or has the potential to be, released to the atmosphere. Examples of batch process vents include, but are not limited to, vents on condensers used for product recovery, reactors, filters, centrifuges, and process tanks. The following are not batch process vents for the purposes of this subpart:
(1) Continuous process vents;
(2) Bottoms receivers;
(3) Surge control vessels;
(4) Gaseous streams routed to a fuel gas system(s);
(5) Vents on storage tanks, wastewater emission sources, or pieces of equipment subject to the emission limits and work practice standards in Tables 4, 6, and 7 to this subpart;
(6) Drums, pails, and totes;
(7) Flexible elephant trunk systems that draw ambient air (i.e., the system is not ducted, piped, or otherwise connected to the unit operations) away from operators when vessels are opened; and
(8) Emission streams from emission episodes that are undiluted and uncontrolled containing less than 50 ppmv HAP or less than 200 lb/yr. The HAP concentration or mass emission rate may be determined using any of the following: process knowledge that no HAP are present in the emission stream; an engineering assessment as discussed in 40 CFR 63.1257(d)(2)(ii); equations specified in 40 CFR 63.1257(d)(2)(i), as applicable; test data using Method 18 of 40

CFR 60, appendix A; or any other test method that has been validated according to the procedures in Method 301 of appendix A of 40 CFR 63.

Bottoms receiver means a tank that collects bottoms from continuous distillation before the stream is sent for storage or for further downstream processing.

Construction means the onsite fabrication, erection, or installation of an affected source or MCPU. Addition of new equipment to an MCPU subject to existing source standards does not constitute construction, but it may constitute reconstruction of the affected source or MCPU if it satisfies the definition of reconstruction in 40 CFR 63.2.

Consumption means the quantity of all HAP raw materials entering a process in excess of the theoretical amount used as reactant, assuming 100 percent stoichiometric conversion. The raw materials include reactants, solvents, and any other additives. If a HAP is generated in the process as well as added as a raw material, consumption includes the quantity generated in the process.

Continuous process vent means the point of discharge to the atmosphere (or the point of entry into a control device, if any) of a gas stream if the gas stream has the characteristics specified in 40 CFR 63.107(b) through (h), or meets the criteria specified in 40 CFR 63.107(i), except:
(1) The reference in 40 CFR 63.107(e) to a chemical manufacturing process unit that meets the criteria of 40 CFR 63.100(b) means an MCPU that meets the criteria of 40 CFR 63.2435(b);
(2) The reference in 40 CFR 63.107(h)(4) to 40 CFR 63.113 means Table 1 to this subpart;
(3) The references in 40 CFR 63.107(h)(7) to 63.119 and 63.126 mean Tables 4 and 5 of the MON rule; and
(4) For the purposes of 40 CFR 63.2455, all references to the characteristics of a process vent (e.g., flowrate, total HAP concentration, or TRE index value) mean the characteristics of the gas stream.

Dedicated MCPU means an MCPU that consists of equipment that is used exclusively for one process, except that storage tanks assigned to the process according to the procedures in 40 CFR 63.2435(d) also may be shared by other processes.

Deviation means any instance in which an affected source subject to the MON rule, or an owner or operator of such a source:
(1) Fails to meet any requirement or obligation established by the MON rule including, but not limited to, any emission limit, operating limit, or work practice standard; or
(2) Fails to meet any term or condition that is adopted to implement an applicable requirement in the MON rule and that is included in the operating permit for any affected source required to obtain such a permit; or
(3) Fails to meet any emission limit, operating limit, or work practice standard in the MON rule during startup, shutdown, or malfunction, regardless of whether or not such failure is permitted by the MON rule.

Energetics means propellants, explosives, and pyrotechnics and include materials listed at 49 CFR 172.101 as DOT Hazard Class I Hazardous Materials, Divisions 1.1 through 1.6.

Equipment means each pump, compressor, agitator, pressure relief device, sampling connection system, open-ended valve or line, valve, connector, and instrumentation system in organic HAP service; and any control devices or systems used to comply with Table 6 of the MON rule.

Excess emissions means emissions greater than those allowed by the emission limit.

Family of materials means a grouping of materials with the same basic composition or the same basic end use or functionality produced using the same basic feedstocks with essentially identical HAP emission profiles (primary constituent and relative magnitude on a pound per product basis)

and manufacturing equipment configuration. Examples of families of materials include multiple grades of the same product or different variations of a product (e.g., blue, black, and red resins).

Group 1 batch process vent means each of the batch process vents in a process for which the collective uncontrolled organic HAP emissions from all of the batch process vents are greater than or equal to 10,000 lb/yr at an existing source or greater than or equal to 3,000 lb/yr at a new source.

Group 2 batch process vent means each batch process vent that does not meet the definition of Group 1 batch process vent.

Group 1 continuous process vent means a continuous process vent with a total resource effectiveness index value, calculated according to 40 CFR 63.2455(b), that is less than 1.9 at an existing source and less than 5.0 at a new source.

Group 2 continuous process vent means a continuous process vent that does not meet the definition of a Group 1 continuous process vent.

Group 1 storage tank means a storage tank with a capacity greater than or equal to 10,000 gal storing material that has a maximum true vapor pressure of total HAP greater than or equal to 6.9 kilopascals at an existing source or greater than or equal to 0.69 kilopascals at a new source.

Group 2 storage tank means a storage tank that does not meet the definition of a Group 1 storage tank.

Group 1 transfer rack means a transfer rack that loads more than 0.65 million liters/year of liquids that contain organic HAP with a rack-weighted average partial pressure, as defined in 40 CFR 63.111, greater than or equal to 1.5 pound per square inch absolute.

Group 2 transfer rack means a transfer rack that does not meet the definition of a Group 1 transfer rack.

Group 1 wastewater stream means a wastewater stream consisting of process wastewater at an existing or new source that meets the criteria for Group 1 status in 40 CFR 63.2485(c) for compounds in Tables 8 and 9 of the MON rule and/or a wastewater stream consisting of process wastewater at a new source that meets the criteria for Group 1 status in 40 CFR 63.132(d) for compounds in Table 8 to subpart G of 40 CFR 63.

Group 2 wastewater stream means any process wastewater stream that does not meet the definition of a Group 1 wastewater stream.

Halogenated vent stream means a vent stream determined to have a mass emission rate of halogen atoms contained in organic compounds of 0.45 kilograms per hour or greater determined by the procedures presented in 40 CFR 63.115(d)(2)(v).

Hydrogen halide and halogen HAP means hydrogen chloride, hydrogen fluoride, and chlorine.

In organic HAP service means that a piece of equipment either contains or contacts a fluid (liquid or gas) that is at least 5 percent by weight of total organic HAP as determined according to the provisions of 40 CFR 63.180(d). The provisions of 40 CFR 63.180(d) also specify how to determine that a piece of equipment is not in organic HAP service.

Isolated intermediate means a product of a process that is stored before subsequent processing. An isolated intermediate is usually a product of a chemical synthesis, fermentation, or biological extraction process. Storage of an isolated intermediate marks the end of a process. Storage occurs at any time the intermediate is placed in equipment used solely for storage.

Large control device means a control device that controls total HAP emissions of greater than or equal to 10 tpy, before control.

Maintenance wastewater means wastewater generated by the draining of process fluid from components in the MCPU into an individual drain system in preparation for or during maintenance activities. Maintenance wastewater can be generated during planned and unplanned shutdowns and during periods not associated with a shutdown. Examples of activities that can generate maintenance wastewater include descaling of heat exchanger tubing bundles, cleaning of distillation column traps, draining of pumps into an individual drain system, and draining of portions of the MCPU for repair. Wastewater from routine cleaning operations occurring as part of batch operations is not considered maintenance wastewater.

Maximum true vapor pressure has the meaning given in 40 CFR 63.111, except that it applies to all HAP rather than only organic HAP.

Miscellaneous organic chemical manufacturing process means all equipment which collectively function to produce a product or isolated intermediate that are materials described in 40 CFR 63.2435(b). For the purposes of the MON rule subpart, process includes any, all or a combination of reaction, recovery, separation, purification, or other activity, operation, manufacture, or treatment which are used to produce a product or isolated intermediate. A process is also defined by the following:
(1) Routine cleaning operations conducted as part of batch operations are considered part of the process;
(2) Each nondedicated solvent recovery operation is considered a single process;
(3) Each nondedicated formulation operation is considered a single process that is used to formulate numerous materials and/or products;
(4) Quality assurance/quality control laboratories are not considered part of any process; and
(5) Ancillary activities are not considered a process or part of any process.

Nondedicated solvent recovery operation means a distillation unit or other purification equipment that receives used solvent from more than one MCPU.

Nonstandard batch means a batch process that is operated outside of the range of operating conditions that are documented in an existing operating scenario but is still a reasonably anticipated event. For example, a nonstandard batch occurs when additional processing or processing at different operating conditions must be conducted to produce a product that is normally produced under the conditions described by the standard batch. A nonstandard batch may be necessary as a result of a malfunction, but it is not itself a malfunction.

On-site or on site means, with respect to records required to be maintained by the MON rule or required by another rule referenced by the MON rule, that records are stored at a location within a major source which encompasses the affected source. On-site includes, but is not limited to, storage at the affected source or MCPU to which the records pertain, or storage in central files elsewhere at the major source.

Operating scenario means, for the purposes of reporting and recordkeeping, any specific operation of an MCPU as described by records specified in 40 CFR 63.2525(b).

Organic group means structures that contain primarily carbon, hydrogen, and oxygen atoms.

Organic peroxides means organic compounds containing the bivalent -o-o-structure which may be considered to be a structural derivative of hydrogen peroxide where one or both of the hydrogen atoms has been replaced by an organic radical.

Predominant HAP means as used in calibrating an analyzer, the single organic HAP that constitutes the largest percentage of the total organic HAP in the analyzed gas stream, by volume.

Process tank means a tank or vessel that is used within a process to collect material discharged from a feedstock storage tank or equipment within the process before the material is transferred to other equipment within the process or a product storage tank. A process tank has emissions that are related to the characteristics of the batch cycle, and it does not accumulate product over multiple batches. Surge control vessels and bottoms receivers are not process tanks.

Production-indexed HAP consumption factor (HAP factor) means the result of dividing the annual consumption of total HAP by the annual production rate, per process.

Production-indexed VOC consumption factor (VOC factor) means the result of dividing the annual consumption of total VOC by the annual production rate, per process.

Quaternary ammonium compounds means a type of organic nitrogen compound in which the molecular structure includes a central nitrogen atom joined to four organic groups as well as an acid radical of some sort.

Recovery device means an individual unit of equipment used for the purpose of recovering chemicals from process vent streams for reuse in a process at the affected source and from wastewater streams for fuel value (i.e., net positive heating value), use, reuse, or for sale for fuel value, use or reuse. Examples of equipment that may be recovery devices include absorbers, carbon adsorbers, condensers, oil-water separators or organic-water separators, or organic removal devices such as decanters, strippers, or thin-film evaporation units. To be a recovery device for a wastewater stream, a decanter and any other equipment based on the operating principle of gravity separation must receive only multi-phase liquid streams.

Responsible official means responsible official as defined in 40 CFR 70.2.

Safety device means a closure device such as a pressure relief valve, frangible disc, fusible plug, or any other type of device which functions exclusively to prevent physical damage or permanent deformation to a unit or its air emission control equipment by venting gases or vapors directly to the atmosphere during unsafe conditions resulting from an unplanned, accidental, or emergency event. For the purposes of this subpart, a safety device is not used for routine venting of gases or vapors from the vapor headspace underneath a cover such as during filling of the unit or to adjust the pressure in response to normal daily diurnal ambient temperature fluctuations. A safety device is designed to remain in a closed position during normal operations and open only when the internal pressure, or another relevant parameter, exceeds the device threshold setting applicable to the air emission control equipment as determined by the owner or operator based on manufacturer recommendations, applicable regulations, fire protection and prevention codes and practices, or other requirements for the safe handling of flammable, combustible, explosive, reactive, or hazardous materials.

Shutdown means the cessation of operation of a continuous operation for any purpose. Shutdown also means the cessation of a batch operation, or any related individual piece of equipment required or used to comply with this subpart, if the steps taken to cease operation differ from those described in a standard batch or nonstandard batch. Shutdown also applies to emptying and degassing storage vessels. Shutdown does not apply to cessation of batch operations at the end of a campaign or between batches within a campaign when the steps taken are routine operations.

Small control device means a control device that controls total HAP emissions of less than 10 tpy, before control.

Standard batch means a batch process operated within a range of operating conditions that are documented in an operating scenario. Emissions from a standard batch are based on the operating conditions that result in highest emissions. The standard batch defines the uncontrolled and controlled emissions for each emission episode defined under the operating scenario.

Startup means the setting in operation of a continuous operation for any purpose; the first time a new or reconstructed batch operation begins production; for new equipment added, including equipment required or used to comply with the MON rule, the first time the equipment is put into operation; or for the introduction of a new product/process, the first time the product or process is run in equipment. For batch operations, startup applies to the first time the equipment is put into operation at the start of a campaign to produce a product that has been produced in the past if the steps taken to begin production differ from those specified in a standard batch or nonstandard batch. Startup does not apply when the equipment is put into operation as part of a batch within a campaign when the steps taken are routine operations.

Storage tank means a tank or other vessel that is used to store liquids that contain organic HAP and/or hydrogen halide and halogen HAP and that has been assigned to an MCPU according to the procedures in 40 CFR 63.2435(d). The following are not considered storage tanks for the purposes of this subpart:
(1) Vessels permanently attached to motor vehicles such as trucks, railcars, barges, or ships;
(2) Pressure vessels designed to operate in excess of 204.9 kilopascals and without emissions to the atmosphere;
(3) Vessels storing organic liquids that contain HAP only as impurities;
(4) Wastewater storage tanks;
(5) Bottoms receivers;
(6) Surge control vessels; and
(7) Process tanks.

Supplemental gases are any gaseous streams that are not defined as process vents, or closed-vent systems from wastewater management and treatment units, storage tanks, or equipment components and that contain less than 50 ppmv TOC, as determined through process knowledge, that are introduced into vent streams or manifolds. Air required to operate combustion device burner(s) is not considered supplemental gas.

Surge control vessel means feed drums, recycle drums, and intermediate vessels immediately preceding continuous reactors, air-oxidation reactors, or distillation operations. Surge control vessels are used within an MCPU when in-process storage, mixing, or management of flowrates or volumes is needed to introduce material into continuous reactors, air-oxidation reactors, or distillation operations.

Total organic compounds or (TOC) means the total gaseous organic compounds (minus methane and ethane) in a vent stream.

Transfer rack means the collection of loading arms and loading hoses, at a single loading rack, that are assigned to an MCPU according to the procedures specified in 40 CFR 63.2435(d) and are used to fill tank trucks and/or rail cars with organic liquids that contain one or more of the organic HAP listed in section 112(b) of the CAA of this subpart. Transfer rack includes the associated pumps, meters, shutoff valves, relief valves, and other piping and valves.

Unit operation means those processing steps that occur within distinct equipment that are used, among other things, to prepare reactants, facilitate reactions, separate and purify products, and recycle materials. Equipment used for these purposes includes, but is not limited to, reactors, distillation columns, extraction columns, absorbers, decanters, dryers, condensers, and filtration equipment.

Waste management unit means the equipment, structure(s), and/or device(s) used to convey, store, treat, or dispose of wastewater streams or residuals. Examples of waste management units include wastewater tanks, air flotation units, surface impoundments, containers, oil-water or organic-water separators, individual drain systems, biological wastewater treatment units, waste incinerators, and organic removal devices such as steam and air stripper units, and thin film evaporation units. If such equipment is being operated as a recovery device, then it is part of a miscellaneous organic chemical manufacturing process and is not a waste management unit.

Wastewater means water that is discarded from an MCPU through a single POD and that contains either: an annual average concentration of compounds in Table 8 or 9 to the MON rule of at least 5 ppmw and has an annual average flowrate of 0.02 liters per minute or greater; or an annual average concentration of compounds in Table 8 or 9 to this subpart of at least 10,000 ppmw at any flowrate. The following are not considered wastewater for the purposes of the MON rule:
(1) Stormwater from segregated sewers;
(2) Water from fire-fighting and deluge systems, including testing of such systems;
(3) Spills;
(4) Water from safety showers;
(5) Samples of a size not greater than reasonably necessary for the method of analysis that is used;
(6) Equipment leaks;
(7) Wastewater drips from procedures such as disconnecting hoses after cleaning lines; and
(8) Noncontact cooling water.

Wastewater stream means a stream that contains only wastewater as defined above.

Work practice standard means any design, equipment, work practice, or operational standard, or combination thereof, that is promulgated pursuant to section 112(h) of the CAA.

Acronyms

C 1 - carbon
CEMS - continuous emissions monitoring system
CFR – Code of Federal Regulations
CMPU - chemical manufacturing process unit
CMS - continuous monitoring system
CPMS - continuous process monitoring system
FTIR - Fourier transform infrared spectroscopy
HAP - hazardous air pollutants
HON – Hazardous Organic NESHAP
MACT - Maximum Achievable Control Technologies
MCPU - miscellaneous organic chemical manufacturing process units
MON - Miscellaneous Organic NESHAP
NESHAP - National Emission Standards for Hazardous Air Pollutants
PM HAP – particulate matter hazardous air pollutants
POD - point of determination
ppmw - parts per million by weight
PUG - process unit groups
SSM - startup, shutdown, and malfunction
SSMP - startup, shutdown, and malfunction plan
tpy - tons per year
TOC - total organic compound
TRE - total resource effectiveness
VOC - volatile organic compounds

Title 40: Protection of Environment

PART 63—NATIONAL EMISSION STANDARDS FOR HAZARDOUS AIR POLLUTANTS FOR SOURCE CATEGORIES

Subpart FFFF—National Emission Standards for Hazardous Air Pollutants: Miscellaneous Organic Chemical Manufacturing

Source: 68 FR 63888, Nov. 10, 2003, unless otherwise noted.

What This Subpart Covers

§ 63.2430 What is the purpose of this subpart?

This subpart establishes national emission standards for hazardous air pollutants (NESHAP) for miscellaneous organic chemical manufacturing. This subpart also establishes requirements to demonstrate initial and continuous compliance with the emission limits, operating limits, and work practice standards.

§ 63.2435 Am I subject to the requirements in this subpart?

(a) You are subject to the requirements in this subpart if you own or operate miscellaneous organic chemical manufacturing process units (MCPU) that are located at, or are part of, a major source of hazardous air pollutants (HAP) emissions as defined in section 112(a) of the Clean Air Act (CAA).
(b) An MCPU includes equipment necessary to operate a miscellaneous organic chemical manufacturing process, as defined in §63.2550, that satisfies all of the conditions specified in paragraphs (b)(1) through (3) of this section. An MCPU also includes any assigned storage tanks and product transfer racks; equipment in open systems that is used to convey or store water having the same concentration and flow characteristics as wastewater; and components such as pumps, compressors, agitators, pressure relief devices, sampling connection

systems, open-ended valves or lines, valves, connectors, and instrumentation systems that are used to manufacture any material or family of materials described in paragraphs (b)(1)(i) through (v) of this section.

(1) The MCPU produces material or family of materials that is described in paragraph (b)(1)(i), (ii), (iii), (iv), or (v) of this section.

(i) An organic chemical or chemicals classified using the 1987 version of SIC code 282, 283, 284, 285, 286, 287, 289, or 386, except as provided in paragraph (c)(5) of this section.

(ii) An organic chemical or chemicals classified using the 1997 version of NAICS code 325, except as provided in paragraph (c)(5) of this section.

(iii) Quaternary ammonium compounds and ammonium sulfate produced with caprolactam.

(iv) Hydrazine.

(v) Organic solvents classified in any of the SIC or NAICS codes listed in paragraph (b)(1)(i) or (ii) of this section that are recovered using nondedicated solvent recovery operations.

(2) The MCPU processes, uses, or produces any of the organic HAP listed in section 112(b) of the CAA or hydrogen halide and halogen HAP, as defined in §63.2550.

(3) The MCPU is not an affected source or part of an affected source under another subpart of this part 63, except for process vents from batch operations within a chemical manufacturing process unit (CMPU), as identified in §63.100(j)(4). For this situation, the MCPU is the same as the CMPU as defined in §63.100, and you are subject only to the requirements for batch process vents in this subpart.

(c) The requirements in this subpart do not apply to the operations specified in paragraphs (c)(1) through (6) of this section.

(1) Research and development facilities, as defined in section 112(c)(7) of the CAA.

(2) The manufacture of ammonium sulfate as a by-product, if the slurry entering

the by-product manufacturing process contains 50 parts per million by weight (ppmw) HAP or less or 10 ppmw benzene or less. You must retain information, data, and analysis to document the HAP concentration in the entering slurry in order to claim this exemption.

(3) The affiliated operations located at an affected source under subparts GG (National Emission Standards for Aerospace Manufacturing and Rework Facilities), KK (National Emission Standards for the Printing and Publishing Industry), JJJJ (NESHAP: Paper and Other Web Coating), future MMMM (NESHAP: Surface Coating of Miscellaneous Metal Parts and Products), and SSSS (NESHAP: Surface Coating of Metal Coil) of this part 63. Affiliated operations include, but are not limited to, mixing or dissolving of coating ingredients; coating mixing for viscosity adjustment, color tint or additive blending, or pH adjustment; cleaning of coating lines and coating line parts; handling and storage of coatings and solvent; and conveyance and treatment of wastewater.

(4) Fabricating operations such as spinning a polymer into its end use.

(5) Production activities described using the 1997 version of NAICS codes 325131, 325181, 325188 (except the requirements do apply to hydrazine), 325314, 325991 (except the requirements do apply to reformulating plastics resins from recycled plastics products), and 325992 (except the requirements do apply to photographic chemicals).

(6) Tall oil recovery systems.

(d) If the predominant use of a transfer rack loading arm or storage tank (including storage tanks in series) is associated with a miscellaneous organic chemical manufacturing process, and the loading arm or storage tank is not part of an affected source under a subpart of this part 63, then you must assign the loading arm or storage tank to the MCPU for that miscellaneous organic chemical manufacturing process. If the predominant use cannot be determined, then you may assign the loading arm or storage tank to any MCPU that shares it and is subject to this subpart. If the use varies from year to year, then you must base the determination on the utilization that occurred during the year preceding

November 10, 2003 or, if the loading arm or storage tank was not in operation during that year, you must base the use on the expected use for the first 5-year period after startup. You must include the determination in the notification of compliance status report specified in §63.2520(d). You must redetermine the primary use at least once every 5 years, or any time you implement emissions averaging or pollution prevention after the compliance date.

(e) For nondedicated equipment used to create at least one MCPU, you may elect to develop process unit groups (PUG), determine the primary product of each PUG, and comply with the requirements of the subpart in 40 CFR part 63 that applies to that primary product as specified in §63.2535(l).

§ 63.2440 What parts of my plant does this subpart cover?

(a) This subpart applies to each miscellaneous organic chemical manufacturing affected source.

(b) The miscellaneous organic chemical manufacturing affected source is the facilitywide collection of MCPU and heat exchange systems, wastewater, and waste management units that are associated with manufacturing materials described in §63.2435(b)(1).

(c) A new affected source is described by either paragraph (c)(1) or (2) of this section.

(1) Each affected source defined in paragraph (b) of this section for which you commenced construction or reconstruction after April 4, 2002, and you meet the applicability criteria at the time you commenced construction or reconstruction.

(2) Each dedicated MCPU that has the potential to emit 10 tons per year (tpy) of any one HAP or 25 tpy of combined HAP, and you commenced construction or reconstruction of the MCPU after April 4, 2002. For the purposes of this paragraph, an MCPU is an affected source in the definition of the term “reconstruction” in §63.2.

(d) An MCPU that is also a CMPU under §63.100 is reconstructed for the purposes of this subpart if, and only if, the CMPU meets the requirements for

reconstruction in §63.100(l)(2).

Compliance Dates

§ 63.2445 When do I have to comply with this subpart?

(a) If you have a new affected source, you must comply with this subpart according to the requirements in paragraphs (a)(1) and (2) of this section.
(1) If you startup your new affected source before November 10, 2003, then you must comply with the requirements for new sources in this subpart no later than November 10, 2003.
(2) If you startup your new affected source after November 10, 2003, then you must comply with the requirements for new sources in this subpart upon startup of your affected source.
(b) If you have an existing source on November 10, 2003, you must comply with the requirements for existing sources in this subpart no later than November 10, 2006.
(c) You must meet the notification requirements in §63.2515 according to the schedule in §63.2515 and in 40 CFR part 63, subpart A. Some of the notifications must be submitted before you are required to comply with the emission limits, operating limits, and work practice standards in this subpart.

Emission Limits, Work Practice Standards, and Compliance Requirements

§ 63.2450 What are my general requirements for complying with this subpart?

(a) You must be in compliance with the emission limits and work practice standards in Tables 1 through 7 to this subpart at all times, except during periods of startup, shutdown, and malfunction (SSM), and you must meet the requirements specified in §§63.2455 through 63.2490 (or the alternative means of compliance in §63.2495, §63.2500, or §63.2505), except as specified in paragraphs (b) through (s) of this section. You must meet the notification,

reporting, and recordkeeping requirements specified in §§63.2515, 63.2520, and 63.2525.

(b) Determine halogenated vent streams. You must determine if an emission stream is a halogenated vent stream, as defined in §63.2550, by calculating the mass emission rate of halogen atoms in accordance with §63.115(d)(2)(v). Alternatively, you may elect to designate the emission stream as halogenated.

(c) Requirements for combined emission streams. When organic HAP emissions from different emission types (e.g., continuous process vents, batch process vents, storage tanks, transfer operations, and waste management units) are combined, you must comply with the requirements of either paragraph (c)(1) or (2) of this section.

(1) Comply with the applicable requirements of this subpart for each kind of organic HAP emissions in the stream (e.g., the requirements of Table 1 to this subpart for continuous process vents and the requirements of Table 4 to this subpart for emissions from storage tanks).

(2) Determine the applicable requirements based on the hierarchy presented in paragraphs (c)(2)(i) through (vi) of this section. For a combined stream, the applicable requirements are specified in the highest-listed paragraph in the hierarchy that applies to any of the individual streams that make up the combined stream. For example, if a combined stream consists of emissions from Group 1 batch process vents and any other type of emission stream, then you must comply with the requirements in paragraph (c)(2)(i) of this section for the combined stream; compliance with the requirements in paragraph (c)(2)(i) of this section constitutes compliance for the other emission streams in the combined stream. Two exceptions are that you must comply with the requirements in Table 3 to this subpart and §63.2465 for all process vents with hydrogen halide and halogen HAP emissions, and recordkeeping requirements for Group 2 applicability or compliance are still required (e.g., the requirement in §63.2525(f) to track the number of batches produced and calculate rolling annual emissions for processes with Group 2 batch process vents).

(i) The requirements of Table 2 to this subpart and §63.2460 for Group 1 batch process vents, including applicable monitoring, recordkeeping, and reporting.
(ii) The requirements of Table 1 to this subpart and §63.2455 for continuous process vents that are routed to a control device, as defined in §63.981, including applicable monitoring, recordkeeping, and reporting.
(iii) The requirements of Table 5 to this subpart and §63.2475 for transfer operations, including applicable monitoring, recordkeeping, and reporting.
(iv) The requirements of Table 7 to this subpart and §63.2485 for emissions from waste management units that are used to manage and treat Group 1 wastewater streams and residuals from Group 1 wastewater streams, including applicable monitoring, recordkeeping, and reporting.
(v) The requirements of Table 4 to this subpart and §63.2470 for control of emissions from storage tanks, including applicable monitoring, recordkeeping, and reporting.
(vi) The requirements of Table 1 to this subpart and §63.2455 for continuous process vents after a recovery device including applicable monitoring, recordkeeping, and reporting.
(d) Except when complying with §63.2485, if you reduce organic HAP emissions by venting emissions through a closed-vent system to any combination of control devices (except a flare) or recovery devices, you must meet the requirements of §63.982(c) and the requirements referenced therein.
(e) Except when complying with §63.2485, if you reduce organic HAP emissions by venting emissions through a closed-vent system to a flare, you must meet the requirements of §63.982(b) and the requirements referenced therein.
(f) If you use a halogen reduction device to reduce hydrogen halide and halogen HAP emissions from halogenated vent streams, you must meet the requirements of §63.994 and the requirements referenced therein. If you use a halogen reduction device before a combustion device, you must determine the halogen atom emission rate prior to the combustion device according to the procedures in §63.115(d)(2)(v).

(g) Requirements for performance tests. The requirements specified in paragraphs (g)(1) through (5) of this section apply instead of or in addition to the requirements specified in subpart SS of this part 63.

(1) Conduct gas molecular weight analysis using Method 3, 3A, or 3B in appendix A to part 60 of this chapter.

(2) Measure moisture content of the stack gas using Method 4 in appendix A to part 60 of this chapter.

(3) If the uncontrolled or inlet gas stream to the control device contains carbon disulfide, you must conduct emissions testing according to paragraph (g)(3)(i) or (ii) of this section.

(i) If you elect to comply with the percent reduction emission limits in Tables 1 through 7 to this subpart, and carbon disulfide is the principal organic HAP component (i.e., greater than 50 percent of the HAP in the stream by volume), then you must use Method 18, or Method 15 (40 CFR part 60, appendix A) to measure carbon disulfide at the inlet and outlet of the control device. Use the percent reduction in carbon disulfide as a surrogate for the percent reduction in total organic HAP emissions.

(ii) If you elect to comply with the outlet total organic compound (TOC) concentration emission limits in Tables 1 through 7 to this subpart, and the uncontrolled or inlet gas stream to the control device contains greater than 10 percent (volume concentration) carbon disulfide, you must use Method 18 or Method 15 to separately determine the carbon disulfide concentration. Calculate the total HAP or TOC emissions by totaling the carbon disulfide emissions measured using Method 18 or 15 and the other HAP emissions measured using Method 18 or 25A.

(4) As an alternative to using Method 18, Method 25/25A, or Method 26/26A of 40 CFR part 60, appendix A, to comply with any of the emission limits specified in Tables 1 through 7 to this subpart, you may use Method 320 of 40 CFR part 60, appendix A. When using Method 320, you must follow the analyte spiking procedures of section 13 of Method 320, unless you demonstrate that the

complete spiking procedure has been conducted at a similar source.
(5) Section 63.997(c)(1) does not apply. For the purposes of this subpart, results of all initial compliance demonstrations must be included in the notification of compliance status report, which is due 150 days after the compliance date, as specified in §63.2520(d)(1).
(h) Design evaluation. To determine the percent reduction of a small control device, you may elect to conduct a design evaluation as specified in §63.1257(a)(1) instead of a performance test as specified in subpart SS of this part 63. You must establish the value(s) and basis for the operating limits as part of the design evaluation.
(i) Outlet concentration correction for supplemental gases. In §63.997(e)(2)(iii)(C), the correction to 3 percent oxygen for emission streams at the outlet of combustion devices is required if you add supplemental gases, as defined in §63.2550, to the vent stream or manifold.
(j) Continuous emissions monitoring systems. Each continuous emissions monitoring system (CEMS) must be installed, operated, and maintained according to the requirements in §63.8 and paragraphs (j)(1) through (5) of this section.
(1) Each CEMS must be installed, operated, and maintained according to the applicable Performance Specification of 40 CFR part 60, appendix B, and according to paragraph (j)(2) of this section, except as specified in paragraph (j)(1)(i) of this section. For any CEMS meeting Performance Specification 8, you must also comply with appendix F, procedure 1 of 40 CFR part 60.
(i) If you wish to use a CEMS other than an Fourier Transform Infrared Spectroscopy (FTIR) meeting the requirements of Performance Specification 15 to measure hydrogen halide and halogen HAP before we promulgate a Performance Specification for such CEMS, you must prepare a monitoring plan and submit it for approval in accordance with the procedures specified in §63.8.
(ii) [Reserved]
(2) You must determine the calibration gases and reporting units for TOC CEMS

in accordance with paragraph (j)(2)(i), (ii), or (iii) of this section.

(i) For CEMS meeting Performance Specification 9 or 15 requirements, determine the target analyte(s) for calibration using either process knowledge of the control device inlet stream or the screening procedures of Method 18 on the control device inlet stream.

(ii) For CEMS meeting Performance Specification 8 used to monitor performance of a combustion device, calibrate the instrument on the predominant organic HAP and report the results as carbon (C 1), and use Method 25A or any approved alternative as the reference method for the relative accuracy tests.

(iii) For CEMS meeting Performance Specification 8 used to monitor performance of a noncombustion device, determine the predominant organic HAP using either process knowledge or the screening procedures of Method 18 on the control device inlet stream, calibrate the monitor on the predominant organic HAP, and report the results as C1. Use Method 18, ASTM D6420–99, or any approved alternative as the reference method for the relative accuracy tests, and report the results as C1.

(3) You must conduct a performance evaluation of each CEMS according to the requirements in 40 CFR 63.8 and according to the applicable Performance Specification of 40 CFR part 60, appendix B, except that the schedule in §63.8(e)(4) does not apply, and the results of the performance evaluation must be included in the notification of compliance status report.

(4) The CEMS data must be reduced to operating day or operating block averages computed using valid data consistent with the data availability requirements specified in §63.999(c)(6)(i)(B) through (D), except monitoring data also are sufficient to constitute a valid hour of data if measured values are available for at least two of the 15-minute periods during an hour when calibration, quality assurance, or maintenance activities are being performed. An operating block is a period of time from the beginning to end of batch operations within a process. Operating block averages may be used only for batch process vent data.

(5) If you add supplemental gases, you must correct the measured concentrations in accordance with paragraph (i) of this section and §63.2460(c)(6).

(k) Continuous parameter monitoring. The provisions in paragraphs (k)(1) through (4) of this section apply in addition to the requirements for continuous parameter monitoring system (CPMS) in subpart SS of this part 63.

(1) You must record the results of each calibration check and all maintenance performed on the CPMS as specified in §63.998(c)(1)(ii)(A).

(2) When subpart SS of this part 63 uses the term “a range” or “operating range” of a monitored parameter, it means an “operating limit” for a monitored parameter for the purposes of this subpart.

(3) As an alternative to measuring pH as specified in §63.994(c)(1)(i), you may elect to continuously monitor the caustic strength of the scrubber effluent.

(4) As an alternative to the inlet and outlet temperature monitoring requirements for catalytic incinerators as specified in §63.988(c)(2), you may elect to comply with the requirements specified in paragraphs (k)(4)(i) through (iii) of this section.

(i) Monitor the inlet temperature as specified in subpart SS of this part 63.

(ii) Check the activity level of the catalyst at least every 12 months and take any necessary corrective action, such as replacing the catalyst to ensure that the catalyst is performing as designed.

(iii) Maintain records of the annual checks of catalyst activity levels and the subsequent corrective actions.

(l) Startup, shutdown, and malfunction. Sections 63.152(f)(7)(ii) through (iv) and 63.998(b)(2)(iii) and (b)(6)(i)(A), which apply to the exclusion of monitoring data collected during periods of SSM from daily averages, do not apply for the purposes of this subpart.

(m) Reporting. (1) When §§63.2455 through 63.2490 reference other subparts in this part 63 that use the term “periodic report,” it means “compliance report” for the purposes of this subpart. The compliance report must include the information specified in §63.2520(e), as well as the information specified in referenced

subparts.
(2) When there are conflicts between this subpart and referenced subparts for the due dates of reports required by this subpart, reports must be submitted according to the due dates presented in this subpart.
(3) Excused excursions, as defined in subparts G and SS of this part 63, are not allowed.
(n) The option in §63.997(e)(2)(iv)(C) to demonstrate compliance with a percent reduction emission limit by measuring TOC is not allowed.
(o) You may not use a flare to control halogenated vent streams or hydrogen halide and halogen HAP emissions.
(p) Opening a safety device, as defined in §63.2550, is allowed at any time conditions require it to avoid unsafe conditions.
(q) If an emission stream contains energetics or organic peroxides that, for safety reasons, cannot meet an applicable emission limit specified in Tables 1 through 7 to this subpart, then you must submit documentation in your precompliance report explaining why an undue safety hazard would be created if the air emission controls were installed, and you must describe the procedures that you will implement to minimize HAP emissions from these vent streams.
(r) Surge control vessels and bottoms receivers. For each surge control vessel or bottoms receiver that meets the capacity and vapor pressure thresholds for a Group 1 storage tank, you must meet emission limits and work practice standards specified in Table 4 to this subpart.
(s) For the purposes of determining Group status for continuous process vents, batch process vents, and storage tanks in §§63.2455, 63.2460, and 63.2470, hydrazine is to be considered an organic HAP.

§ 63.2455 What requirements must I meet for continuous process vents?

(a) You must meet each emission limit in Table 1 to this subpart that applies to your continuous process vents, and you must meet each applicable requirement specified in paragraphs (b) through (c) of this section.

(b) For each continuous process vent, you must either designate the vent as a Group 1 continuous process vent or determine the total resource effectiveness (TRE) index value as specified in §63.115(d), except as specified in paragraphs (b)(1) through (3) of this section.

(1) You are not required to determine the Group status or the TRE index value for any continuous process vent that is combined with Group 1 batch process vents before a control device or recovery device because the requirements of §63.2450(c)(2)(i) apply to the combined stream.

(2) When a TRE index value of 4.0 is referred to in §63.115(d), TRE index values of 5.0 for existing affected sources and 8.0 for new and reconstructed affected sources apply for the purposes of this subpart.

(3) When §63.115(d) refers to “emission reductions specified in §63.113(a),” the reductions specified in Table 1 to this subpart apply for the purposes of this subpart.

(c) If you use a recovery device to maintain the TRE above a specified threshold, you must meet the requirements of §63.982(e) and the requirements referenced therein, except as specified in §63.2450 and paragraph (c)(1) of this section.

(1) When §63.993 uses the phrase “the TRE index value is between the level specified in a referencing subpart and 4.0,” the phrase “the TRE index value is >1.9 but ≤5.0” applies for an existing affected source, and the phrase “the TRE index value is >5.0 but ≤8.0” applies for a new and reconstructed affected source, for the purposes of this subpart.

(2) [Reserved]

§ 63.2460 What requirements must I meet for batch process vents?

(a) You must meet each emission limit in Table 2 to this subpart that applies to you, and you must meet each applicable requirement specified in paragraphs (b) and (c) of this section.

(b) Group status. If a process has batch process vents, as defined in §63.2550, you must determine the group status of the batch process vents by determining

and summing the uncontrolled organic HAP emissions from each of the batch process vents within the process using the procedures specified in §63.1257(d)(2)(i) and (ii), except as specified in paragraphs (b)(1) through (4) of this section.

(1) To calculate emissions caused by the heating of a vessel to a temperature lower than the boiling point, you must use the procedures in §63.1257(d)(2)(i)(C)(3).

(2) To calculate emissions from depressurization, you must use the procedures in §63.1257(d)(2)(i)(D)(10).

(3) To calculate emissions from vacuum systems for the purposes of this subpart, the receiving vessel is part of the vacuum system, and terms used in Equation 33 to 40 CFR part 63, subpart GGG, are defined as follows:

P system = absolute pressure of receiving vessel; P i = partial pressure of the HAP at the receiver temperature; P j = partial pressure of condensable (including HAP) at the receiver temperature; MW i = molecular weight of the individual HAP in the emission stream, with HAP partial pressures calculated at the temperature of the receiver.

(4) You may elect to designate the batch process vents within a process as Group 1 and not calculate uncontrolled emissions under either of the situations described in paragraph (b)(4)(i) or (ii) of this section.

(i) If you comply with the alternative standard specified in §63.2505.

(ii) If all Group 1 batch process vents within a process are controlled; you conduct the performance test under hypothetical worst case conditions, as defined in §63.1257(b)(8)(i)(B); and the emission profile is based on capture and control system limitations as specified in §63.1257(b)(8)(ii)(C).

(c) Exceptions to the requirements in subpart SS of this part 63 are specified in paragraphs (c)(1) through (7) of this section.

(1) Process condensers. Process condensers, as defined in §63.1251, are not considered to be control devices for batch process vents.

(2) Initial compliance. (i) To demonstrate initial compliance with a percent reduction emission limit in Table 2 to this subpart, you must compare the sums of the controlled and uncontrolled emissions for the applicable Group 1 batch

process vents within the process and show that the specified reduction is met.
(ii) When you conduct a performance test or design evaluation for a control device used to control emissions from batch process vents, you must establish emission profiles and conduct the test under worst-case conditions according to §63.1257(b)(8) instead of under normal operating conditions as specified in §63.7(e)(1). The requirements in §63.997(e)(1)(i) and (iii) also do not apply for performance tests conducted to determine compliance with the emission limits for batch process vents. References in §63.997(b)(1) to “methods specified in §63.997(e)” include the methods specified in §63.1257(b)(8).
(iii) As an alternative to conducting a performance test or design evaluation for a condenser, you may determine controlled emissions using the procedures specified in §63.1257(d)(3)(i)(B).
(iv) When §63.1257(d)(3)(i)(B)(7) specifies that condenser-controlled emissions from an air dryer must be calculated using Equation 11 of 40 CFR part 63, subpart GGG, with “V equal to the air flow rate,” it means “V equal to the dryer outlet gas flow rate,” for the purposes of this subpart. Alternatively, you may use Equation 12 of 40 CFR part 63, subpart GGG, with V equal to the dryer inlet air flow rate. Account for time as appropriate in either equation.
(v) You must demonstrate that each process condenser is properly operated according to the procedures specified in §63.1257(d)(2)(i)(C)(4)(ii) and (d)(3)(iii)(B). The reference in §63.1257(d)(3)(iii)(B) to the alternative standard in §63.1254(c) means §63.2505 for the purposes of this subpart. As an alternative to measuring the exhaust gas temperature, as required by §63.1257(d)(3)(iii)(B), you may elect to measure the liquid temperature in the receiver.
(vi) You must conduct a subsequent performance test or compliance demonstration equivalent to an initial compliance demonstration within 180 days of a change in the worst-case conditions.
(3) Establishing operating limits. You must establish operating limits under the conditions required for your initial compliance demonstration, except you may elect to establish operating limit(s) for conditions other than those under which a

performance test was conducted as specified in paragraph (c)(3)(i) of this section and, if applicable, paragraph (c)(3)(ii) of this section.

(i) The operating limits may be based on the results of the performance test and supplementary information such as engineering assessments and manufacturer's recommendations. These limits may be established for conditions as unique as individual emission episodes for a batch process. You must provide rationale in the precompliance report for the specific level for each operating limit, including any data and calculations used to develop the limit and a description of why the limit indicates proper operation of the control device. The procedures provided in this paragraph (c)(3)(i) have not been approved by the Administrator and determination of the operating limit using these procedures is subject to review and approval by the Administrator.

(ii) If you elect to establish separate monitoring levels for different emission episodes within a batch process, you must maintain records in your daily schedule or log of processes indicating each point at which you change from one operating limit to another, even if the duration of the monitoring for an operating limit is less than 15 minutes. You must maintain a daily schedule or log of processes according to §63.2525(c).

(4) Averaging periods. As an alternative to the requirement for daily averages in §63.998(b)(3), you may determine averages for operating blocks. An operating block is a period of time that is equal to the time from the beginning to end of batch process operations within a process.

(5) Periodic verification. For a control device with total inlet HAP emissions less than 1 tpy, you must establish an operating limit(s) for a parameter(s) that you will measure and record at least once per averaging period (i.e., daily or block) to verify that the control device is operating properly. You may elect to measure the same parameter(s) that is required for control devices that control inlet HAP emissions equal to or greater than 1 tpy. If the parameter will not be measured continuously, you must request approval of your proposed procedure in the precompliance report. You must identify the operating limit(s) and the

measurement frequency, and you must provide rationale to support how these measurements demonstrate the control device is operating properly.

(6) Outlet concentration correction for supplemental gases. If you use a control device other than a combustion device to comply with a TOC, organic HAP, or hydrogen halide and halogen HAP outlet concentration emission limit for batch process vents, you must correct the actual concentration for supplemental gases using Equation 1 of this section; you may use process knowledge and representative operating data to determine the fraction of the total flow due to supplemental gas.

$$C_a = C_m \left(\frac{Q_s + Q_a}{Q_a} \right) \qquad (Eq.\ 1)$$

Where:

Ca = corrected outlet TOC, organic HAP, or hydrogen halide and halogen HAP concentration, dry basis, ppmv; Cm = actual TOC, organic HAP, or hydrogen halide and halogen HAP concentration measured at control device outlet, dry basis, ppmv; Qa = total volumetric flowrate of all gas streams vented to the control device, except supplemental gases; Qs = total volumetric flowrate of supplemental gases.

(7) If flow to a control device could be intermittent, you must install, calibrate, and operate a flow indicator at the inlet or outlet of the control device to identify periods of no flow. Periods of no flow may not be used in daily or block averages, and it may not be used in fulfilling a minimum data availability requirement.

§ 63.2465 What requirements must I meet for process vents that emit hydrogen halide and halogen HAP or PM HAP?

(a) You must meet each emission limit in Table 3 to this subpart that applies to you, and you must meet each applicable requirement in paragraphs (b) through (d) of this section.

(b) If any process vents within a process emit hydrogen halide and halogen HAP, you must determine and sum the uncontrolled hydrogen halide and halogen HAP emissions from each of the process vents within the process using the procedures specified in §63.1257(d)(2)(i) and (ii).

(c) If collective uncontrolled hydrogen halide and halogen HAP emissions from

the process vents within a process are greater than or equal to 1,000 pounds per year (lb/yr), you must comply with §63.994 and the requirements referenced therein, except as specified in paragraphs (c)(1) through (3) of this section.
(1) When §63.994(b)(1) requires a performance test, you may elect to conduct a design evaluation in accordance with §63.1257(a)(1).
(2) When §63.994(b)(1) refers to “a combustion device followed by a halogen scrubber or other halogen reduction device,” it means any combination of control devices used to meet the emission limits specified in Table 3 to this subpart.
(3) Section 63.994(b)(2) does not apply for the purposes of this section.
(d) To demonstrate compliance with the particulate matter (PM) HAP emission limit for new sources in Table 3 to this subpart, you must comply with paragraphs (d)(1) and (2) of this section.
(1) Use Method 5 of appendix A of 40 CFR part 60 to determine the concentration of PM HAP at the inlet and outlet of a control device.
(2) Comply with the monitoring requirements specified in §63.1366(b)(1)(xi) for each fabric filter used to control PM HAP emissions.

§ 63.2470 What requirements must I meet for storage tanks?

(a) You must meet each emission limit in Table 4 to this subpart that applies to your storage tanks, and you must meet each applicable requirement specified in paragraphs (b) through (e) of this section.
(b) If you reduce organic HAP emissions by venting emissions to a fuel gas system or process, you must meet the requirements of §63.982(d) and the requirements referenced therein.
(c) Exceptions to subparts SS and WW of this part 63.
(1) If you conduct a performance test or design evaluation for a control device used to control emissions only from storage tanks, you must establish operating limits, conduct monitoring, and keep records using the same procedures as required in subpart SS of this part 63 for control devices used to reduce emissions from process vents instead of the procedures specified in §§63.985(c),

63.998(d)(2)(i), and 63.999(b)(2).

(2) When the term “storage vessel” is used in subparts SS and WW of this part 63, the term “storage tank,” as defined in §63.2550 applies for the purposes of this subpart.

(d) Planned routine maintenance. The emission limits in Table 4 to this subpart for control devices used to control emissions from storage tanks do not apply during periods of planned routine maintenance. Periods of planned routine maintenance of each control device, during which the control device does not meet the emission limit specified in Table 4 to this subpart, must not exceed 240 hours per year (hr/yr). You may submit an application to the Administrator requesting an extension of this time limit to a total of 360 hr/yr. The application must explain why the extension is needed, it must indicate that no material will be added to the storage tank between the time the 240-hr limit is exceeded and the control device is again operational, and it must be submitted at least 60 days before the 240-hr limit will be exceeded.

(e) Vapor balancing alternative. As an alternative to the emission limits specified in Table 4 to this subpart, you may elect to implement vapor balancing in accordance with §63.1253(f), except as specified in paragraphs (e)(1) through (3) of this section.

(1) When §63.1253(f)(6)(i) refers to a 90 percent reduction, 95 percent applies for the purposes of this subpart.

(2) To comply with §63.1253(f)(6)(i), the owner or operator of an offsite cleaning and reloading facility must comply with §§63.2445 through 63.2550 instead of complying with §63.1253(f)(7)(ii).

(3) You may elect to set a pressure relief device to a value less than the 2.5 pounds per square inch gage pressure (psig) required in §63.1253(f)(5) if you provide rationale in your notification of compliance status report explaining why the alternative value is sufficient to prevent breathing losses at all times.

§ 63.2475 What requirements must I meet for transfer racks?

(a) You must comply with each emission limit and work practice standard in Table 5 to this subpart that applies to your transfer racks, and you must meet each applicable requirement in paragraphs (b) and (c) of this section.
(b) When the term “high throughput transfer rack” is used in subpart SS of this part 63, the term “Group 1 transfer rack,” as defined in §63.2550, applies for the purposes of this subpart.
(c) If you reduce organic HAP emissions by venting emissions to a fuel gas system or process, you must meet the requirements of §63.982(d) and the requirements referenced therein.

§ 63.2480 What requirements must I meet for equipment leaks?

(a) You must meet each requirement in Table 6 to this subpart that applies to your equipment leaks, except as specified in paragraphs (b) and (c) of this section.
(b) The requirements for pressure testing in §63.1036(b) may be applied to all processes, not just batch processes.
(c) For the purposes of this subpart, pressure testing for leaks in accordance with §63.1036(b) is not required after reconfiguration of an equipment train if flexible hose connections are the only disturbed equipment.

§ 63.2485 What requirements must I meet for wastewater streams and liquid streams in open systems within an MCPU?

(a) You must meet each requirement in Table 7 to this subpart that applies to your wastewater streams and liquid streams in open systems within an MCPU, except as specified in paragraphs (b) through (l) of this section.
(b) Wastewater HAP. Where §63.105 and §§63.132 through 63.148 refer to compounds in Table 9 of subpart G of this part 63, the compounds in Tables 8 and 9 to this subpart apply for the purposes of this subpart.
(c) Group 1 wastewater. Section 63.132(c)(1) (i) and (ii) do not apply. For the purposes of this subpart, a process wastewater stream is Group 1 for compounds

in Tables 8 and 9 to this subpart if any of the conditions specified in paragraphs (c) (1) through (3) of this section are met.

(1) The total annual average concentration of compounds in Table 8 to this subpart is greater than 50 ppmw, and the combined total annual average concentration of compounds in Tables 8 and 9 to this subpart is greater than or equal to 10,000 ppmw at any flowrate.

(2) The total annual average concentration of compounds Table 8 to this subpart is greater 50 ppmw, the combined total annual average concentration of compounds in Tables 8 and 9 to this subpart is greater than or equal to 1,000 ppmw, and the annual average flowrate is greater than or equal to 1 l/min.

(3) The total annual average concentration of compounds in Table 8 to this subpart is less than or equal to 50 ppmw, the total annual average concentration of compounds in Table 9 to this subpart is greater than or equal to 30,000 ppmw at an existing source or greater than or equal to 4,500 ppmw at a new source, and the total annual load of compounds in Table 9 to this subpart is greater than or equal to 1 tpy.

(d) Wastewater tank requirements. (1) When §§63.133 and 63.147 reference floating roof requirements in §§63.119 and 63.120, the corresponding requirements in subpart WW of this part 63 may be applied for the purposes of this subpart.

(2) When §63.133 refers to Table 9 of subpart G of this part 63, the maximum true vapor pressure in the table shall be limited to the HAP listed in Tables 8 and 9 to this subpart.

(3) For the purposes of this subpart, the requirements of §63.133(a)(2) are satisfied by operating and maintaining a fixed roof if you demonstrate that the total soluble and partially soluble HAP emissions from the wastewater tank are no more than 5 percent higher than the emissions would be if the contents of the wastewater tank were not heated, treated by an exothermic reaction, or sparged.

(4) The emission limits specified in §§63.133(b)(2) and 63.139 for control devices used to control emissions from wastewater tanks do not apply during periods of

planned routine maintenance of the control device(s) of no more than 240 hr/yr. You may request an extension to a total of 360 hr/yr in accordance with the procedures specified in §63.2470(d).

(e) Individual drain systems. The provisions of §63.136(e)(3) apply except as specified in paragraph (e)(1) of this section.

(1) A sewer line connected to drains that are in compliance with §63.136(e)(1) may be vented to the atmosphere, provided that the sewer line entrance to the first downstream junction box is water sealed and the sewer line vent pipe is designed as specified in §63.136(e)(2)(ii)(A).

(2) [Reserved]

(f) Closed-vent system requirements. When §63.148(k) refers to closed vent systems that are subject to the requirements of §63.172, the requirements of either §63.172 or §63.1034 apply for the purposes of this subpart.

(g) Halogenated vent stream requirements. For each halogenated vent stream from a Group 1 wastewater stream or residual removed from a Group 1 wastewater stream that is vented through a closed-vent system to a combustion device to reduce organic HAP emissions, you must meet the same emission limits as specified for batch process vents in item 2 of Table 2 to this subpart.

(h) Alternative test methods. (1) As an alternative to the test methods specified in §63.144(b)(5)(i), you may use Method 8260 or 8270 as specified in §63.1257(b)(10)(iii).

(2) As an alternative to using the methods specified in §63.144(b)(5)(i), you may conduct wastewater analyses using Method 1666 or 1671 of 40 CFR part 136 and comply with the sampling protocol requirements specified in §63.144(b)(5)(ii). The validation requirements specified in §63.144(b)(5)(iii) do not apply if you use Method 1666 or 1671 of 40 CFR part 136.

(3) As an alternative to using Method 18 of 40 CFR part 60, as specified in §§63.139(c)(1)(ii) and 63.145(i)(2), you may elect to use Method 25A of 40 CFR part 60 as specified in §63.997.

(i) Offsite management and treatment option. (1) If you ship wastewater to an

offsite treatment facility that meets the requirements of §63.138(h), you may elect to document in your notification of compliance status report that the wastewater will be treated as hazardous waste at a facility that meets the requirements of §63.138(h) as an alternative to having the offsite facility submit the certification specified in §63.132(g)(2).

(2) As an alternative to the management and treatment options specified in §63.132(g)(2), any affected wastewater stream (or residual removed from an affected wastewater stream) with a total annual average concentration of compounds in Table 8 to this subpart less than 50 ppmw may be transferred offsite in accordance with paragraphs (i)(2) (i) and (ii) of this section.

(i) The transferee (or you) must demonstrate that less than 5 percent of the HAP in Table 9 to this subpart is emitted from the waste management units up to the activated sludge unit.

(ii) The transferee must treat the wastewater stream or residual in a biological treatment unit in accordance with §§63.138 and 63.145 and the requirements referenced therein.

(j) You must determine the annual average concentration and annual average flowrate for wastewater streams for each MCPU. The procedures for flexible operation units specified in §63.144 (b) and (c) do not apply for the purposes of this subpart.

(k) The requirement to correct outlet concentrations from combustion devices to 3 percent oxygen in §§63.139(c)(1)(ii) and 63.146(i)(6) applies only if supplemental gases are combined with a vent stream from a Group 1 wastewater stream. If emissions are controlled with a vapor recovery system as specified in §63.139(c)(2), you must correct for supplemental gases as specified in §63.2460(c)(6).

(l) Requirements for liquid streams in open systems. (1) References in §63.149 to §63.100(b) mean §63.2435(b) for the purposes of this subpart.

(2) When §63.149(e) refers to 40 CFR 63.100(l) (1) or (2), §63.2445(a) applies for the purposes of this subpart.

(3) When §63.149 uses the term “chemical manufacturing process unit,” the term “MCPU” applies for the purposes of this subpart.
(4) When §63.149(e)(1) refers to characteristics of water that contain compounds in Table 9 to 40 CFR part 63, subpart G, the characteristics specified in paragraphs (c) (1) through (3) of this section apply for the purposes of this subpart.
(5) When §63.149(e)(2) refers to characteristics of water that contain compounds in Table 9 to 40 CFR part 63, subpart G, the characteristics specified in paragraph (c)(2) of this section apply for the purposes of this subpart.

§ 63.2490 What requirements must I meet for heat exchange systems?

(a) You must comply with each requirement in Table 10 to this subpart that applies to your heat exchange systems, except as specified in paragraphs (b) and (c) of this section.
(b) The phrase “a chemical manufacturing process unit meeting the conditions of §63.100 (b)(1) through (b)(3) of this section” in §63.104(a) means “an MCPU meeting the conditions of §63.2435” for the purposes of this subpart.
(c) The reference to §63.100(c) in §63.104(a) does not apply for the purposes of this subpart.

Alternative Means of Compliance

§ 63.2495 How do I comply with the pollution prevention standard?

(a) You may elect to comply with the pollution prevention alternative requirements specified in paragraphs (a) (1) and (2) of this section in lieu of the emission limitations and work practice standards contained in Tables 1 through 7 to this subpart for any MCPU for which initial startup occurred before April 4, 2002.
(1) You must reduce the production-indexed HAP consumption factor (HAP factor) by at least 65 percent from a 3-year average baseline beginning no earlier than the 1994 through 1996 calendar years. For any reduction in the HAP factor

that you achieve by reducing HAP that are also volatile organic compounds (VOC), you must demonstrate an equivalent reduction in the production-indexed VOC consumption factor (VOC factor) on a mass basis. For any reduction in the HAP factor that you achieve by reducing a HAP that is not a VOC, you may not increase the VOC factor.

(2) Any MCPU for which you seek to comply by using the pollution prevention alternative must begin with the same starting material(s) and end with the same product(s). You may not comply by eliminating any steps of a process by transferring the step offsite (to another manufacturing location). You may also not merge a solvent recovery step conducted offsite to onsite and as part of an existing process as a method of reducing consumption.

(3) You may comply with the requirements of paragraph (a)(1) of this section for a series of processes, including situations where multiple processes are merged, if you demonstrate to the satisfaction of the Administrator that the multiple processes were merged after the baseline period into an existing process or processes.

(b) Exclusions. (1) You must comply with the emission limitations and work practice standards contained in Tables 1 through 7 to this subpart for all HAP that are generated in the MCPU and that are not included in consumption, as defined in §63.2550. Hydrogen halides that are generated as a result of combustion control must be controlled according to the requirements of §63.994 and the requirements referenced therein.

(2) You may not merge nondedicated formulation or nondedicated solvent recovery processes with any other processes.

(c) Initial compliance procedures. To demonstrate initial compliance with paragraph (a) of this section, you must prepare a demonstration summary in accordance with paragraph (c) (1) of this section and calculate baseline and target annual HAP and VOC factors in accordance with paragraphs (c) (2) and (3) of this section.

(1) Demonstration plan. You must prepare a pollution prevention demonstration

plan that contains, at a minimum, the information in paragraphs (c)(1) (i) through (iii) of this section for each MCPU for which you comply with paragraph (a) of this section.

(i) Descriptions of the methodologies and forms used to measure and record consumption of HAP and VOC compounds.

(ii) Descriptions of the methodologies and forms used to measure and record production of the product(s).

(iii) Supporting documentation for the descriptions provided in accordance with paragraphs (c)(1) (i) and (ii) of this section including, but not limited to, samples of operator log sheets and daily, monthly, and/or annual inventories of materials and products. You must describe how this documentation will be used to calculate the annual factors required in paragraph (d) of this section.

(2) Baseline factors. You must calculate baseline HAP and VOC factors by dividing the consumption of total HAP and total VOC by the production rate, per process, for the first 3-year period in which the process was operational, beginning no earlier than the period consisting of the 1994 through 1996 calendar years.

(3) Target annual factors. You must calculate target annual HAP and VOC factors. The target annual HAP factor must be equal to 35 percent of the baseline HAP factor. The target annual VOC factor must be lower than the baseline VOC factor by an amount equivalent to the reduction in any HAP that is also a VOC, on a mass basis. The target annual VOC factor may be the same as the baseline VOC factor if the only HAP you reduce is not a VOC.

(d) Continuous compliance requirements. You must calculate annual rolling average values of the HAP and VOC factors (annual factors) in accordance with the procedures specified in paragraphs (d) (1) through (3) of this section. To show continuous compliance, the annual factors must be equal to or less than the target annual factors calculated according to paragraph (c)(3) of this section.

(1) To calculate the annual factors, you must divide the consumption of both total HAP and total VOC by the production rate, per process, for 12-month periods at

the frequency specified in either paragraph (d) (2) or (3) of this section, as applicable.
(2) For continuous processes, you must calculate the annual factors every 30 days for the 12-month period preceding the 30th day (i.e., annual rolling average calculated every 30 days). A process with both batch and continuous operations is considered a continuous process for the purposes of this section.
(3) For batch processes, you must calculate the annual factors every 10 batches for the 12-month period preceding the 10th batch (i.e., annual rolling average calculated every 10 batches), except as specified in paragraphs (d)(3) (i) and (ii) of this section.
(i) If you produce more than 10 batches during a month, you must calculate the annual factors at least once during that month.
(ii) If you produce less than 10 batches in a 12-month period, you must calculate the annual factors for the number of batches in the 12-month period since the previous calculations.
(e) Records. You must keep records of HAP and VOC consumption, production, and the rolling annual HAP and VOC factors for each MCPU for which you are complying with paragraph (a) of this section.
(f) Reporting. (1) You must include the pollution prevention demonstration plan in the precompliance report required by §63.2520(c).
(2) You must identify all days when the annual factors were above the target factors in the compliance reports.

§ 63.2500 How do I comply with emissions averaging?

(a) For an existing source, you may elect to comply with the percent reduction emission limitations in Tables 1, 2, 4, 5, and 7 to this subpart by complying with the emissions averaging provisions specified in §63.150, except as specified in paragraphs (b) through (f) of this section.
(b) The batch process vents in an MCPU collectively are considered one individual emission point for the purposes of emissions averaging, except that

only individual batch process vents must be excluded to meet the requirements of §63.150(d)(5).
(c) References in §63.150 to §§63.112 through 63.130 mean the corresponding requirements in §§63.2450 through 63.2490, including applicable monitoring, recordkeeping, and reporting.
(d) References to “periodic reports” in §63.150 mean “compliance report” for the purposes of this subpart.
(e) For batch process vents, estimate uncontrolled emissions for a standard batch using the procedures in §63.1257(d)(2)(i) and (ii) instead of the procedures in §63.150(g)(2). Multiply the calculated emissions per batch by the number of batches per month when calculating the monthly emissions for use in calculating debits and credits.
(f) References to “storage vessels” in §63.150 mean “storage tank” as defined in §63.2550 for the purposes of this subpart.

§ 63.2505 How do I comply with the alternative standard?

As an alternative to complying with the emission limits and work practice standards for process vents and storage tanks in Tables 1 through 4 to this subpart and the requirements in §§63.2455 through 63.2470, you may comply with the emission limits in paragraph (a) of this section and demonstrate compliance in accordance with the requirements in paragraph (b) of this section.
(a) Emission limits and work practice standards. (1) You must route vent streams through a closed-vent system to a control device that reduces HAP emissions as specified in either paragraph (a)(1)(i) or (ii) of this section.
(i) If you use a combustion control device, it must reduce HAP emissions as specified in paragraphs (a)(1)(i)(A), (B), and (C) of this section.
(A) To an outlet TOC concentration of 20 parts per million by volume (ppmv) or less.
(B) To an outlet concentration of hydrogen halide and halogen HAP of 20 ppmv or less.

(C) As an alternative to paragraph (a)(1)(i)(B) of this section, if you control halogenated vent streams emitted from a combustion device followed by a scrubber, reduce the hydrogen halide and halogen HAP generated in the combustion device by greater than or equal to 95 percent by weight in the scrubber.

(ii) If you use a noncombustion control device(s), it must reduce HAP emissions to an outlet total organic HAP concentration of 50 ppmv or less, and an outlet concentration of hydrogen halide and halogen HAP of 50 ppmv or less.

(2) Any Group 1 process vents within a process that are not controlled according to this alternative standard must be controlled according to the emission limits in Tables 1 through 3 to this subpart.

(b) Compliance requirements. To demonstrate compliance with paragraph (a) of this section, you must meet the requirements of §63.1258(b)(5)(i) beginning no later than the initial compliance date specified in §63.2445, except as specified in paragraphs (b)(1) through (7) of this section.

(1) You must comply with the requirements in §63.983 and the requirements referenced therein for closed-vent systems.

(2) When §63.1258(b)(5)(i) refers to §§63.1253(d) and 63.1254(c), the requirements in paragraph (a) of this section apply for the purposes of this subpart.

(3) You must submit the results of any determination of the target analytes or predominant HAP in the notification of compliance status report.

(4) When §63.1258(b)(5)(i)(B) refers to “HCl,” it means “total hydrogen halide and halogen HAP” for the purposes of this subpart.

(5) If you elect to comply with the requirement to reduce hydrogen halide and halogen HAP by greater than or equal to 95 percent by weight in paragraph (a)(1)(i)(C) of this section, you must meet the requirements in paragraphs (b)(5)(i) and (ii) of this section.

(i) Demonstrate initial compliance with the 95 percent reduction by conducting a performance test and setting a site-specific operating limit(s) for the scrubber in

accordance with §63.994 and the requirements referenced therein. You must submit the results of the initial compliance demonstration in the notification of compliance status report.
(ii) Install, operate, and maintain CPMS for the scrubber as specified in §63.2450(k), instead of as specified in §63.1258(b)(5)(i)(C).
(6) If flow to the scrubber could be intermittent, you must install, calibrate, and operate a flow indicator as specified in §63.2460(c)(7).
(7) Use the operating day as the averaging period for CEMS data and scrubber parameter monitoring data.

Notification, Reports, and Records

§ 63.2515 What notifications must I submit and when?

(a) You must submit all of the notifications in §§63.6(h)(4) and (5), 63.7(b) and (c), 63.8(e), (f)(4) and (6), and 63.9(b) through (h) that apply to you by the dates specified.
(b) Initial notification. As specified in §63.9(b)(2), if you startup your affected source before November 10, 2003, you must submit an initial notification not later than 120 calendar days after November 10, 2003.
(2) As specified in §63.9(b)(3), if you startup your new affected source on or after November 10, 2003, you must submit an initial notification not later than 120 calendar days after you become subject to this subpart.
(c) Notification of performance test. If you are required to conduct a performance test, you must submit a notification of intent to conduct a performance test at least 60 calendar days before the performance test is scheduled to begin as required in §63.7(b)(1). For any performance test required as part of the initial compliance procedures for batch process vents in Table 2 to this subpart, you must also submit the test plan required by §63.7(c) and the emission profile with the notification of the performance test.

§ 63.2520 What reports must I submit and when?

(a) You must submit each report in Table 11 to this subpart that applies to you.
(b) Unless the Administrator has approved a different schedule for submission of reports under §63.10(a), you must submit each report by the date in Table 11 to this subpart and according to paragraphs (b)(1) through (5) of this section.
(1) The first compliance report must cover the period beginning on the compliance date that is specified for your affected source in §63.2445 and ending on June 30 or December 31, whichever date is the first date following the end of the first 6 months after the compliance date that is specified for your affected source in §63.2445.
(2) The first compliance report must be postmarked or delivered no later than August 31 or February 28, whichever date is the first date following the end of the first reporting period specified in paragraph (b)(1) of this section.
(3) Each subsequent compliance report must cover the semiannual reporting period from January 1 through June 30 or the semiannual reporting period from July 1 through December 31.
(4) Each subsequent compliance report must be postmarked or delivered no later than August 31 or February 28, whichever date is the first date following the end of the semiannual reporting period.
(5) For each affected source that is subject to permitting regulations pursuant to 40 CFR part 70 or 40 CFR part 71, and if the permitting authority has established dates for submitting semiannual reports pursuant to 40 CFR 70.6(a)(3)(iii)(A) or 40 CFR 71.6(a)(3)(iii)(A), you may submit the first and subsequent compliance reports according to the dates the permitting authority has established instead of according to the dates in paragraphs (b)(1) through (4) of this section.
(c) Precompliance report. You must submit a precompliance report to request approval for any of the items in paragraphs (c)(1) through (7) of this section. We will either approve or disapprove the report within 90 days after we receive it. If we disapprove the report, you must still be in compliance with the emission

limitations and work practice standards in this subpart by the compliance date. To change any of the information submitted in the report, you must notify us 60 days before the planned change is to be implemented.

(1) Requests for approval to set operating limits for parameters other than those specified in §§63.2455 through 63.2485 and referenced therein. Alternatively, you may make these requests according to §63.8(f).

(2) Descriptions of daily or per batch demonstrations to verify that control devices subject to §63.2460(c)(5) are operating as designed.

(3) A description of the test conditions, data, calculations, and other information used to establish operating limits according to §63.2460(c)(3).

(4) Data and rationale used to support an engineering assessment to calculate uncontrolled emissions in accordance with §63.1257(d)(2)(ii).

(5) The pollution prevention demonstration plan required in §63.2495(c)(1), if you are complying with the pollution prevention alternative.

(6) Documentation of the practices that you will implement to minimize HAP emissions from streams that contain energetics and organic peroxides, and rationale for why meeting the emission limit specified in Tables 1 through 7 to this subpart would create an undue safety hazard.

(7) For fabric filters that are monitored with bag leak detectors, an operation and maintenance plan that describes proper operation and maintenance procedures, and a corrective action plan that describes corrective actions to be taken, and the timing of those actions, when the PM concentration exceeds the set point and activates the alarm.

(d) Notification of compliance status report. You must submit a notification of compliance status report according to the schedule in paragraph (d)(1) of this section, and the notification of compliance status report must contain the information specified in paragraph (d)(2) of this section.

(1) You must submit the notification of compliance status report no later than 150 days after the applicable compliance date specified in §63.2445.

(2) The notification of compliance status report must include the information in

paragraphs (d)(2)(i) through (ix) of this section.
(i) The results of any applicability determinations, emission calculations, or analyses used to identify and quantify HAP emissions from the affected source.
(ii) The results of emissions profiles, performance tests, engineering analyses, design evaluations, flare compliance assessments, inspections and repairs, and calculations used to demonstrate initial compliance according to §§63.2455 through 63.2485. For performance tests, results must include descriptions of sampling and analysis procedures and quality assurance procedures.
(iii) Descriptions of monitoring devices, monitoring frequencies, and the operating limits established during the initial compliance demonstrations, including data and calculations to support the levels you establish.
(iv) All operating scenarios.
(v) Descriptions of worst-case operating and/or testing conditions for control devices.
(vi) Identification of parts of the affected source subject to overlapping requirements described in §63.2535 and the authority under which you will comply.
(vii) The information specified in §63.1039(a)(1) through (3) for each process subject to the work practice standards for equipment leaks in Table 6 to this subpart.
(viii) Identify storage tanks for which you are complying with the vapor balancing alternative in §63.2470(g).
(ix) Records as specified in §63.2535(i)(1) through (3) of process units used to create a PUG and calculations of the initial primary product of the PUG.
(e) Compliance report. The compliance report must contain the information specified in paragraphs (e)(1) through (10) of this section.
(1) Company name and address.
(2) Statement by a responsible official with that official's name, title, and signature, certifying the accuracy of the content of the report.
(3) Date of report and beginning and ending dates of the reporting period.

(4) For each SSM during which excess emissions occur, the compliance report must include records that the procedures specified in your startup, shutdown, and malfunction plan (SSMP) were followed or documentation of actions taken that are not consistent with the SSMP, and include a brief description of each malfunction.

(5) The compliance report must contain the information on deviations, as defined in §63.2550, according to paragraphs (e)(5)(i), (ii), and (iii) of this section.

(i) If there are no deviations from any emission limit, operating limit or work practice standard specified in this subpart, include a statement that there were no deviations from the emission limits, operating limits, or work practice standards during the reporting period.

(ii) For each deviation from an emission limit, operating limit, and work practice standard that occurs at an affected source where you are not using a continuous monitoring system (CMS) to comply with the emission limit or work practice standard in this subpart, you must include the information in paragraphs (e)(5)(ii)(A) through (C) of this section. This includes periods of SSM.

(A) The total operating time of the affected source during the reporting period.

(B) Information on the number, duration, and cause of deviations (including unknown cause, if applicable), as applicable, and the corrective action taken.

(C) Operating logs for the day(s) during which the deviation occurred, except operating logs are not required for deviations of the work practice standards for equipment leaks.

(iii) For each deviation from an emission limit or operating limit occurring at an affected source where you are using a CMS to comply with an emission limit in this subpart, you must include the information in paragraphs (e)(5)(iii)(A) through (L) of this section. This includes periods of SSM.

(A) The date and time that each CMS was inoperative, except for zero (low-level) and high-level checks.

(B) The date, time, and duration that each CEMS was out-of-control, including the information in §63.8(c)(8).

(C) The date and time that each deviation started and stopped, and whether each deviation occurred during a period of startup, shutdown, or malfunction or during another period.
(D) A summary of the total duration of the deviation during the reporting period, and the total duration as a percent of the total operating time of the affected source during that reporting period.
(E) A breakdown of the total duration of the deviations during the reporting period into those that are due to startup, shutdown, control equipment problems, process problems, other known causes, and other unknown causes.
(F) A summary of the total duration of CMS downtime during the reporting period, and the total duration of CMS downtime as a percent of the total operating time of the affected source during that reporting period.
(G) An identification of each HAP that is known to be in the emission stream.
(H) A brief description of the process units.
(I) A brief description of the CMS.
(J) The date of the latest CMS certification or audit.
(K) Operating logs for each day(s) during which the deviation occurred.
(L) The operating day or operating block average values of monitored parameters for each day(s) during which the deviation occurred.
(6) If you use a CEMS, and there were no periods during which it was out-of-control as specified in §63.8(c)(7), include a statement that there were no periods during which the CEMS was out-of-control during the reporting period.
(7) Include each new operating scenario which has been operated since the time period covered by the last compliance report and has not been submitted in the notification of compliance status report or a previous compliance report. For each new operating scenario, you must provide verification that the operating conditions for any associated control or treatment device have not been exceeded and that any required calculations and engineering analyses have been performed. For the purposes of this paragraph, a revised operating scenario for an existing process is considered to be a new operating scenario.

(8) Records of process units added to a PUG as specified in §63.2525(i)(4) and records of primary product redeterminations as specified in §63.2525(i)(5).
(9) Applicable records and information for periodic reports as specified in referenced subparts F, G, SS, UU, WW, and GGG of this part.
(10) Notification of process change. (i) Except as specified in paragraph (e)(10)(ii) of this section, whenever you make a process change, or change any of the information submitted in the notification of compliance status report, that is not within the scope of an existing operating scenario, you must document the change in your compliance report. A process change does not include moving within a range of conditions identified in the standard batch. The notification must include all of the information in paragraphs (e)(10)(i)(A) through (C) of this section.
(A) A description of the process change.
(B) Revisions to any of the information reported in the original notification of compliance status report under paragraph (d) of this section.
(C) Information required by the notification of compliance status report under paragraph (d) of this section for changes involving the addition of processes or equipment at the affected source.
(ii) You must submit a report 60 days before the scheduled implementation date of any of the changes identified in paragraph (e)(10)(ii)(A), (B), or (C) of this section.
(A) Any change to the information contained in the precompliance report.
(B) A change in the status of a control device from small to large.
(C) A change from Group 2 to Group 1 for any emission point.

§ 63.2525 What records must I keep?

You must keep the records specified in paragraphs (a) through (k) of this section.
(a) Each applicable record required by subpart A of this part 63 and in referenced subparts F, G, SS, UU, WW, and GGG of this part 63.
(b) Records of each operating scenario as specified in paragraphs (b)(1) through

(8) of this section.
(1) A description of the process and the type of process equipment used.
(2) An identification of related process vents, including their associated emissions episodes if not complying with the alternative standard in §63.2505; wastewater point of determination (POD); storage tanks; and transfer racks.
(3) The applicable control requirements of this subpart, including the level of required control, and for vents, the level of control for each vent.
(4) The control device or treatment process used, as applicable, including a description of operating and/or testing conditions for any associated control device.
(5) The process vents, wastewater POD, transfer racks, and storage tanks (including those from other processes) that are simultaneously routed to the control device or treatment process(s).
(6) The applicable monitoring requirements of this subpart and any parametric level that assures compliance for all emissions routed to the control device or treatment process.
(7) Calculations and engineering analyses required to demonstrate compliance.
(8) For reporting purposes, a change to any of these elements not previously reported, except for paragraph (b)(5) of this section, constitutes a new operating scenario.
(c) A schedule or log of operating scenarios updated each time a different operating scenario is put into operation.
(d) The information specified in paragraphs (d)(1) and (2) of this section for Group 1 batch process vents in compliance with a percent reduction emission limit in Table 2 to this subpart if some of the vents are controlled to less the percent reduction requirement.
(1) Records of whether each batch operated was considered a standard batch.
(2) The estimated uncontrolled and controlled emissions for each batch that is considered to be a nonstandard batch.
(e) The information specified in paragraphs (e)(1) through (4) of this section for

each process with Group 2 batch process vents or uncontrolled hydrogen halide and halogen HAP emissions from the sum of all batch and continuous process vents less than 1,000 lb/yr. No record is required if you documented in the notification of compliance status report that the MCPU does not process, use, or produce HAP.

(1) A record of the day each batch was completed.

(2) A record of whether each batch operated was considered a standard batch.

(3) The estimated uncontrolled and controlled emissions for each batch that is considered to be a nonstandard batch.

(4) Records of the daily 365-day rolling summations of emissions, or alternative records that correlate to the emissions (e.g., number of batches), calculated no less frequently than monthly.

(f) A record of each time a safety device is opened to avoid unsafe conditions in accordance with §63.2450(s).

(g) Records of the results of each CPMS calibration check and the maintenance performed, as specified in §63.2450(k)(1).

(h) For each CEMS, you must keep records of the date and time that each deviation started and stopped, and whether the deviation occurred during a period of startup, shutdown, or malfunction or during another period.

(i) For each PUG, you must keep records specified in paragraphs (i)(1) through (5) of this section.

(1) Descriptions of the MCPU and other process units in the initial PUG required by §63.2535(l)(1)(v).

(2) Rationale for including each MCPU and other process unit in the initial PUG (i.e., identify the overlapping equipment between process units) required by §63.2535(l)(1)(v).

(3) Calculations used to determine the primary product for the initial PUG required by §63.2535(l)(2)(iv).

(4) Descriptions of process units added to the PUG after the creation date and rationale for including the additional process units in the PUG as required by

§63.2535(l)(1)(v).
(5) The calculation of each primary product redetermination required by §63.2535(l)(2)(iv).
(j) In the SSMP required by §63.6(e)(3), you are not required to include Group 2 emission points, unless those emission points are used in an emissions average. For equipment leaks, the SSMP requirement is limited to control devices and is optional for other equipment.
(k) For each bag leak detector used to monitor PM HAP emissions from a fabric filter, maintain records of any bag leak detection alarm, including the date and time, with a brief explanation of the cause of the alarm and the corrective action taken.

Other Requirements and Information

§ 63.2535 What compliance options do I have if part of my plant is subject to both this subpart and another subpart?

For any equipment, emission stream, or wastewater stream subject to the provisions of both this subpart and another rule, you may elect to comply only with the provisions as specified in paragraphs (a) through (l) of this section. You also must identify the subject equipment, emission stream, or wastewater stream, and the provisions with which you will comply, in your notification of compliance status report required by §63.2520(d).
(a) Compliance with other subparts of this part 63. If you have an MCPU that includes a batch process vent that also is part of a CMPU as defined in subparts F and G of this part 63, you must comply with the emission limits; operating limits; work practice standards; and the compliance, monitoring, reporting and recordkeeping requirements for batch process vents in this subpart, and you must continue to comply with the requirements in subparts F, G, and H of this part 63 that are applicable to the CMPU and associated equipment.
(b) Compliance with 40 CFR parts 264 and 265, subparts AA, BB, and/or CC. (1)

After the compliance dates specified in §63.2445, if a control device that you use to comply with this subpart is also subject to monitoring, recordkeeping, and reporting requirements in 40 CFR part 264, subpart AA, BB, or CC; or the monitoring and recordkeeping requirements in 40 CFR part 265, subpart AA, BB, or CC; and you comply with the periodic reporting requirements under 40 CFR part 264, subpart AA, BB, or CC that would apply to the device if your facility had final-permitted status, you may elect to comply either with the monitoring, recordkeeping, and reporting requirements of this subpart; or with the monitoring and recordkeeping requirements in 40 CFR part 264 or 265 and the reporting requirements in 40 CFR part 264, as described in this paragraph (b)(1), which constitute compliance with the monitoring, recordkeeping, and reporting requirements of this subpart. If you elect to comply with the monitoring, recordkeeping, and reporting requirements in 40 CFR parts 264 and/or 265, you must report the information described in §63.2520(e).

(2) After the compliance dates specified in §63.2445, if you have an affected source with equipment that is also subject to 40 CFR part 264, subpart BB, or to 40 CFR part 265, subpart BB, then compliance with the recordkeeping and reporting requirements of 40 CFR parts 264 and/or 265 may be used to comply with the recordkeeping and reporting requirements of this subpart, to the extent that the requirements of 40 CFR parts 264 and/or 265 duplicate the requirements of this subpart.

(c) Compliance with 40 CFR part 60, subpart Kb and 40 CFR part 61, subpart Y. After the compliance dates specified in §63.2445, you are in compliance with the provisions of this subpart FFFF for any storage tank that is assigned to an MCPU and that is both controlled with a floating roof and in compliance with the provisions of either 40 CFR part 60, subpart Kb, or 40 CFR part 61, subpart Y. You are in compliance with this subpart FFFF if you have a storage tank with a fixed roof, closed-vent system, and control device in compliance with the provisions of either 40 CFR part 60, subpart Kb, or 40 CFR part 61, subpart Y, except that you must comply with the monitoring, recordkeeping, and reporting

requirements in this subpart FFFF. Alternatively, if a storage tank assigned to an MCPU is subject to control under 40 CFR part 60, subpart Kb, or 40 CFR part 61, subpart Y, you may elect to comply only with the requirements for Group 1 storage tanks in this subpart FFFF.

(d) Compliance with subpart I, GGG, or MMM of this part 63. After the compliance dates specified in §63.2445, if you have an affected source with equipment subject to subpart I, GGG, or MMM of this part 63, you may elect to comply with the provisions of subpart H, GGG, or MMM of this part 63, respectively, for all such equipment.

(e) Compliance with subpart GGG of this part 63 for wastewater. After the compliance dates specified in §63.2445, if you have an affected source subject to this subpart and you have an affected source that generates wastewater streams that meet the applicability thresholds specified in §63.1256, you may elect to comply with the provisions of this subpart FFFF for all such wastewater streams.

(f) Compliance with subpart MMM of this part 63 for wastewater. After the compliance dates specified in §63.2445, if you have an affected source subject to this subpart, and you have an affected source that generates wastewater streams that meet the applicability thresholds specified in §63.1362(d), you may elect to comply with the provisions of this subpart FFFF for all such wastewater streams (except that the 99 percent reduction requirement for streams subject to §63.1362(d)(10) still applies).

(g) Compliance with other regulations for wastewater. After the compliance dates specified in §63.2445, if you have a Group 1 wastewater stream that is also subject to provisions in 40 CFR parts 260 through 272, you may elect to determine whether this subpart or 40 CFR parts 260 through 272 contain the more stringent control requirements (e.g., design, operation, and inspection requirements for waste management units; numerical treatment standards; etc.) and the more stringent testing, monitoring, recordkeeping, and reporting requirements. Compliance with provisions of 40 CFR parts 260 through 272 that are determined to be more stringent than the requirements of this subpart

constitute compliance with this subpart. For example, provisions of 40 CFR parts 260 through 272 for treatment units that meet the conditions specified in §63.138(h) constitute compliance with this subpart. You must identify in the notification of compliance status report required by §63.2520(d) the information and procedures that you used to make any stringency determinations.

(h) Compliance with 40 CFR part 60, subpart DDD, III, NNN, or RRR. After the compliance dates specified in §63.2445, if you have an MCPU that contains equipment subject to the provisions of this subpart that are also subject to the provisions of 40 CFR part 60, subpart DDD, III, NNN, or RRR, you may elect to apply this subpart to all such equipment in the MCPU. If an MCPU subject to the provisions of this subpart has equipment to which this subpart does not apply but which is subject to a standard in 40 CFR part 60, subpart DDD, III, NNN, or RRR, you may elect to comply with the requirements for Group 1 process vents in this subpart for such equipment. If you elect any of these methods of compliance, you must consider all total organic compounds, minus methane and ethane, in such equipment for purposes of compliance with this subpart, as if they were organic HAP. Compliance with the provisions of this subpart, in the manner described in this paragraph (h), will constitute compliance with 40 CFR part 60, subpart DDD, III, NNN, or RRR, as applicable.

(i) Compliance with 40 CFR part 61, subpart BB. (1) After the compliance dates specified in §63.2445, a Group 1 transfer rack, as defined in §63.2550, that is also subject to the provisions of 40 CFR part 61, subpart BB, you are required to comply only with the provisions of this subpart.

(2) After the compliance dates specified in §63.2445, a Group 2 transfer rack, as defined in §63.2550, that is also subject to the provisions of 40 CFR part 61, subpart BB, is required to comply with the provisions of either paragraph (l)(2)(i) or (ii) of this section.

(i) If the transfer rack is subject to the control requirements specified in §61.302 of 40 CFR part 61, subpart BB, then you may elect to comply with either the requirements of 40 CFR part 61, subpart BB, or the requirements for Group 1

transfer racks under this subpart FFFF.
(ii) If the transfer rack is subject only to reporting and recordkeeping requirements under 40 CFR part 61, subpart BB, then you are required to comply only with the reporting and recordkeeping requirements specified in this subpart for Group 2 transfer racks, and you are exempt from the reporting and recordkeeping requirements in 40 CFR part 61, subpart BB.
(j) Compliance with 40 CFR part 61, subpart FF. After the compliance date specified in §63.2445, for a Group 1 or Group 2 wastewater stream that is also subject to the provisions of 40 CFR 61.342(c) through (h), and is not exempt under 40 CFR 61.342(c)(2) or (3), you may elect to comply only with the requirements for Group 1 wastewater streams in this subpart FFFF. If a Group 2 wastewater stream is exempted from 40 CFR 61.342(c)(1) under 40 CFR 61.342(c)(2) or (3), then you are required to comply only with the reporting and recordkeeping requirements specified in this subpart for Group 2 wastewater streams, and you are exempt from the requirements in 40 CFR part 61, subpart FF.
(k) Compliance with 40 CFR part 60, subpart VV, and 40 CFR part 61, subpart V. After the compliance date specified in §63.2445, if you have an affected source with equipment that is also subject to the requirements of 40 CFR part 60, subpart VV, or 40 CFR part 61, subpart V, you may elect to apply this subpart to all such equipment. Alternatively, if you have an affected source with no continuous process vents and equipment that is also subject to the requirements of 40 CFR part 60, subpart VV, or 40 CFR part 61, subpart V, you may elect to comply with 40 CFR part 60, subpart VV or 40 CFR part 61, subpart V, as applicable, for all such equipment.
(l) Applicability of process units included in a process unit group. You may elect to develop and comply with the requirements for PUG in accordance with paragraphs (l)(1) through (3) of this section.
(1) Procedures to create process unit groups. Develop and document changes in a PUG in accordance with the procedures specified in paragraphs (l)(1)(i) through

(v) of this section.

(i) Initially, identify an MCPU that is created from nondedicated equipment that will operate on or after November 10, 2003 and identify all processing equipment that is part of this MCPU, based on descriptions in operating scenarios.

(ii) Add to the group any other nondedicated MCPU and other nondedicated process units expected to be operated in the 5 years after the date specified in paragraph (l)(1)(i) of this section, provided they satisfy the criteria specified in paragraphs (l)(1)(ii)(A) through (C) of this section. Also identify all of the processing equipment used for each process unit based on information from operating scenarios and other applicable documentation.

(A) Each process unit that is added to a group must have some processing equipment that is also part of one or more process units in the group.

(B) No process unit may be part of more than one PUG.

(C) The processing equipment used to satisfy the requirement of paragraph (l)(1)(ii)(A) of this section may not be a storage tank or control device.

(iii) The initial PUG consists of all of the processing equipment for the process units identified in paragraphs (l)(1)(i) and (ii) of this section. As an alternative to the procedures specified in paragraphs (l)(1)(i) and (ii) of this section, you may use a PUG that was developed in accordance with §63.1360(h) as your initial PUG.

(iv) Add process units developed in the future in accordance with the conditions specified in paragraphs (l)(1)(ii)(A) and (B) of this section.

(v) Maintain records that describe the process units in the initial PUG, the procedure used to create the PUG, and subsequent changes to each PUG as specified in §63.2525(i). Submit the records in reports as specified in §63.2520(d)(2)(ix) and (e)(8).

(2) Determine primary product. You must determine the primary product of each PUG created in paragraph (l)(1) of this section according to the procedures specified in paragraphs (l)(2)(i) through (iv) of this section.

(i) The primary product is the type of product (e.g., organic chemicals subject to

§63.2435(b)(1), pharmaceutical products subject to §63.1250, or pesticide active ingredients subject to §63.1360) expected to be produced for the greatest operating time in the 5-year period specified in paragraph (l)(1)(ii) of this section.
(ii) If the PUG produces multiple types of products equally based on operating time, then the primary product is the type of product with the greatest production on a mass basis over the 5-year period specified in paragraph (l)(1)(ii) of this section.
(iii) At a minimum, you must redetermine the primary product of the PUG following the procedure specified in paragraphs (l)(2)(i) and (ii) of this section every 5 years.
(iv) You must record the calculation of the initial primary product determination as specified in §63.2525(i)(3) and report the results in the notification of compliance status report as specified in §63.2520(d)(8)(ix). You must record the calculation of each redetermination of the primary product as specified in §63.2525(i)(5) and report the calculation in a compliance report submitted no later than the report covering the period for the end of the 5th year after cessation of production of the previous primary product, as specified in §63.2520(e)(8).
(3) Compliance requirements. (i) If the primary product of the PUG is determined according to paragraph (l)(2) of this section to be material described in §63.2435(b)(1), then you must comply with this subpart for each MCPU in the PUG. You may also elect to comply with this subpart for all other process units in the PUG, which constitutes compliance with other part 63 rules.
(ii) If the primary product of the PUG is determined according to paragraph (l)(2) of this section to be material not described in §63.2435(b)(1), then you must comply with paragraph (l)(3)(ii)(A), (B), or (C) of this section, as applicable.
(A) If the primary product is subject to subpart GGG of this part 63, then comply with the requirements of subpart GGG for each MCPU in the PUG.
(B) If the primary product is subject to subpart MMM of this part 63, then comply with the requirements of subpart MMM for each MCPU in the PUG.
(C) If the primary product is subject to any subpart in this part 63 other than

subpart GGG or subpart MMM, then comply with the requirements of this subpart for each MCPU in the PUG.
(iii) The requirements for new and reconstructed sources in the alternative subpart apply to all MCPU in the PUG if and only if the affected source under the alternative subpart meets the requirements for construction or reconstruction.

§ 63.2540 What parts of the General Provisions apply to me?

Table 12 to this subpart shows which parts of the General Provisions in §§63.1 through 63.15 apply to you.

§ 63.2545 Who implements and enforces this subpart?

(a) This subpart can be implemented and enforced by us, the U.S. Environmental Protection Agency (U.S. EPA), or a delegated authority such as your State, local, or tribal agency. If the U.S. EPA Administrator has delegated authority to your State, local, or tribal agency, then that agency also has the authority to implement and enforce this subpart. You should contact your U.S. EPA Regional Office to find out if this subpart is delegated to your State, local, or tribal agency.
(b) In delegating implementation and enforcement authority of this subpart to a State, local, or tribal agency under 40 CFR part 63, subpart E, the authorities contained in paragraphs (b)(1) through (4) of this section are retained by the Administrator of U.S. EPA and are not delegated to the State, local, or tribal agency.
(1) Approval of alternatives to the non-opacity emission limits and work practice standards in §63.2450(a) under §63.6(g).
(2) Approval of major alternatives to test methods under §63.7(e)(2)(ii) and (f) and as defined in §63.90.
(3) Approval of major alternatives to monitoring under §63.8(f) and as defined in §63.90.
(4) Approval of major alternatives to recordkeeping and reporting under §63.10(f)

and as defined in §63.90.

§ 63.2550 What definitions apply to this subpart?

(a) For an affected source complying with the requirements in subpart SS of this part 63, the terms used in this subpart and in subpart SS of this part 63 have the meaning given them in §63.981, except as specified in §§63.2450(k)(2) and (m), 63.2470(c)(2), 63.2475(b), and paragraph (i) of this section.
(b) For an affected source complying with the requirements in subpart TT of this part 63, the terms used in this subpart and in subpart TT of this part 63 have the meaning given them in §63.1001.
(c) For an affected source complying with the requirements in subpart UU of this part 63, the terms used in this subpart and in subpart UU of this part 63 have the meaning given them in §63.1020.
(d) For an affected source complying with the requirements in subpart WW of this part 63, the terms used in this subpart and subpart WW of this part 63 have the meaning given them in §63.1061, except as specified in §§63.2450(m), 63.2470(c)(2), and paragraph (i) of this section.
(e) For an affected source complying with the requirements in §§63.132 through 63.149, the terms used in this subpart and §§63.132 through 63.149 have the meaning given them in §§63.101 and 63.111, except as specified in §63.2450(m) and paragraph (i) of this section.
(f) For an affected source complying with the requirements in §§63.104 and 63.105, the terms used in this subpart and in §§63.104 and 63.105 of this subpart have the meaning given them in §63.101, except as specified in §§63.2450(m), 63.2490(b), and paragraph (i) of this section.
(g) For an affected source complying with requirements in §§63.1253, 63.1257, and 63.1258, the terms used in this subpart and in §§63.1253, 63.1257, and 63.1258 have the meaning given them in §63.1251, except as specified in §63.2450(m) and paragraph (i) of this section.
(h) For an affected source complying with the requirements in 40 CFR part 65,

subpart F, the terms used in this subpart and in 40 CFR part 65, subpart F, have the meaning given them in 40 CFR 65.2.

(i) All other terms used in this subpart are defined in the Clean Air Act (CAA), in 40 CFR 63.2, and in this paragraph (i). If a term is defined in §63.2, §63.101, §63.111, §63.981, §63.1001, §63.1020, §63.1061, §63.1251, or §65.2 and in this paragraph (i), the definition in this paragraph (i) applies for the purposes of this subpart.

Ancillary activities means boilers and incinerators (not used to comply with the emission limits in Tables 1 through 7 to this subpart), chillers and refrigeration systems, and other equipment and activities that are not directly involved (i.e., they operate within a closed system and materials are not combined with process fluids) in the processing of raw materials or the manufacturing of a product or isolated intermediate.

Batch operation means a noncontinuous operation involving intermittent or discontinuous feed into equipment, and, in general, involves the emptying of the equipment after the operation ceases and prior to beginning a new operation. Addition of raw material and withdrawal of product do not occur simultaneously in a batch operation.

Batch process vent means a vent from a unit operation or vents from multiple unit operations within a process that are manifolded together into a common header, through which a HAP-containing gas stream is, or has the potential to be, released to the atmosphere. Examples of batch process vents include, but are not limited to, vents on condensers used for product recovery, reactors, filters, centrifuges, and process tanks. The following are not batch process vents for the purposes of this subpart:

(1) Continuous process vents;

(2) Bottoms receivers;

(3) Surge control vessels;

(4) Gaseous streams routed to a fuel gas system(s);

(5) Vents on storage tanks, wastewater emission sources, or pieces of equipment

subject to the emission limits and work practice standards in Tables 4, 6, and 7 to this subpart;
(6) Drums, pails, and totes;
(7) Flexible elephant trunk systems that draw ambient air (i.e., the system is not ducted, piped, or otherwise connected to the unit operations) away from operators when vessels are opened; and
(8) Emission streams from emission episodes that are undiluted and uncontrolled containing less than 50 ppmv HAP or less than 200 lb/yr. The HAP concentration or mass emission rate may be determined using any of the following: process knowledge that no HAP are present in the emission stream; an engineering assessment as discussed in §63.1257(d)(2)(ii); equations specified in §63.1257(d)(2)(i), as applicable; test data using Methods 18 of 40 CFR part 60, appendix A; or any other test method that has been validated according to the procedures in Method 301 of appendix A of this part 63.
Bottoms receiver means a tank that collects bottoms from continuous distillation before the stream is sent for storage or for further downstream processing.
Construction means the onsite fabrication, erection, or installation of an affected source or MCPU. Addition of new equipment to an MCPU subject to existing source standards does not constitute construction, but it may constitute reconstruction of the affected source or MCPU if it satisfies the definition of reconstruction in §63.2.
Consumption means the quantity of all HAP raw materials entering a process in excess of the theoretical amount used as reactant, assuming 100 percent stoichiometric conversion. The raw materials include reactants, solvents, and any other additives. If a HAP is generated in the process as well as added as a raw material, consumption includes the quantity generated in the process.
Continuous process vent means the point of discharge to the atmosphere (or the point of entry into a control device, if any) of a gas stream if the gas stream has the characteristics specified in §63.107(b) through (h), or meets the criteria specified in §63.107(i), except:

(1) The reference in §63.107(e) to a chemical manufacturing process unit that meets the criteria of §63.100(b) means an MCPU that meets the criteria of §63.2435(b);
(2) The reference in §63.107(h)(4) to §63.113 means Table 1 to this subpart;
(3) The references in §63.107(h)(7) to §§63.119 and 63.126 mean Tables 4 and 5 to this subpart; and
(4) For the purposes of §63.2455, all references to the characteristics of a process vent (e.g., flowrate, total HAP concentration, or TRE index value) mean the characteristics of the gas stream.
Dedicated MCPU means an MCPU that consists of equipment that is used exclusively for one process, except that storage tanks assigned to the process according to the procedures in §63.2435(d) also may be shared by other processes.
Deviation means any instance in which an affected source subject to this subpart, or an owner or operator of such a source:
(1) Fails to meet any requirement or obligation established by this subpart including, but not limited to, any emission limit, operating limit, or work practice standard; or
(2) Fails to meet any term or condition that is adopted to implement an applicable requirement in this subpart and that is included in the operating permit for any affected source required to obtain such a permit; or
(3) Fails to meet any emission limit, operating limit, or work practice standard in this subpart during startup, shutdown, or malfunction, regardless of whether or not such failure is permitted by this subpart.
Energetics means propellants, explosives, and pyrotechnics and include materials listed at 49 CFR 172.101 as Hazard Class I Hazardous Materials, Divisions 1.1 through 1.6.
Equipment means each pump, compressor, agitator, pressure relief device, sampling connection system, open-ended valve or line, valve, connector, and instrumentation system in organic HAP service; and any control devices or

systems used to comply with Table 6 to this subpart.

Excess emissions means emissions greater than those allowed by the emission limit.

Family of materials means a grouping of materials with the same basic composition or the same basic end use or functionality produced using the same basic feedstocks with essentially identical HAP emission profiles (primary constituent and relative magnitude on a pound per product basis) and manufacturing equipment configuration. Examples of families of materials include multiple grades of the same product or different variations of a product (e.g., blue, black, and red resins).

Group 1 batch process vent means each of the batch process vents in a process for which the collective uncontrolled organic HAP emissions from all of the batch process vents are greater than or equal to 10,000 lb/yr at an existing source or greater than or equal to 3,000 lb/yr at a new source.

Group 2 batch process vent means each batch process vent that does not meet the definition of Group 1 batch process vent.

Group 1 continuous process vent means a continuous process vent with a total resource effectiveness index value, calculated according to §63.2455(b), that is less than 1.9 at an existing source and less than 5.0 at a new source.

Group 2 continuous process vent means a continuous process vent that does not meet the definition of a Group 1 continuous process vent.

Group 1 storage tank means a storage tank with a capacity greater than or equal to 10,000 gal storing material that has a maximum true vapor pressure of total HAP greater than or equal to 6.9 kilopascals at an existing source or greater than or equal to 0.69 kilopascals at a new source.

Group 2 storage tank means a storage tank that does not meet the definition of a Group 1 storage tank.

Group 1 transfer rack means a transfer rack that loads more than 0.65 million liters/year of liquids that contain organic HAP with a rack-weighted average partial pressure, as defined in §63.111, greater than or equal to 1.5 pound per

square inch absolute.

Group 2 transfer rack means a transfer rack that does not meet the definition of a Group 1 transfer rack.

Group 1 wastewater stream means a wastewater stream consisting of process wastewater at an existing or new source that meets the criteria for Group 1 status in §63.2485(c) for compounds in Tables 8 and 9 to this subpart and/or a wastewater stream consisting of process wastewater at a new source that meets the criteria for Group 1 status in §63.132(d) for compounds in Table 8 to subpart G of this part 63.

Group 2 wastewater stream means any process wastewater stream that does not meet the definition of a Group 1 wastewater stream.

Halogenated vent stream means a vent stream determined to have a mass emission rate of halogen atoms contained in organic compounds of 0.45 kilograms per hour or greater determined by the procedures presented in §63.115(d)(2)(v).

Hydrogen halide and halogen HAP means hydrogen chloride, hydrogen fluoride, and chlorine.

In organic HAP service means that a piece of equipment either contains or contacts a fluid (liquid or gas) that is at least 5 percent by weight of total organic HAP as determined according to the provisions of §63.180(d). The provisions of §63.180(d) also specify how to determine that a piece of equipment is not in organic HAP service.

Isolated intermediate means a product of a process that is stored before subsequent processing. An isolated intermediate is usually a product of a chemical synthesis, fermentation, or biological extraction process. Storage of an isolated intermediate marks the end of a process. Storage occurs at any time the intermediate is placed in equipment used solely for storage.

Large control device means a control device that controls total HAP emissions of greater than or equal to 10 tpy, before control.

Maintenance wastewater means wastewater generated by the draining of

process fluid from components in the MCPU into an individual drain system in preparation for or during maintenance activities. Maintenance wastewater can be generated during planned and unplanned shutdowns and during periods not associated with a shutdown. Examples of activities that can generate maintenance wastewater include descaling of heat exchanger tubing bundles, cleaning of distillation column traps, draining of pumps into an individual drain system, and draining of portions of the MCPU for repair. Wastewater from routine cleaning operations occurring as part of batch operations is not considered maintenance wastewater.

Maximum true vapor pressure has the meaning given in §63.111, except that it applies to all HAP rather than only organic HAP.

Miscellaneous organic chemical manufacturing process means all equipment which collectively function to produce a product or isolated intermediate that are materials described in §63.2435(b). For the purposes of this subpart, process includes any, all or a combination of reaction, recovery, separation, purification, or other activity, operation, manufacture, or treatment which are used to produce a product or isolated intermediate. A process is also defined by the following:

(1) Routine cleaning operations conducted as part of batch operations are considered part of the process;

(2) Each nondedicated solvent recovery operation is considered a single process;

(3) Each nondedicated formulation operation is considered a single process that is used to formulate numerous materials and/or products;

(4) Quality assurance/quality control laboratories are not considered part of any process; and

(5) Ancillary activities are not considered a process or part of any process.

Nondedicated solvent recovery operation means a distillation unit or other purification equipment that receives used solvent from more than one MCPU.

Nonstandard batch means a batch process that is operated outside of the range of operating conditions that are documented in an existing operating scenario but is still a reasonably anticipated event. For example, a nonstandard batch occurs

when additional processing or processing at different operating conditions must be conducted to produce a product that is normally produced under the conditions described by the standard batch. A nonstandard batch may be necessary as a result of a malfunction, but it is not itself a malfunction.

On-site or on site means, with respect to records required to be maintained by this subpart or required by another subpart referenced by this subpart, that records are stored at a location within a major source which encompasses the affected source. On-site includes, but is not limited to, storage at the affected source or MCPU to which the records pertain, or storage in central files elsewhere at the major source.

Operating scenario means, for the purposes of reporting and recordkeeping, any specific operation of an MCPU as described by records specified in §63.2525(b).

Organic group means structures that contain primarily carbon, hydrogen, and oxygen atoms.

Organic peroxides means organic compounds containing the bivalent -o-o- structure which may be considered to be a structural derivative of hydrogen peroxide where one or both of the hydrogen atoms has been replaced by an organic radical.

Predominant HAP means as used in calibrating an analyzer, the single organic HAP that constitutes the largest percentage of the total organic HAP in the analyzed gas stream, by volume.

Process tank means a tank or vessel that is used within a process to collect material discharged from a feedstock storage tank or equipment within the process before the material is transferred to other equipment within the process or a product storage tank. A process tank has emissions that are related to the characteristics of the batch cycle, and it does not accumulate product over multiple batches. Surge control vessels and bottoms receivers are not process tanks.

Production-indexed HAP consumption factor (HAP factor) means the result of dividing the annual consumption of total HAP by the annual production rate, per

process.

Production-indexed VOC consumption factor (VOC factor) means the result of dividing the annual consumption of total VOC by the annual production rate, per process.

Quaternary ammonium compounds means a type of organic nitrogen compound in which the molecular structure includes a central nitrogen atom joined to four organic groups as well as an acid radical of some sort.

Recovery device means an individual unit of equipment used for the purpose of recovering chemicals from process vent streams for reuse in a process at the affected source and from wastewater streams for fuel value (i.e., net positive heating value), use, reuse, or for sale for fuel value, use or reuse. Examples of equipment that may be recovery devices include absorbers, carbon adsorbers, condensers, oil-water separators or organic-water separators, or organic removal devices such as decanters, strippers, or thin-film evaporation units. To be a recovery device for a wastewater stream, a decanter and any other equipment based on the operating principle of gravity separation must receive only multi-phase liquid streams.

Responsible official means responsible official as defined in 40 CFR 70.2.

Safety device means a closure device such as a pressure relief valve, frangible disc, fusible plug, or any other type of device which functions exclusively to prevent physical damage or permanent deformation to a unit or its air emission control equipment by venting gases or vapors directly to the atmosphere during unsafe conditions resulting from an unplanned, accidental, or emergency event. For the purposes of this subpart, a safety device is not used for routine venting of gases or vapors from the vapor headspace underneath a cover such as during filling of the unit or to adjust the pressure in response to normal daily diurnal ambient temperature fluctuations. A safety device is designed to remain in a closed position during normal operations and open only when the internal pressure, or another relevant parameter, exceeds the device threshold setting applicable to the air emission control equipment as determined by the owner or

operator based on manufacturer recommendations, applicable regulations, fire protection and prevention codes and practices, or other requirements for the safe handling of flammable, combustible, explosive, reactive, or hazardous materials.
Shutdown means the cessation of operation of a continuous operation for any purpose. Shutdown also means the cessation of a batch operation, or any related individual piece of equipment required or used to comply with this subpart, if the steps taken to cease operation differ from those described in a standard batch or nonstandard batch. Shutdown also applies to emptying and degassing storage vessels. Shutdown does not apply to cessation of batch operations at the end of a campaign or between batches within a campaign when the steps taken are routine operations.
Small control device means a control device that controls total HAP emissions of less than 10 tpy, before control.
Standard batch means a batch process operated within a range of operating conditions that are documented in an operating scenario. Emissions from a standard batch are based on the operating conditions that result in highest emissions. The standard batch defines the uncontrolled and controlled emissions for each emission episode defined under the operating scenario.
Startup means the setting in operation of a continuous operation for any purpose; the first time a new or reconstructed batch operation begins production; for new equipment added, including equipment required or used to comply with this subpart, the first time the equipment is put into operation; or for the introduction of a new product/process, the first time the product or process is run in equipment. For batch operations, startup applies to the first time the equipment is put into operation at the start of a campaign to produce a product that has been produced in the past if the steps taken to begin production differ from those specified in a standard batch or nonstandard batch. Startup does not apply when the equipment is put into operation as part of a batch within a campaign when the steps taken are routine operations.
Storage tank means a tank or other vessel that is used to store liquids that

contain organic HAP and/or hydrogen halide and halogen HAP and that has been assigned to an MCPU according to the procedures in §63.2435(d). The following are not considered storage tanks for the purposes of this subpart:

(1) Vessels permanently attached to motor vehicles such as trucks, railcars, barges, or ships;

(2) Pressure vessels designed to operate in excess of 204.9 kilopascals and without emissions to the atmosphere;

(3) Vessels storing organic liquids that contain HAP only as impurities;

(4) Wastewater storage tanks;

(5) Bottoms receivers;

(6) Surge control vessels; and

(7) Process tanks.

Supplemental gases are any gaseous streams that are not defined as process vents, or closed-vent systems from wastewater management and treatment units, storage tanks, or equipment components and that contain less than 50 ppmv TOC, as determined through process knowledge, that are introduced into vent streams or manifolds. Air required to operate combustion device burner(s) is not considered supplemental gas.

Surge control vessel means feed drums, recycle drums, and intermediate vessels immediately preceding continuous reactors, air-oxidation reactors, or distillation operations. Surge control vessels are used within an MCPU when in-process storage, mixing, or management of flowrates or volumes is needed to introduce material into continuous reactors, air-oxidation reactors, or distillation operations.

Total organic compounds or (TOC) means the total gaseous organic compounds (minus methane and ethane) in a vent stream.

Transfer rack means the collection of loading arms and loading hoses, at a single loading rack, that are assigned to an MCPU according to the procedures specified in §63.2435(d) and are used to fill tank trucks and/or rail cars with organic liquids that contain one or more of the organic HAP listed in section 112(b) of the CAA of this subpart. Transfer rack includes the associated pumps,

meters, shutoff valves, relief valves, and other piping and valves.
Unit operation means those processing steps that occur within distinct equipment that are used, among other things, to prepare reactants, facilitate reactions, separate and purify products, and recycle materials. Equipment used for these purposes includes, but is not limited to, reactors, distillation columns, extraction columns, absorbers, decanters, dryers, condensers, and filtration equipment.
Waste management unit means the equipment, structure(s), and/or device(s) used to convey, store, treat, or dispose of wastewater streams or residuals. Examples of waste management units include wastewater tanks, air flotation units, surface impoundments, containers, oil-water or organic-water separators, individual drain systems, biological wastewater treatment units, waste incinerators, and organic removal devices such as steam and air stripper units, and thin film evaporation units. If such equipment is being operated as a recovery device, then it is part of a miscellaneous organic chemical manufacturing process and is not a waste management unit.
Wastewater means water that is discarded from an MCPU through a single POD and that contains either: an annual average concentration of compounds in Table 8 or 9 to this subpart of at least 5 ppmw and has an annual average flowrate of 0.02 liters per minute or greater; or an annual average concentration of compounds in Table 8 or 9 to this subpart of at least 10,000 ppmw at any flowrate. The following are not considered wastewater for the purposes of this subpart:
(1) Stormwater from segregated sewers;
(2) Water from fire-fighting and deluge systems, including testing of such systems;
(3) Spills;
(4) Water from safety showers;
(5) Samples of a size not greater than reasonably necessary for the method of analysis that is used;
(6) Equipment leaks;

(7) Wastewater drips from procedures such as disconnecting hoses after cleaning lines; and

(8) Noncontact cooling water.

Wastewater stream means a stream that contains only wastewater as defined in this paragraph (h).

Work practice standard means any design, equipment, work practice, or operational standard, or combination thereof, that is promulgated pursuant to section 112(h) of the CAA.

following are not considered wastewater for the purposes of this subpart:

(1) Stormwater from segregated sewers;

(2) Water from fire-fighting and deluge systems, including testing of such systems;

(3) Spills;

(4) Water from safety showers;

(5) Samples of a size not greater than reasonably necessary for the method of analysis that is used;

(6) Equipment leaks;

(7) Wastewater drips from procedures such as disconnecting hoses after cleaning lines; and

(8) Noncontact cooling water.

Wastewater stream means a stream that contains only wastewater as defined in this paragraph (h).

Work practice standard means any design, equipment, work practice, or operational standard, or combination thereof, that is promulgated pursuant to section 112(h) of the CAA.

Tables to Subpart FFFF of Part 63

As required in § 63.2455, you must meet each emission limit and work practice standard in the following table that applies to your continuous process vents:

TABLE 1 TO SUBPART FFFF OF PART 63.—EMISSION LIMITS AND WORK PRACTICE STANDARDS FOR CONTINUOUS PROCESS VENTS

For each . . .	For which . . .	Then you must . . .
1. Group 1 continuous process vent.	a. Not applicable	i. Reduce emissions of total organic HAP by ≥98 percent by weight or to an outlet process concentration ≤20 ppmv as organic HAP or TOC by venting emissions through a closed-vent system to any combination of control devices (except a flare); or ii. Reduce emissions of total organic HAP by venting emissions through a closed vent system to a flare; or iii. Use a recovery device to maintain the TRE above 1.9 for an existing source or above 5.0 for a new source.
2. Halogenated Group 1 continuous process vent stream.	a. You use a combustion control device to control organic HAP emissions.	i. Use a halogen reduction device after the combustion device to reduce emissions of hydrogen halide and halogen HAP by ≥99 percent by weight, or to ≤0.45 kg/hr, or to ≤20 ppmv; or ii. Use a halogen reduction device before the combustion device to reduce the halogen atom mass emission rate to ≤0.45 kg/hr or to a concentration ≤20 ppmv.
3. Group 2 continuous process vent at an existing source.	You use a recovery device to maintain the TRE level >1.9 but ≤5.0.	Comply with the requirements in § 63.993 and the requirements referenced therein.
4. Group 2 continuous process vent at a new source.	You use a recovery device to maintain the TRE level >5.0 but ≤8.0.	Comply with the requirements in § 63.993 and the requirements referenced therein.

As required in § 63.2460, you must meet each emission limit and work practice standard in the following table that applies to your batch process vents:

TABLE 2 TO SUBPART FFFF OF PART 63. EMISSION LIMITS AND WORK PRACTICE STANDARDS FOR BATCH PROCESS VENTS

For each . . .	Then you must . . .	And you must . . .
1. Process with Group 1 batch process vents.	a. Reduce collective uncontrolled organic HAP emissions from the sum of all batch process vents within the process by ≥98 percent by weight by venting emissions from a sufficient number of the vents through a closed-vent system to any combination of control devices (except a flare); or	Not applicable.
	b. Reduce collective uncontrolled organic HAP emissions from the sum of all batch process vents within the process by ≥95 percent by weight by venting emissions from a sufficient number of the vents through a closed-vent system to any combination of recovery devices; or	Not applicable.
	c. For all batch process vents within the process that are not controlled by venting through a closed-vent system to a flare or to any other combination of control devices that reduce total organic HAP to an outlet concentration ≤20 ppmv as TOC or total organic HAP, reduce organic HAP emissions by venting emissions from a sufficient number of the vents through a closed-vent system to any combination of recovery devices that reduce collective emissions by ≥95 percent by weight and/or any combination of control devices that reduce collective emissions by ≥98 percent by weight.	Not applicable.

TABLE 2 TO SUBPART FFFF OF PART 63. EMISSION LIMITS AND WORK PRACTICE STANDARDS FOR BATCH PROCESS VENTS—Continued

For each . . .	Then you must . . .	And you must . . .
2. Halogenated Group 1 batch process vent for which you use a combustion device to control organic HAP emissions.	a. Use a halogen reduction device after the combustion control device; or	i. Reduce overall emissions of hydrogen halide and halogen HAP by ≥99 percent; or ii. Reduce overall emissions of hydrogen halide and halogen HAP to ≤0.45 kg/hr; or iii. Reduce overall emissions of hydrogen halide and halogen HAP to a concentration ≤20 ppmv.
	b. Use a halogen reduction device before the combustion control device.	Reduce the halogen atom mass emission rate to ≤0.45 kg/hr or to a concentration ≤20 ppmv.

As required in § 63.2465, you must meet each emission limit in the following table that applies to your process vents that contain hydrogen halide and halogen HAP emissions or PM HAP emissions:

TABLE 3 TO SUBPART FFFF OF PART 63.—EMISSION LIMITS FOR HYDROGEN HALIDE AND HALOGEN HAP EMISSIONS OR PM HAP EMISSIONS FROM PROCESS VENTS

For each . . .	You must . . .
1. Process with uncontrolled hydrogen halide and halogen HAP emissions from process vents ≥1,000 lb/yr.	Reduce collective hydrogen halide and halogen HAP emissions by ≥99 percent by weight or to an outlet concentration <20 ppmv by venting through a closed-vent system to any combination of control devices.
2. Process at a new source with uncontrolled PM HAP emissions from process vents ≥400 lb/yr.	Reduce overall PM HAP emissions by ≥97 percent by weight.

As required in § 63.2470, you must meet each emission limit in the following table that applies to your storage tanks:

TABLE 4 TO SUBPART FFFF OF PART 63.—EMISSION LIMITS FOR STORAGE TANKS

For each . . .	For which . . .	Then you must . . .
1. Group 1 storage tank	a. The maximum true vapor pressure of total HAP at the storage temperature is ≥76.6 kilopascals.	i. Reduce total HAP emissions by ≥95 percent by weight or to ≤20 ppmv of TOC or organic HAP and ≤20 ppmv of hydrogen halide and halogen HAP by venting emissions through a closed vent system to any combination of control devices (excluding a flare); or ii. Reduce total organic HAP emissions by venting emissions through a closed vent system to a flare; or iii. Reduce total HAP emissions by venting emissions to a fuel gas system or process.
	b. The maximum true vapor pressure of total HAP at the storage temperature is ≤76.6 kilopascals.	i. Comply with the requirements of subpart WW of this part, except as specified in § 63.2470; or ii. Reduce total HAP emissions by ≥95 percent by weight or to <20 ppmv of TOC or organic HAP and <20 ppmv of hydrogen halide and halogen HAP by venting emissions through a closed vent system to any combination of control devices (excluding a flare); or iii. Reduce total organic HAP emissions by venting emissions through a closed vent system to a flare; or iv. Reduce total HAP emissions by venting emissions to a fuel gas system or process.
2. Halogenated vent stream from a Group 1 storage tank.	You use a combustion control device to control organic HAP emissions.	Meet one of the emission limit options specified in Item 2.a.i or ii. in Table 1 to this subpart.

As required in § 63.2475, you must meet each emission limit and work practice standard in the following table that applies to your transfer racks:

TABLE 5 TO SUBPART FFFF OF PART 63.—EMISSION LIMITS AND WORK PRACTICE STANDARDS FOR TRANSFER RACKS

For each . . .	You must . . .
1. Group 1 transfer rack	a. Reduce emissions of total organic HAP by ≥98 percent by weight or to an outlet concentration ≤20 ppmv as organic HAP or TOC by venting emissions through a closed-vent system to any combination of control devices (except a flare); or

TABLE 5 TO SUBPART FFFF OF PART 63.—EMISSION LIMITS AND WORK PRACTICE STANDARDS FOR TRANSFER RACKS—Continued

For each . . .	You must . . .
2. Halogenated Group 1 transfer rack vent stream for which you use a combustion device to control organic HAP emissions.	b. Reduce emissions of total organic HAP by venting emissions through a closed-vent system to a flare; or c. Reduce emissions of total organic HAP by venting emissions to a fuel gas system or process; or d. Use a vapor balancing system designed and operated to collect organic HAP vapors displaced from tank trucks and railcars during loading and route the collected HAP vapors to the storage tank from which the liquid being loaded originated or to another storage tank connected by a common header. a. Use a halogen reduction device after the combustion device to reduce emissions of hydrogen halide and halogen HAP by ≥99 percent by weight, to ≤0.45 kg/hr, or to ≤20 ppmv; or b. Use a halogen reduction device before the combustion device to reduce the halogen atom mass emission rate to ≤0.45 kg/hr or to a concentration ≤20 ppmv.

As required in § 63.2480, you must meet each requirement in the following table that applies to your equipment leaks:

TABLE 6 TO SUBPART FFFF OF PART 63.—REQUIREMENTS FOR EQUIPMENT LEAKS

For all . . .	And that is part of . . .	You must . . .
1. Equipment that is in organic HAP service at an existing source.	a. An MCPU with no continuous process vents.	i. Comply with the requirements of subpart TT of this part 63 and the requirements referenced therein; or ii. Comply with the requirements of subpart UU of this part 63 and the requirements referenced therein; or iii. Comply with the requirements of 40 CFR part 65, subpart F.
	b. An MCPU with at least one continuous process vent.	i. Comply with the requirements of subpart UU of this part 63 and the requirements referenced therein; or ii. Comply with the requirements of 40 CFR part 65, subpart F.
2. Equipment that is in organic HAP service at a new source.	a. Any MCPU	i. Comply with the requirements of subpart UU of this part 63 and the requirements referenced therein; or ii. Comply with the requirements of 40 CFR part 65, subpart F.

As required in § 63.2485, you must meet each requirement in the following table that applies to your wastewater streams and liquid streams in open systems within an MCPU:

TABLE 7 TO SUBPART FFFF OF PART 63.—REQUIREMENTS FOR WASTEWATER STREAMS AND LIQUID STREAMS IN OPEN SYSTEMS WITHIN AN MCPU

For each . . .	You must . . .
1. Process wastewater stream	Comply with the requirements in §§ 63.132 through 63.148 and the requirements referenced therein, except as specified in § 63.2485.
2. Maintenance wastewater stream	Comply with the requirements in § 63.105 and the requirements referenced therein, except as specified in § 63.2485.
3. Liquid streams in an open system within an MCPU.	Comply with the requirements in § 63.149 and the requirements referenced therein, except as specified in § 63.2485.

As specified in § 63.2485, the partially soluble HAP in wastewater that are subject to management and treatment requirements in this subpart FFFF are listed in the following table:

TABLE 8 TO SUBPART FFFF OF PART 63.—PARTIALLY SOLUBLE HAZARDOUS AIR POLLUTANTS

Chemical name . . .	CAS No.
1. 1,1,1–Trichloroethane (methyl chloroform)	71556
2. 1,1,2,2–Tetrachloroethane	79345
3. 1,1,2–Trichloroethane	79005
4. 1,1–Dichloroethylene (vinylidene chloride)	75354
5. 1,2–Dibromoethane	106934
6. 1,2–Dichloroethane (ethylene dichloride)	107062
7. 1,2–Dichloropropane	78875
8. 1,3–Dichloropropene	542756
9. 2,4,5–Trichlorophenol	95954
10. 2–Butanone (MEK)	78933
11. 1,4–Dichlorobenzene	106467

TABLE 8 TO SUBPART FFFF OF PART 63.—PARTIALLY SOLUBLE HAZARDOUS AIR POLLUTANTS—Continued

Chemical name . . .	CAS No.
12. 2–Nitropropane	79469
13. 4–Methyl-2-pentanone (MIBK)	108101
14. Acetaldehyde	75070
15. Acrolein	107028
16. Acrylonitrile	107131
17. Allyl chloride	107051
18. Benzene	71432
19. Benzyl chloride	100447
20. Biphenyl	92524
21. Bromoform (tribromomethane)	75252
22. Bromomethane	74839
23. Butadiene	106990
24. Carbon disulfide	75150
25. Chlorobenzene	108907
26. Chloroethane (ethyl chloride)	75003
27. Chloroform	67663
28. Chloromethane	74873
29. Chloroprene	126998
30. Cumene	98828
31. Dichloroethyl ether	111444
32. Dinitrophenol	51285
33. Epichlorohydrin	106898
34. Ethyl acrylate	140885
35. Ethylbenzene	100414
36. Ethylene oxide	75218
37. Ethylidene dichloride	75343
38. Hexachlorobenzene	118741
39. Hexachlorobutadiene	87683
40. Hexachloroethane	67721
41. Methyl methacrylate	80626
42. Methyl-t-butyl ether	1634044
43. Methylene chloride	75092
44. N-hexane	110543
45. N,N-dimethylaniline	121697
46. Naphthalene	91203
47. Phosgene	75445
48. Propionaldehyde	123386
49. Propylene oxide	75569
50. Styrene	100425
51. Tetrachloroethylene (perchloroethylene)	79345
52. Tetrachloromethane (carbon tetrachloride)	56235
53. Toluene	108883
54. Trichlorobenzene (1,2,4-)	120821
55. Trichloroethylene	79016
56. Trimethylpentane	540841
57. Vinyl acetate	108054
58. Vinyl chloride	75014
59. Xylene (m)	108383
60. Xylene (o)	95476
61. Xylene (p)	106423

As specified in § 63.2485, the soluble HAP in wastewater that are subject to management and treatment requirements of this subpart FFFF are listed in the following table:

TABLE 9 TO SUBPART FFFF OF PART 63.—SOLUBLE HAZARDOUS AIR POLLUTANTS

Chemical name . . .	CAS No.
1. Acetonitrile	75058
2. Acetophenone	98862
3. Diethyl sulfate	64675
4. Dimethyl hydrazine (1,1)	58147
5. Dimethyl sulfate	77781
6. Dinitrotoluene (2,4)	121142
7. Dioxane (1,4)	123911
8. Ethylene glycol dimethyl ether	
9. Ethylene glycol monobutyl ether acetate	
10. Ethylene glycol monomethyl ether acetate	

TABLE 9 TO SUBPART FFFF OF PART 63.—SOLUBLE HAZARDOUS AIR POLLUTANTS—Continued

Chemical name . . .	CAS No.
11. Isophorone	78591
12. Methanol	67561
13. Nitrobenzene	98953
14. Toluidine (o-)	95534
15. Triethylamine	121448

As required in § 63.2490, you must meet each requirement in the following table that applies to your heat exchange systems:

TABLE 10 TO SUBPART FFFF OF PART 63.—WORK PRACTICE STANDARDS FOR HEAT EXCHANGE SYSTEMS

For each . . .	You must . . .
Heat exchange system, as defined in § 63.101	Comply with the requirements of § 63.104 and the requirements referenced therein, except as specified in § 63.2490.

As required in § 63.2520(a) and (b), you must submit each report that applies to you on the schedule shown in the following table:

TABLE 11 TO SUBPART FFFF OF PART 63.—REQUIREMENTS FOR REPORTS

You must submit a(n)	The report must contain . . .	You must submit the report . . .
1. Precompliance report	The information specified in § 63.2520(c).	At least 6 months prior to the compliance date; or for new sources, with the application for approval of construction or reconstruction.
2. Notification of compliance status report.	The information specified in § 63.2520(d).	No later than 150 days after the compliance date specified in § 63.2445.
3. Compliance report	The information specified in § 63.2520(e).	Semiannually according to the requirements in § 63.2520(b).

As specified in § 63.2540, the parts of the General Provisions that apply to you are shown in the following table:

TABLE 12 TO SUBPART FFFF OF PART 63.—APPLICABILITY OF GENERAL PROVISIONS TO SUBPART FFFF

Citation	Subject	Explanation
§ 63.1	Applicability	Yes.
§ 63.2	Definitions	Yes.
§ 63.3	Units and Abbreviations	Yes.
§ 63.4	Prohibited Activities	Yes.
§ 63.5	Construction/Reconstruction	Yes.
§ 63.6(a)	Applicability	Yes.
§ 63.6(b)(1)–(4)	Compliance Dates for New and Reconstructed sources.	Yes.
§ 63.6(b)(5)	Notification	Yes.
§ 63.6(b)(6)	[Reserved].	
§ 63.6(b)(7)	Compliance Dates for New and Reconstructed Area Sources That Become Major.	Yes.
§ 63.6(c)(1)–(2)	Compliance Dates for Existing Sources	Yes.
§ 63.6(c)(3)–(4)	[Reserved].	
§ 63.6(c)(5)	Compliance Dates for Existing Area Sources That Become Major.	Yes
§ 63.6(d)	[Reserved].	
§ 63.6(e)(1)–(2)	Operation & Maintenance	Yes.
§ 63.6(e)(3)(i), (ii), and (v) through (viii).	Startup, Shutdown, Malfunction Plan (SSMP)	Yes, except information regarding Group 2 emission points and equipment leaks is not required in the SSMP, as specified in § 63.2525(j).
§ 63.6(e)(3)(iii) and (iv)	Recordkeeping and Reporting During SSM	No, § 63.998(d)(3) and 63.998(c)(1)(ii)(D) through (G) specify the recordkeeping requirement for SSM events, and § 63.2520(e)(4) specifies reporting requirements.
§ 63.6(f)(1)	Compliance Except During SSM	Yes.
§ 63.6(f)(2)–(3)	Methods for Determining Compliance	Yes.
§ 63.6(g)(1)–(3)	Alternative Standard	Yes.

TABLE 12 TO SUBPART FFFF OF PART 63.—APPLICABILITY OF GENERAL PROVISIONS TO SUBPART FFFF—Continued

Citation	Subject	Explanation
§63.6(h)	Opacity/Visible Emission (VE) Standards	Only for flares for which Method 22 observations are required as part of a flare compliance assessment.
§63.6(i)(1)–(14)	Compliance Extension	Yes.
§63.6(j)	Presidential Compliance Exemption	Yes.
§63.7(a)(1)–(2)	Performance Test Dates	Yes, except substitute 150 days for 180 days.
§63.7(a)(3)	Section 114 Authority	Yes, and this paragraph also applies to flare compliance assessments as specified under §63.997(b)(2).
§63.7(b)(1)	Notification of Performance Test	Yes.
§63.7(b)(2)	Notification of Rescheduling	Yes.
§63.7(c)	Quality Assurance/Test Plan	Yes, except the test plan must be submitted with the notification of the performance test if the control device controls batch process vents.
§63.7(d)	Testing Facilities	Yes.
§63.7(e)(1)	Conditions for Conducting Performance Tests	Yes, except that performance tests for batch process vents must be conducted under worst-case conditions as specified in §63.2460.
§63.7(e)(2)	Conditions for Conducting Performance Tests	Yes.
§63.7(e)(3)	Test Run Duration	Yes.
§63.7(f)	Alternative Test Method	Yes.
§63.7(g)	Performance Test Data Analysis	Yes.
§63.7(h)	Waiver of Tests	Yes.
§63.8(a)(1)	Applicability of Monitoring Requirements	Yes.
§63.8(a)(2)	Performance Specifications	Yes.
§63.8(a)(3)	[Reserved].	
§63.8(a)(4)	Monitoring with Flares	Yes.
§63.8(b)(1)	Monitoring	Yes.
§63.8(b)(2)–(3)	Multiple Effluents and Multiple Monitoring Systems	Yes.
§63.8(c)(1)	Monitoring System Operation and Maintenance	Yes.
§63.8(c)(1)(i)	Routine and Predictable SSM	Yes.
§63.8(c)(1)(ii)	SSM not in SSMP	Yes.
§63.8(c)(1)(iii)	Compliance with Operation and Maintenance Requirements.	Yes.
§63.8(c)(2)–(3)	Monitoring System Installation	Yes.
§63.8(c)(4)	CMS Requirements	No. CMS requirements are specified in referenced subparts G and SS of this part 63.
§63.8(c)(4)(i)–(ii)		Only for the alternative standard, but §63.8(c)(4)(i) does not apply because the alternative standard does not require continuous opacity monitoring systems (COMS).
§63.8(c)(5)	COMS Minimum Procedures	No. Subpart FFFF does not contain opacity or VE limits.
§63.8(c)(6)	CMS Requirements	Only for the alternative standard in §63.2505.
§63.8(c)(7)–(8)	CMS Requirements	Only for the alternative standard in §63.2505. Requirements for CPMS are specified in referenced subparts G and SS of this part 63.
§63.8(d)	CMS Quality Control	Only for the alternative standard in §63.2505.
§63.8(e)	CMS Performance Evaluation	Only for the alternative standard in §63.2505, but §63.8(e)(5)(ii) does not apply because the alternative standard does not require COMS.
§63.8(f)(1)–(5)	Alternative Monitoring Method	Yes, except you may also request approval using the precompliance report.
§63.8(f)(6)	Alternative to Relative Accuracy Test	Only applicable when using CEMS to demonstrate compliance, including the alternative standard in §63.2505.
§63.8(g)(1)–(4)	Data Reduction	Only when using CEMS, including for the alternative standard in §63.2505, except that the requirements for COMS do not apply because subpart FFFF has no opacity or VE limits, and §63.8(g)(2) does not apply because data reduction requirements for CEMS are specified in §63.2450(j).
§63.8(g)(5)	Data Reduction	No. Requirements for CEMS are specified in §63.2450(j). Requirements for CPMS are specified in referenced subparts G and SS of this part 63.
§63.9(a)	Notification Requirements	Yes.
§63.9(b)(1)–(5)	Initial Notifications	Yes.
§63.9(c)	Request for Compliance Extension	Yes.
§63.9(d)	Notification of Special Compliance Requirements for New Source.	Yes.
§63.9(e)	Notification of Performance Test	Yes.
§63.9(f)	Notification of VE/Opacity Test	No. Subpart FFFF does not contain opacity or VE limits.

TABLE 12 TO SUBPART FFFF OF PART 63.—APPLICABILITY OF GENERAL PROVISIONS TO SUBPART FFFF—Continued

Citation	Subject	Explanation
§ 63.9(g)	Additional Notifications When Using CMS	Only for the alternative standard in § 63.2505.
§ 63.9(h)(1)–(6)	Notification of Compliance Status	Yes, except subpart FFFF has no opacity or VE limits, and § 63.9(h)(2) does not apply because § 63.2520(d) specifies the required contents and due date of the notification of compliance status report.
§ 63.9(i)	Adjustment of Submittal Deadlines	Yes.
§ 63.9(j)	Change in Previous Information	No, § 63.2520(e) specifies reporting requirements for process changes.
§ 63.10(a)	Recordkeeping/Reporting	Yes.
§ 63.10(b)(1)	Recordkeeping/Reporting	Yes.
§ 63.10(b)(2)(i)–(ii), (iv), (v)	Records related to SSM	No, §§ 63.998(d)(3) and 63.998(c)(1)(ii)(D) through (G) specify recordkeeping requirements for periods of SSM.
§ 63.10(b)(2)(iii)	Records related to maintenance of air pollution control equipment.	Yes.
§ 63.10(b)(2)(vi), (x), and (xi)	CMS Records	Only for CEMS; requirements for CPMS are specified in referenced subparts G and SS of this part 63.
§ 63.10(b)(2)(vii)–(ix)	Records	Yes.
§ 63.10(b)(2)(xii)	Records	Yes.
§ 63.10(b)(2)(xiii)	Records	Only for the alternative standard in § 63.2505.
§ 63.10(b)(2)(xiv)	Records	Yes.
§ 63.10(b)(3)	Records	Yes.
§ 63.10(c)(1)–(6), (9)–(15)	Records	Only for the alternative standard in § 63.2505.
§ 63.10(c)(7)–(8)	Records	No. Recordkeeping requirements are specified in § 63.2525.
§ 63.10(d)(1)	General Reporting Requirements	Yes.
§ 63.10(d)(2)	Report of Performance Test Results	Yes.
§ 63.10(d)(3)	Reporting Opacity or VE Observations	No. Subpart FFFF does not contain opacity or VE limits.
§ 63.10(d)(4)	Progress Reports	Yes.
§ 63.10(d)(5)(i)	Periodic Startup, Shutdown, and Malfunction Reports	No, § 63.2520(e)(4) and (5) specify the SSM reporting requirements.
§ 63.10(d)(5)(ii)	Immediate SSM Reports	No.
§ 63.10(e)(1)–(2)	Additional CMS Reports	Only for the alternative standard, but § 63.10(e)(2)(ii) does not apply because the alternative standard does not require COMS.
§ 63.10(e)(3)	Reports	No. Reporting requirements are specified in § 63.2520.
§ 63.10(e)(3)(i)–(iii)	Reports	No. Reporting requirements are specified in § 63.2520.
§ 63.10(e)(3)(iv)–(v)	Excess Emissions Reports	No. Reporting requirements are specified in § 63.2520.
§ 63.10(e)(3)(iv)–(v)	Excess Emissions Reports	No. Reporting requirements are specified in § 63.2520.
§ 63.10(e)(3)(vi)–(viii)	Excess Emissions Report and Summary Report	No. Reporting requirements are specified in § 63.2520.
§ 63.10(e)(4)	Reporting COMS data	No. Subpart FFFF does not contain opacity or VE limits.
§ 63.10(f)	Waiver for Recordkeeping/Reporting	Yes.
§ 63.11	Flares	Yes.
§ 63.12	Delegation	Yes.
§ 63.13	Addresses	Yes.
§ 63.14	Incorporation by Reference	Yes.
§ 63.15	Availability of Information	Yes.

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